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PSP 102.5

**The PSP model is a joint development of Delft University
of Technology and NXP Semiconductors**

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Unclassified Report

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Abstract: The PSP model is a compact MOSFET model intended for analog, RF, and digital design. It is jointly developed by NXP Semiconductors and Delft University of Technology. (Until 2011, it was jointly developed by NXP Semiconductors and Arizona State University. The roots of PSP lie in both *MOS Model 11* (developed by NXP Semiconductors) and *SP* (developed at the Pennsylvania State University and later at Arizona State University). PSP is a surface-potential based MOS Model, containing all relevant physical effects (mobility reduction, velocity saturation, DIBL, gate current, lateral doping gradient effects, STI stress, etc.) to model present-day and upcoming deep-submicron bulk CMOS technologies. The source/drain junction model, c.q. the JUNCAP2 model, is fully integrated in PSP. This report contains a full description of the PSP model, including parameter sets, scaling rules, model equations, and a description of the parameter extraction procedure.

In December 2005, the Compact Model Council (CMC) has elected PSP as the new industrial standard model for compact MOSFET modeling.

Since December 2012, Delft University of Technology replaces Arizona State University as the supporting institution.

Conclusions:

History of model and documentation

History of the model

April 2005 Release of PSP 100.0 (which includes JUNCAP2 200.0) as part of SiMKit 2.1. A Verilog-A implementation of the PSP-model is made available as well. The PSP-NQS model is released as Verilog-A code only.

August 2005 Release of PSP 100.1 (which includes JUNCAP2 200.1) as part of SiMKit 2.2. Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only. Focus of this release was mainly on the optimization of the evaluation speed of PSP. Moreover, the PSP implementation has been extended with operating point output (SiMKit-version only).

March 2006 Release of PSP 101.0 (which includes JUNCAP2 200.1) as part of SiMKit 2.3. PSP 101.0 is *not* backward compatible with PSP 100.1. Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only. Focus of this release was on the implementation of requirements for CMC standardization, especially those which could not preserve backward compatibility.

June 2006 Release of PSP 102.0 (which includes JUNCAP2 200.1) as part of SiMKit 2.3.2. PSP 102.0 is backward compatible with PSP 101.0 in all practical cases, provided a simple transformation to the parameter set is applied (see description below). Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only.

Global parameter sets for PSP 101.0 can be transformed to PSP 102.0 by replacing **DPHIBL** (in 102.0 parameter set) by **DPHIBO · DPHIBL** (from 101.0 parameter set). After this transformation, the simulation results of PSP 102.0 are identical to those of PSP 101.0 in all practical situations.

October 2006 Release of PSP 102.1 (which includes JUNCAP2 200.2) as part of SiMKit 2.4. PSP 102.1 is backward compatible with PSP 102.0. SiMKit 2.4 includes a preliminary implementation of the PSP-NQS model. Similar to the previous version, a Verilog-A implementation of the PSP-model is available as well.

October 2007 Release of PSP 102.2 (which includes JUNCAP2 200.3). PSP 102.2 is backward compatible with PSP 102.1.

April 2008 Release of PSP 102.3 (which includes JUNCAP2 200.3) as part of SiMKit 3.1. PSP 102.3 is backward compatible with PSP 102.2. The main changes are:

- Added asymmetric junction model for the drain-bulk junction. The new junction parameters have a suffix “D” added to their names. When **SWJUNASYM** = 1 the original parameters are used for the source-bulk junction and the new parameters are used for drain-bulk junction. When **SWJUNASYM** = 0 the original junction parameters are used for both source-bulk and drain-bulk junctions as in symmetric case, and the new junction parameters are neglected.
- Added asymmetric models for the overlap region of the drain side. These include
 - Added related model parameters **TOXOVDO**, **LOVD** and **NOVDO** to global, **TOXOVDO** and **NOVD** to local and **POTOXOVDO**, **PONOVDO**, **PLNOVD**, **PWNOVD** and **PLWNOVD** to binning models.
 - Asymmetric GIDL/GISL model. Added related parameters **AGIDLWD**, **BGIDLDO**, **STBGIDLDO** and **CGIDLDO** to global, **AGIDL**, **BGIDL**, **STBGIDL** and **CGIDL** to local and **POAGIDL**, **PLAGIDL**, **PWAGIDL**, **PLWAGIDL**, **POBGIDL**, **POSTBGIDL** and **POCGIDL** to binning models.

- Asymmetric overlap gate current model. Added related parameters **IGOVDW** to global, **IGOVD** to local and **POIGOVD**, **PLIGOVD**, **PWIGOVD** and **PLWIGOVD** to binning models.
- Asymmetric overlap capacitance model. Added related parameters **CGOVD** to local, **POCGOVD**, **PLCGOVD**, **PWCGOVD** and **PLWCGOVD** to binning models.
- Asymmetric outer fringe capacitance model. Added related parameters **CFRDW** to global, **CFRD** to local and **POCFRD**, **PLCFRD**, **PWCFRD** and **PLWCFRD** to binning models.

When **SWJUNASYM** = 1 the original parameters for the models listed above are used for the source side and the newly added parameters are used for the drain side. When **SWJUNASYM** = 0 the original parameters are used for both source and drain sides and the new parameters are ignored.

- Added **EF**(local), **EFO**(global) and **POEF**(binning) as flicker noise frequency exponent parameters.
- Added noise parameters **LINTNOI** and **ALPNOI** to global model to increase the flexibility of the length scaling of the flicker noise.
- Some minor bug-fixes and implementation changes.

December 2012 Release of PSP 102.4 as part of SiMKit 4.0.1. PSP 102.4 is backward compatible with the previous version, PSP 102.3. The main changes are:

- Several improvements in the noise-model implementation
 - Fixed sign of correlation coefficient (Verilog-A only).
 - Simplified implementation and better scaled noise amplitude at internal nodes (Verilog-A only).
 - Improved behavior when crossing $V_{ds} = 0$ at high-frequency.
- Scaled local parameters were added to OP-output.
- Some minor implementation changes.
- New parameter **PARAMCHK** to set level of clip warnings (SiMKit only).
- More efficient model evaluation when **MULT** = 0 (SiMKit only).

December 2013 Release of PSP 102.5.0 (which includes JUNCAP 200.4) as part of SiMKit 4.2. The main changes are:

- Addition of excess noise, which is important for sub-100-nm channel lengths. This addition is backwards compatible with PSP 102.4. New parameters: **FNTEXC** (local model), **FNTEXCL** (global model), and **POFNTEXC**, **PLFNTEXC**, **PWFNTEXC**, **PLWFNTEXC** (binning model).
- Minor bugfixes.

History of the documentation

April 2005 First release of PSP (PSP 100.0) documentation.

August 2005 Documentation updated for PSP 100.1, errors corrected and new items added.

March 2006 Documentation adapted to PSP 101.0. Added more details on noise-model implementation and a full description of the NQS-model.

June 2006 Documentation adapted to PSP 102.0 and some errors corrected.

October 2006 Documentation adapted to PSP 102.1 and some errors corrected.

October 2007 Documentation adapted to PSP 102.2 and some errors corrected.

April 2008 Documentation adapted to PSP 102.3 and some errors corrected.

January 2011 Description of SiMKit noise implementation (Section 6.5) aligned with recent modifications.

April 2013 Documentation adapted to PSP 102.4.

December 2013 Documentation adapted to PSP 102.5 and some errors corrected.

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Section 1

Introduction

1.1 Origin and purpose

The PSP model is a compact MOSFET model intended for analog, RF, and digital design. It is jointly developed by NXP Semiconductors and Delft University of Technology. (Until 2011, it was jointly developed by NXP Semiconductors and Arizona State University. The roots of PSP lie in both *MOS Model 11* (developed by NXP Semiconductors) and *SP* (developed at the Pennsylvania State University and later at Arizona State University). PSP is a surface-potential based MOS Model, containing all relevant physical effects (mobility reduction, velocity saturation, DIBL, gate current, lateral doping gradient effects, STI stress, etc.) to model present-day and upcoming deep-submicron bulk CMOS technologies. The source/drain junction model, c.q. the JUNCAP2 model, is fully integrated in PSP.

PSP not only gives an accurate description of currents, charges, and their first order derivatives (i.e. transconductance, conductance and capacitances), but also of the higher order derivatives, resulting in an accurate description of electrical distortion behavior. The latter is especially important for analog and RF circuit design. The model furthermore gives an accurate description of the noise behavior of MOSFETs. Finally, PSP has an option for simulation of non-quasi-static (NQS) effects.

The source code of PSP and the most recent version of this documentation are available on the PSP model web site: psp.ewi.tudelft.nl and the NXP Semiconductors web site: www.nxp.com/models.

1.2 Structure of PSP

The PSP model has a hierarchical structure, similar to that of MOS Model 11 and SP. This means that there is a strict separation of the geometry scaling in the global model and the model equations in the local model.

As a consequence, PSP can be used at either one of two levels.

- **Global level** One uses a global parameter set, which describes a whole geometry range. Combined with instance parameters (such as L and W), a local parameter set is internally generated and further processed at the local level in exactly the same way as a custom-made local parameter set.
- **Local level** One uses a custom-made local parameter set to simulate a transistor with a specific geometry. Temperature scaling is included at this level.

The set of parameters which occur in the equations for the various electrical quantities is called the *local* parameter set. In PSP, temperature scaling parameters are included in the local parameter set. An overview of the local parameters in PSP is given in Section 2.5.7. Each of these parameters can be determined by purely electrical measurements. As a consequence, a local parameter set gives a complete description of the electrical properties of a device of *one* particular geometry.

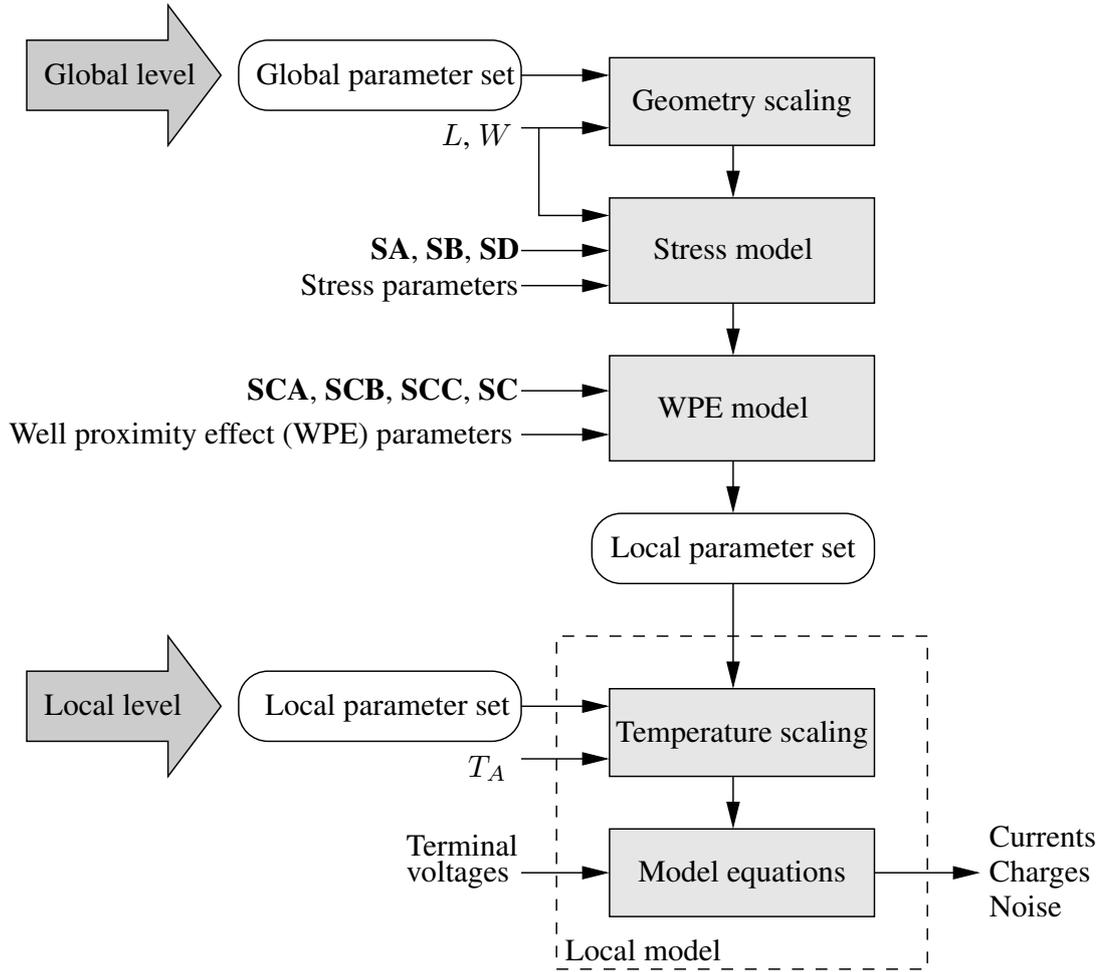


Figure 1.1: Simplified schematic overview of PSP’s hierarchical structure.

Since most of these (local) parameters scale with geometry, all transistors of a particular process can be described by a (larger) set of parameters, called the *global* parameter set. An overview of the global parameters in PSP is given in Section 2.5.3. Roughly speaking, this set contains all local parameters for a long/wide device plus a number of sensitivity coefficients. From the global parameter set, one can obtain a local parameter set for a specific device by applying a set of scaling rules (see Section 3.2). The geometrical properties of that specific device (such as its length and width) enter these scaling rules as *instance parameters*.

From PSP 101.0 onwards it is possible to use a set of binning rules (see Section 3.3) as an alternative to the geometrical (physics based) scaling rules. These binning rules come with their own set of parameters (see Section 2.5.4). Similar to the geometrical scaling rules, the binning rules yield a local parameter set which is used as input for the local model.

PSP is preferably used at global level when designing a circuit in a specific technology for which a global parameter set is available. On the other hand, using PSP at local level can be advantageous during parameter extraction.

As an option, it is possible to deal with the modifications of transistor properties due to stress and well proximity effect (WPE). In PSP, this is implemented by additional sets of transformation rules, which are optionally applied to the intermediate local parameter set generated at the global level. The parameters associated with the stress and WPE models are consequently part of the global parameter set (both geometrical and binning).

The model structure described above is schematically depicted in Fig. 1.1.

The JUNCAP2 model is implemented in such a way that the same set of JUNCAP2 parameters can be used at

both the global and the local level. This is further explained in Section 6.4.

1.3 Availability

The PSP model developers (Delft University of Technology and NXP Semiconductors) distribute the PSP code in two formats:

1. Verilog-A code
2. C-code (as part of SiMKit-library)

The C-version is automatically generated from the Verilog-A version by the software package ADMS [1]. This procedure guarantees the two implementations to contain identical equations. Nevertheless—due to some specific limitations/capabilities of the two formats—there are a few minor differences, which are described in Section 6.5.

1.3.1 SiMKit

SiMKit is a simulator-independent compact transistor model library. Simulator-specific connections are handled through so-called adapters that provide the correct interfacing to the circuit simulator of choice. Currently, adapters to the following circuit simulators are provided:

1. Spectre (Cadence)
2. Pstar (NXP Semiconductors)
3. ADS (Agilent)

Some other circuit simulators vendors provide their own SiMKit adapter, such that simulations with models in SiMKit are possible.

Section 2

Constants and Parameters

2.1 Nomenclature

The nomenclature of the quantities listed in the following sections has been chosen to express their purpose and their relation to other quantities and to preclude ambiguity and inconsistency. Throughout this document, all PSP parameter names are printed in boldface capitals. Parameters which refer to the long transistor limit and/or the reference temperature have a name containing an ‘O’, while the names of scaling parameters end with the letter ‘L’ and/or ‘W’ for length or width scaling, respectively. Parameters for temperature scaling start with ‘ST’, followed by the name of the parameter to which the temperature scaling applies. Parameters used for the binning model start with ‘PO’, ‘PL’, ‘PW’, or ‘PLW’, followed by the name of the local parameter they refer to.

2.2 Parameter clipping

For most parameters, a maximum and/or minimum value is given in the tables below. In PSP, all parameters are limited (clipped) to this pre-specified range in order to prevent difficulties in the numerical evaluation of the model, such as division by zero.

N.B. After computation of the scaling rules (either physical or binning), stress and well proximity effect equations, the resulting local parameters are subjected to the clipping values as given in Section 2.5.7.

2.3 Circuit simulator variables

External electrical variables

The definitions of the external electrical variables are illustrated in Fig. 2.1. The relationship between these external variables and the internal variables used in Chapter 4 is given in Fig. 6.1.

Symbol	Unit	Description
V_D^e	V	Potential applied to drain node
V_G^e	V	Potential applied to gate node
V_S^e	V	Potential applied to source node
V_B^e	V	Potential applied to bulk node
I_D^e	A	DC current into drain node

continued on next page...

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Symbol	Unit	Description
I_G^e	A	DC current into gate node
I_S^e	A	DC current into source node
I_B^e	A	DC current into bulk node
S_{fl}^e	A ² s	Spectral density of flicker noise current in the channel
S_{id}^e	A ² s	Spectral density of thermal noise current in the channel
$S_{\text{ig,S}}^e$	A ² s	Spectral density of induced gate noise at source side
$S_{\text{ig,D}}^e$	A ² s	Spectral density of induced gate noise at drain side
S_{igs}^e	A ² s	Spectral density of gate current shot noise at source side
S_{igd}^e	A ² s	Spectral density of gate current shot noise at drain side
$S_{\text{j,S}}^e$	A ² s	Spectral density of source junction shot noise
$S_{\text{j,D}}^e$	A ² s	Spectral density of drain junction shot noise
S_{igid}^e	A ² s	Cross spectral density between S_{id}^e and (S_{igS}^e or S_{igD}^e)

Other circuit simulator variables

Next to the electrical variables described above, the quantities in the table below are also provided to the model by the circuit simulator.

Symbol	Unit	Description
T_A	°C	Ambient circuit temperature
f_{op}	Hz	Operation frequency

2.4 Model constants

In the following table the symbolic representation, the value and the description of the various physical constants used in the PSP model are given.

No.	Symbol	Unit	Value	Description
1	T_0	K	273.15	Offset between Celsius and Kelvin temperature scale
2	k_B	J/K	$1.3806505 \cdot 10^{-23}$	Boltzmann constant
3	\hbar	J s	$1.05457168 \cdot 10^{-34}$	Reduced Planck constant
4	q	C	$1.6021918 \cdot 10^{-19}$	Elementary unit charge
5	m_0	kg	$9.1093826 \cdot 10^{-31}$	Electron rest mass
6	ϵ_0	F/m	$8.85418782 \cdot 10^{-12}$	Permittivity of free space
7	$\epsilon_{\text{r,Si}}$	–	11.8	Relative permittivity of silicon
8	QM_N	$\text{V m}^{\frac{4}{3}} \text{C}^{-\frac{2}{3}}$	5.951993	Constant of quantum-mechanical behavior of electrons
9	QM_P	$\text{V m}^{\frac{4}{3}} \text{C}^{-\frac{2}{3}}$	7.448711	Constant of quantum-mechanical behavior of holes

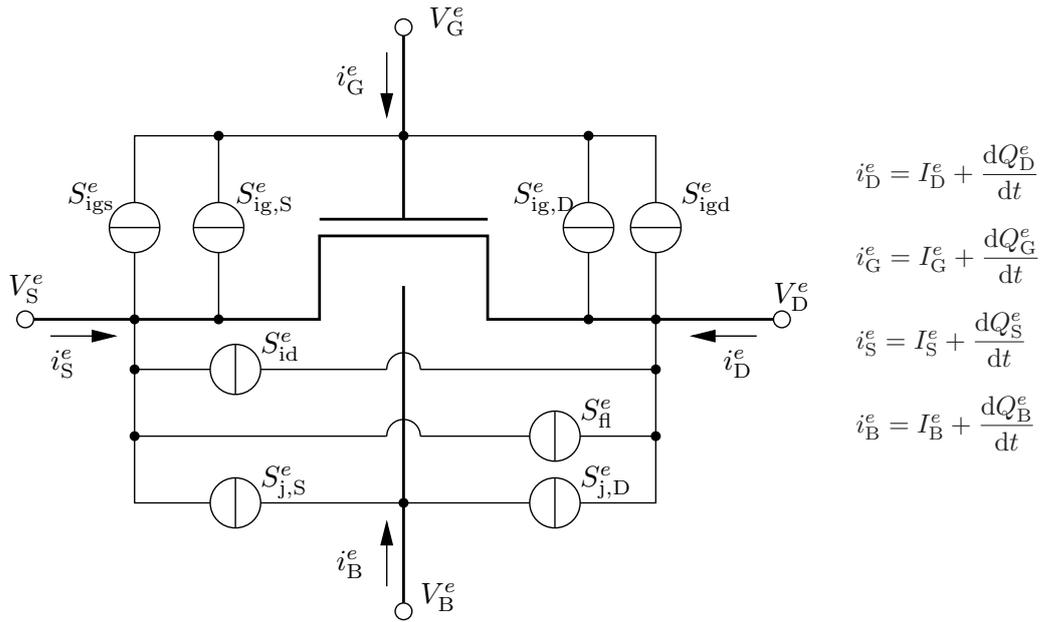


Figure 2.1: Definition of external electrical quantities.

2.5 Model parameters

In this section all parameters of the PSP-model are described. The parameters for the intrinsic MOS model, the stress and well proximity effect models and the junction model are given in separate tables. The complete parameter list for each of the model entry levels is composed of several parts, as indicated in the table below.

Entry level	Sections
Global (geometrical scaling)	2.5.1 (instance parameters)
	2.5.3 (intrinsic MOS)
	2.5.5 (stress)
	2.5.6 (well proximity effect)
	2.5.8 (junctions)
	2.5.9 (parasitic resistances)
Binning	2.5.1 (instance parameters)
	2.5.4 (intrinsic MOS)
	2.5.5 (stress)
	2.5.6 (well proximity effect)
	2.5.8 (junctions)
	2.5.9 (parasitic resistances)
Local	2.5.2 (instance parameters)
	2.5.7 (intrinsic MOS)
	2.5.8 (junctions)
	2.5.9 (parasitic resistances)

2.5.1 Instance parameters for global and binning model

No.	Name	Unit	Default	Min.	Max.	Description
0	<i>L</i>	m	10 ⁻⁶	10 ⁻⁹	–	Drawn channel length
1	<i>W</i>	m	10 ⁻⁶	10 ⁻⁹	–	Drawn channel width (total width)
2	ABSOURCE	m ²	10 ⁻¹²	0	–	Source junction area
3	LSSOURCE	m	10 ⁻⁶	0	–	STI-edge part of source junction perimeter
4	LGSOURCE	m	10 ⁻⁶	0	–	Gate-edge part of source junction perimeter
5	ABDRAIN	m ²	10 ⁻¹²	0	–	Drain junction area
6	 LSDRAIN	m	10 ⁻⁶	0	–	STI-edge part of drain junction perimeter
7	 LGDRAIN	m	10 ⁻⁶	0	–	Gate-edge part of drain junction perimeter
8	AS	m ²	10 ⁻¹²	0	–	Source junction area (alternative spec.)
9	PS	m	10 ⁻⁶	0	–	Source STI-edge perimeter (alternative spec.)
10	AD	m ²	10 ⁻¹²	0	–	Drain junction area (alternative spec.)
11	PD	m	10 ⁻⁶	0	–	Drain STI-edge perimeter (alternative spec.)
12	DELVTO	V	0	–	–	Threshold voltage shift parameter
13	FACTUO	–	1	0	–	Zero-field mobility pre-factor
14	SA	m	0	–	–	Distance between OD-edge and poly at source side
15	SB	m	0	–	–	Distance between OD-edge and poly at drain side
16	SD	m	0	–	–	Distance between neighboring fingers
17	SCA	–	0	0	–	Integral of the first distribution function for scattered well dopant
18	SCB	–	0	0	–	Integral of the second distribution function for scattered well dopant
19	SCC	–	0	0	–	Integral of the third distribution function for scattered well dopant
20	SC	m	0	–	–	Distance between OD edge and nearest well edge
21	NGCON	–	1	1	2	Number of gate contacts
22	XGW	m	10 ⁻⁷	–	–	Distance from the gate contact to the channel edge
23	NF	–	1	1	–	Number of fingers; internally rounded to the nearest integer
24	MULT	–	1	0	–	Number of devices in parallel

Note that if both **SA** and **SB** are set to 0 the stress-equations are not computed. If **SCA**, **SCB**, **SCC** and **SC** are all set to 0 the well proximity effect equations are not computed.

The switching parameter **SWJUNCAP** is used to determine the meaning and usage of the junction instance parameters, where **AB** (junction area), **LS** (STI-edge part of junction perimeter), and **LG** (gate-edge part of junction perimeter) are the instance parameters of a single instance (source or drain) of the JUNCAP2 model.

	source			drain		
SWJUNCAP	AB	LS	LG	AB	LS	LG
0	0	0	0	0	0	0
1	ABSOURCE	LSSOURCE	LGSOURCE	ABDRAIN	LSDRAIN	LGDRAIN
2	AS	PS	W_E	AD	PD	W_E
3	AS	$PS - W_E$	W_E	AD	$PD - W_E$	W_E

2.5.2 Instance parameters for local model

As explained in Section 6.4, the instance parameters for the JUNCAP2 model are used at the local level as well.

No.	Name	Unit	Default	Min.	Max.	Description
0	ABSOURCE	m ²	$1 \cdot 10^{-12}$	0	—	Source junction area
1	LSSOURCE	m	$1 \cdot 10^{-6}$	0	—	STI-edge part of source junction perimeter
2	LGSOURCE	m	$1 \cdot 10^{-6}$	0	—	Gate-edge part of source junction perimeter
3	ABDRAIN	m ²	$1 \cdot 10^{-12}$	0	—	Drain junction area
4	LSDRAIN	m	$1 \cdot 10^{-6}$	0	—	STI-edge part of drain junction perimeter
5	LGDRAIN	m	$1 \cdot 10^{-6}$	0	—	Gate-edge part of drain junction perimeter
6	AS	m ²	$1 \cdot 10^{-12}$	0	—	Source junction area (alternative spec.)
7	PS	m	$1 \cdot 10^{-6}$	0	—	Source STI-edge perimeter (alternative spec.)
8	AD	m ²	$1 \cdot 10^{-12}$	0	—	Drain junction area (alternative spec.)
9	PD	m	$1 \cdot 10^{-6}$	0	—	Drain STI-edge perimeter (alternative spec.)
10	JW	m	$1 \cdot 10^{-6}$	0	—	Junction width
11	DELVTO	V	0	—	—	Threshold voltage shift parameter
12	FACTUO	—	1	0	—	Zero-field mobility pre-factor
13	MULT	—	1	0	—	Number of devices in parallel

Also at the local level, the switching parameter **SWJUNCAP** is used to determine the meaning and usage of the junction instance parameters, where **AB** (junction area), **LS** (STI-edge part of junction perimeter), and **LG** (gate-edge part of junction perimeter) are the instance parameters of a single instance (source or drain) of the JUNCAP2 model. Because the transistor width W is not available at the local level, an additional instance parameter **JW** (junction width) is required when **SWJUNCAP** = 2 or 3.

	source			drain		
SWJUNCAP	AB	LS	LG	AB	LS	LG
0	0	0	0	0	0	0
1	ABSOURCE	LSSOURCE	LGSOURCE	ABDRAIN	LSDRAIN	LGDRAIN
2	AS	PS	JW	AD	PD	JW
3	AS	$PS - JW$	JW	AD	$PD - JW$	JW

2.5.3 Parameters for global model (physical geometrical scaling rules)

The physical geometry scaling rules of PSP (see Section 3.2) have been developed to give a good description over the whole geometry range of CMOS technologies.

No.	Name	Unit	Default	Min.	Max.	Description
0	LEVEL	–	1020	–	–	Model selection parameter; see Sec. 6.1
1	TYPE	–	1	–1	1	Channel type parameter; 1 ↔ NMOS, –1 ↔ PMOS ¹
2	TR	°C	21	–273	–	Reference temperature
Switch Parameters						
3	PARAMCHK	–	0	–	–	Level of clip-warning info ²
4	SWGATE	–	0	0	1	Flag for gate current (0 ↔ “off”)
5	SWIMPACT	–	0	0	1	Flag for impact ionization current (0 ↔ “off”)
6	SWGIDL	–	0	0	1	Flag for GIDL/GISL current (0 ↔ “off”)
7	SWJUNCAP	–	0	0	3	Flag for JUNCAP (0 ↔ “off”); see Sec. 2.5.1
8	SWJUNASYM	–	0	–	–	Flag for asymmetric junctions (0 ↔ “off”) ³
9	QMC	–	1	0	–	Quantum-mechanical correction factor
Process Parameters						
10	LVARO	m	0	–	–	Geometry independent difference between actual and programmed poly-silicon gate length
11	LVARL	–	0	–	–	Length dependence of ΔL_{PS}
12	LVARW	–	0	–	–	Width dependence of ΔL_{PS}
13	LAP	m	0	–	–	Effective channel length reduction per side due to lateral diffusion of source/drain dopant ions
14	WVARO	m	0	–	–	Geometry independent difference between actual and programmed field-oxide opening
15	WVARL	–	0	–	–	Length dependence of ΔW_{OD}
16	WVARW	–	0	–	–	Width dependence of ΔW_{OD}
17	WOT	m	0	–	–	Effective reduction of channel width per side due to lateral diffusion of channel-stop dopant ions
18	DLQ	m	0	–	–	Effective channel length offset for CV
19	DWQ	m	0	–	–	Effective channel width offset for CV
20	VFBO	V	–1	–	–	Geometry-independent flat-band voltage at TR
21	VFBL	–	0	–	–	Length dependence VFB
22	VFBW	–	0	–	–	Width dependence of VFB
23	VFBLW	–	0	–	–	Area dependence of VFB

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¹See Section 6.3.1 for more information on usage of **TYPE** in various simulators.

²Only in SiMKit-version of PSP. See Section 6.5.4 for more information.

³See Section 3.7 for more information on usage of **SWJUNASYM**.

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No.	Name	Unit	Default	Min.	Max.	Description
24	STVFBO	V/K	$5 \cdot 10^{-4}$	—	—	Geometry-independent temperature dependence of VFB
25	STVFBL	—	0	—	—	Length dependence of STVFB
26	STVFBW	—	0	—	—	Width dependence of STVFB
27	STVFBLW	—	0	—	—	Area dependence of STVFB
28	TOXO	m	$2 \cdot 10^{-9}$	10^{-10}	—	Gate oxide thickness
29	EPSROXO	—	3.9	1	—	Relative permittivity of gate dielectric
30	NSUBO	m^{-3}	$3 \cdot 10^{23}$	10^{20}	—	Geometry independent substrate doping
31	NSUBW	—	0	—	—	Width dependence of substrate doping due to segregation
32	WSEG	m	10^{-8}	10^{-10}	—	Characteristic length for segregation of substrate doping
33	NPCK	m^{-3}	10^{24}	0	—	Pocket doping level
34	NPCKW	—	0	—	—	Width dependence of NPCK due to segregation
35	WSEGP	m	10^{-8}	10^{-10}	—	Characteristic length for segregation of pocket doping
36	LPCK	m	10^{-8}	10^{-10}	—	Characteristic length for lateral doping profile
37	LPCKW	—	0	—	—	Width dependence of LPCK due to segregation
38	FOL1	—	0	—	—	First order length dependence of short channel body-effect
39	FOL2	—	0	—	—	Second order length dependence of short channel body-effect
40	VNSUBO	V	0	—	—	Effective doping bias-dependence parameter
41	NSLPO	V	0.05	—	—	Effective doping bias-dependence parameter
42	DNSUBO	V^{-1}	0	—	—	Effective doping bias-dependence parameter
43	DPHIBO	V	0	—	—	Geometry independent offset of φ_B
44	DPHIBL	V	0	—	—	Length dependence of DPHIB
45	DPHIBLEXP	—	1	—	—	Exponent for length dependence of DPHIB
46	DPHIBW	—	0	—	—	Width dependence of DPHIB
47	DPHIBLW	—	0	—	—	Area dependence of DPHIB
48	NPO	m^{-3}	10^{26}	—	—	Geometry-independent gate poly-silicon doping
49	NPL	—	0	—	—	Length dependence of NP
50	CTO	—	0	—	—	Geometry-independent part of interface states factor CT
51	CTL	—	0	—	—	Length dependence of CT

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No.	Name	Unit	Default	Min.	Max.	Description
52	CTLEXP	–	1	–	–	Exponent describing length dependence of CT
53	CTW	–	0	–	–	Width dependence of CT
54	CTLW	–	0	–	–	Area dependence of CT
55	TOXOVO	m	$2 \cdot 10^{-9}$	10^{-10}	–	Overlap oxide thickness
56	TOXOVDO	m	$2 \cdot 10^{-9}$	10^{-10}	–	Overlap oxide thickness for drain side
57	LOV	m	0	0	–	Overlap length for overlap capacitance
58	LOVD	m	0	0	–	Overlap length for gate/drain overlap capacitance
59	NOVO	m^{-3}	$5 \cdot 10^{25}$	–	–	Effective doping of overlap region
60	NOVDO	m^{-3}	$5 \cdot 10^{25}$	–	–	Effective doping of overlap region for drain side
DIBL-Parameters						
61	CFL	V^{-1}	0	–	–	Length dependence of DIBL-parameter
62	CFLEXP	–	2	–	–	Exponent for length dependence of CF
63	CFW	–	0	–	–	Width dependence of CF
64	CFBO	V^{-1}	0	–	–	Back-bias dependence of CF
Mobility Parameters						
65	UO	$m^2/V/s$	$5 \cdot 10^{-2}$	–	–	Zero-field mobility at TR
66	FBET1	–	0	–	–	Relative mobility decrease due to first lateral profile
67	FBET1W	–	0	–	–	Width dependence of FBET1
68	LP1	m	10^{-8}	10^{-10}	–	Mobility-related characteristic length of first lateral profile
69	LP1W	–	0	–	–	Width dependence of LP1
70	FBET2	–	0	–	–	Relative mobility decrease due to second lateral profile
71	LP2	m	10^{-8}	10^{-10}	–	Mobility-related characteristic length of second lateral profile
72	BETW1	–	0	–	–	First higher-order width scaling coefficient of BETN
73	BETW2	–	0	–	–	Second higher-order width scaling coefficient of BETN
74	WBET	m	10^{-9}	10^{-10}	–	Characteristic width for width scaling of BETN
75	STBETO	–	1	–	–	Geometry independent temperature dependence of BETN
76	STBETL	–	0	–	–	Length dependence of STBET
77	STBETW	–	0	–	–	Width dependence of STBET
78	STBETLW	–	0	–	–	Area dependence of STBET
79	MUEO	m/V	0.5	–	–	Geometry independent mobility reduction coefficient at TR

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No.	Name	Unit	Default	Min.	Max.	Description
80	MUEW	–	0	–	–	Width dependence of MUE
81	STMUEO	–	0	–	–	Temperature dependence of MUE
82	THEMUO	–	1.5	0	–	Mobility reduction exponent at TR
83	STTHEMUO	–	1.5	–	–	Temperature dependence of THEMU
84	CSO	–	0	–	–	Geometry independent Coulomb scattering parameter at TR
85	CSL	–	0	–	–	Length dependence of CS
86	CSLEXP	–	0	–	–	Exponent for length dependence of CS
87	CSW	–	0	–	–	Width dependence of CS
88	CSLW	–	0	–	–	Area dependence of CS
89	STCSO	–	0	–	–	Temperature dependence of CS
90	XCORO	V^{-1}	0	–	–	Geometry independent non-universality parameter
91	XCORL	–	0	–	–	Length dependence of XCOR
92	XCORW	–	0	–	–	Width dependence of XCOR
93	XCORLW	–	0	–	–	Area dependence of XCOR
94	STXCORO	–	0	–	–	Temperature dependence of XCOR
95	FETAO	–	1	–	–	Effective field parameter
Series Resistance Parameters						
96	RSW1	Ω	2500	–	–	Source/drain series resistance for channel width W_{EN} at TR
97	RSW2	–	0	–	–	Higher-order width scaling of source/drain series resistance
98	STRSO	–	1	–	–	Temperature dependence of RS
99	RSBO	V^{-1}	0	–	–	Back-bias dependence of RS
100	RSGO	V^{-1}	0	–	–	Gate-bias dependence of RS
Velocity Saturation Parameters						
101	THESATO	V^{-1}	0	–	–	Geometry independent velocity saturation parameter at TR
102	THESATL	V^{-1}	0.05	–	–	Length dependence of THESAT
103	THESATLEXP	–	1	–	–	Exponent for length dependence of THESAT
104	THESATW	–	0	–	–	Width dependence of THESAT
105	THESATLW	–	0	–	–	Area dependence THESAT
106	STTHESATO	–	1	–	–	Geometry independent temperature dependence of THESAT
107	STTHESATL	–	0	–	–	Length dependence of STTHESAT
108	STTHESATW	–	0	–	–	Width dependence of STTHESAT
109	STTHESATLW	–	0	–	–	Area dependence of STTHESAT

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No.	Name	Unit	Default	Min.	Max.	Description
110	THESATBO	V^{-1}	0	–	–	Back-bias dependence of THESAT
111	THESATGO	V^{-1}	0	–	–	Gate-bias dependence of THESAT
Saturation Voltage Parameters						
112	AXO	–	18	–	–	Geometry independent linear/saturation transition factor
113	AXL	–	0.4	0	–	Length dependence of AX
Channel Length Modulation (CLM) Parameters						
114	ALPL	–	$5 \cdot 10^{-4}$	–	–	Length dependence of CLM pre-factor ALP
115	ALPLEXP	–	1	–	–	Exponent for length dependence of ALP
116	ALPW	–	0	–	–	Width dependence of ALP
117	ALP1L1	V	0	–	–	Length dependence of CLM enhancement factor above threshold
118	ALP1LEXP	–	0.5	–	–	Exponent describing the length dependence of ALP1
119	ALP1L2	–	0	0	–	Second order length dependence of ALP1
120	ALP1W	–	0	–	–	Width dependence of ALP1
121	ALP2L1	V	0	–	–	Length dependence of CLM enhancement factor below threshold
122	ALP2LEXP	–	0.5	–	–	Exponent describing the length dependence ALP2
123	ALP2L2	–	0	0	–	Second order length dependence of ALP2
124	ALP2W	–	0	–	–	Width dependence of ALP2
125	VPO	V	0.05	–	–	CLM logarithmic dependence parameter
Impact Ionization (II) Parameters						
126	A1O	–	1	–	–	Geometry independent part of impact-ionization pre-factor A1
127	A1L	–	0	–	–	Length dependence of A1
128	A1W	–	0	–	–	Width dependence of A1
129	A2O	V	10	–	–	Impact-ionization exponent at TR
130	STA2O	V	0	–	–	Temperature dependence of A2
131	A3O	–	1.0	–	–	Geometry independent saturation-voltage dependence of II
132	A3L	–	0	–	–	Length dependence of A3
133	A3W	–	0	–	–	Width dependence of A3
134	A4O	$V^{-\frac{1}{2}}$	0	–	–	Geometry independent back-bias dependence of II
135	A4L	–	0	–	–	Length dependence of A4
136	A4W	–	0	–	–	Width dependence of A4

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No.	Name	Unit	Default	Min.	Max.	Description
Gate Current Parameters						
137	GCOO	–	0	–	–	Gate tunneling energy adjustment
138	IGINVLW	A	0	–	–	Gate channel current pre-factor for a channel area of $W_{EN} \cdot L_{EN}$
139	IGOVW	A	0	–	–	Gate overlap current pre-factor for a channel width of W_{EN}
140	IGOVDW	A	0	–	–	Gate overlap current pre-factor for a channel width of W_{EN} for drain side
141	STIGO	–	2	–	–	Temperature dependence of gate current
142	GC2O	–	0.375	–	–	Gate current slope factor
143	GC3O	–	0.063	–	–	Gate current curvature factor
144	CHIBO	V	3.1	–	–	Tunneling barrier height
Gate-Induced Drain Leakage (GIDL) Parameters						
145	AGIDLW	A/V^3	0	–	–	Width dependence of GIDL pre-factor
146	AGIDLDO	A/V^3	0	–	–	Width dependence of GIDL pre-factor for drain side
147	BGIDLO	V	41	–	–	GIDL probability factor at TR
148	BGIDLDO	V	41	–	–	GIDL probability factor at TR for drain side
149	STBGIDLO	V/K	0	–	–	Temperature dependence of BGIDL
150	STBGIDLDO	V/K	0	–	–	Temperature dependence of BGIDL for drain side
151	CGIDLO	–	0	–	–	Back-bias dependence of GIDL
152	CGIDLDO	–	0	–	–	Back-bias dependence of GIDL for drain side
Charge Model Parameters						
153	CGBOVL	F	0	–	–	Oxide capacitance for gate–bulk overlap for a channel length of L_{EN}
154	CFRW	F	0	–	–	Outer fringe capacitance for a channel width of W_{EN}
155	CFRDW	F	0	–	–	Outer fringe capacitance for a channel width of W_{EN} for drain side
Noise Model Parameters						
156	FNTO	–	1.0	–	–	Thermal noise coefficient
157	FNTEXCL	–	0	0	–	Length dependence of excess noise
158	NFALW	V^{-1}/m^4	$8 \cdot 10^{22}$	–	–	First coefficient of flicker noise for a channel area of $W_{EN} \cdot L_{EN}$
159	NFBLW	V^{-1}/m^2	$3 \cdot 10^7$	–	–	Second coefficient of flicker noise for a channel area of $W_{EN} \cdot L_{EN}$
160	NFCLW	V^{-1}	0	–	–	Third coefficient of flicker noise for a channel area of $W_{EN} \cdot L_{EN}$
161	EFO	–	1.0	–	–	Flicker noise frequency exponent
162	LINTNOI	m	0.0	–	–	Length offset for flicker noise

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No.	Name	Unit	Default	Min.	Max.	Description
163	ALPNOI	–	2.0	–	–	Exponent for length offset for flicker noise
Other Parameters						
164	DTA	K	0	–	–	Temperature offset w.r.t. ambient circuit temperature

2.5.4 Parameters for binning model

The binning scaling rules of PSP (see Section 3.3) have been developed as a flexible but phenomenological alternative to the geometrical scaling rules.

No.	Name	Unit	Default	Min.	Max.	Description
0	LEVEL	–	1021	–	–	Model selection parameter; see Sec. 6.1
1	TYPE	–	1	–1	1	Channel type parameter; 1 ↔ NMOS, –1 ↔ PMOS ⁴
2	TR	°C	21	–273	–	reference temperature
Switch Parameters						
3	PARAMCHK	–	0	–	–	Level of clip-warning info ⁵
4	SWGATE	–	0	0	1	Flag for gate current (0 ↔ “off”)
5	SWIMPACT	–	0	0	1	Flag for impact ionization current (0 ↔ “off”)
6	SWGIDL	–	0	0	1	Flag for GIDL/GISL current (0 ↔ “off”)
7	SWJUNCAP	–	0	0	3	Flag for JUNCAP (0 ↔ “off”); see Sec. 2.5.2
8	SWJUNASYM	–	0	–	–	Flag for asymmetric junctions (0 ↔ “off”) ⁶
9	QMC	–	1	0	–	Quantum-mechanical correction factor
Labels for binning set						
10	LMIN	m	0	–	–	Dummy parameter to label binning set
11	LMAX	m	1	–	–	Dummy parameter to label binning set
12	WMIN	m	0	–	–	Dummy parameter to label binning set
13	WMAX	m	1	–	–	Dummy parameter to label binning set
Process Parameters						
14	LVARO	m	0	–	–	Geometry independent difference between actual and programmed poly-silicon gate length
15	LVARL	–	0	–	–	Length dependence of difference between actual and programmed poly-silicon gate length
16	LAP	m	0	–	–	Effective channel length reduction per side due to lateral diffusion of source/drain dopant ions
17	WVARO	m	0	–	–	Geometry independent difference between actual and programmed field-oxide opening
18	WVARW	–	0	–	–	Width dependence of difference between actual and programmed field-oxide opening
19	WOT	m	0	–	–	Effective reduction of channel width per side due to lateral diffusion of channel-stop dopant ions
20	DLQ	m	0	–	–	Effective channel length reduction for CV
21	DWQ	m	0	–	–	Effective channel width reduction for CV

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⁴See Section 6.3.1 for more information on usage of **TYPE** in various simulators.

⁵Only in SiMKit-version of PSP. See Section 6.5.4 for more information.

⁶See Section 3.7 for more information on usage of **SWJUNASYM**.

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No.	Name	Unit	Default	Min.	Max.	Description
22	POVFB	V	-1	-	-	Coefficient for the geometry independent part of flat-band voltage at TR
23	PLVFB	V	0	-	-	Coefficient for the length dependence of flat-band voltage at TR
24	PWVFB	V	0	-	-	Coefficient for the width dependence of flat-band voltage at TR
25	PLWVFB	V	0	-	-	Coefficient for the length times width dependence of flat-band voltage at TR
26	POSTVFB	V/K	$5 \cdot 10^{-4}$	-	-	Coefficient for the geometry independent part of temperature dependence of VFB
27	PLSTVFB	V/K	0	-	-	Coefficient for the length dependence of temperature dependence of VFB
28	PWSTVFB	V/K	0	-	-	Coefficient for the width dependence of temperature dependence of VFB
29	PLWSTVFB	V/K	0	-	-	Coefficient for the length times width dependence of temperature dependence of VFB
30	POTOX	m	$2 \cdot 10^{-9}$	-	-	Coefficient for the geometry independent part of gate oxide thickness
31	POEPSROX	-	3.9	1	-	Coefficient for the geometry independent part of relative permittivity of gate dielectric
32	PONEFF	m^{-3}	$5 \cdot 10^{23}$	-	-	Coefficient for the geometry independent part of substrate doping
33	PLNEFF	m^{-3}	0	-	-	Coefficient for the length dependence of substrate doping
34	PWNEFF	m^{-3}	0	-	-	Coefficient for the width dependence of substrate doping
35	PLWNEFF	m^{-3}	0	-	-	Coefficient for the length times width dependence of substrate doping
36	POVNSUB	V	0	-	-	Coefficient for the geometry independent part of effective doping bias-dependence parameter
37	PONSLP	V	$5 \cdot 10^{-2}$	-	-	Coefficient for the geometry independent part of effective doping bias-dependence parameter
38	PODNSUB	V^{-1}	0	-	-	Coefficient for the geometry independent part of effective doping bias-dependence parameter
39	PODPHIB	V	0	-	-	Coefficient for the geometry independent part of offset of ϕ_B
40	PLDPHIB	V	0	-	-	Coefficient for the length dependence of offset of ϕ_B

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No.	Name	Unit	Default	Min.	Max.	Description
41	PWDPHIB	V	0	—	—	Coefficient for the width dependence of offset of ϕ_B
42	PLWDPHIB	V	0	—	—	Coefficient for the length times width dependence of offset of ϕ_B
43	PONP	m^{-3}	10^{26}	—	—	Coefficient for the geometry independent part of gate poly-silicon doping
44	PLNP	m^{-3}	0	—	—	Coefficient for the length dependence of gate poly-silicon doping
45	PWNP	m^{-3}	0	—	—	Coefficient for the width dependence of gate poly-silicon doping
46	PLWNP	m^{-3}	0	—	—	Coefficient for the length times width dependence of gate poly-silicon doping
47	POCT	—	0	—	—	Coefficient for the geometry independent part of interface states factor
48	PLCT	—	0	—	—	Coefficient for the length dependence of interface states factor
49	PWCT	—	0	—	—	Coefficient for the width dependence of interface states factor
50	PLWCT	—	0	—	—	Coefficient for the length times width dependence of interface states factor
51	POTOXOV	m	$2 \cdot 10^{-9}$	—	—	Coefficient for the geometry independent part of overlap oxide thickness
52	POTOXOVD	m	$2 \cdot 10^{-9}$	—	—	Coefficient for the geometry independent part of overlap oxide thickness for drain side
53	PONOV	m^{-3}	$5 \cdot 10^{25}$	—	—	Coefficient for the geometry independent part of effective doping of overlap region
54	PLNOV	m^{-3}	0	—	—	Coefficient for the length dependence of effective doping of overlap region
55	PWNOV	m^{-3}	0	—	—	Coefficient for the width dependence of effective doping of overlap region
56	PLWNOV	m^{-3}	0	—	—	Coefficient for the length times width dependence of effective doping of overlap region
57	PONOVD	m^{-3}	$5 \cdot 10^{25}$	—	—	Coefficient for the geometry independent part of effective doping of overlap region for drain side
58	PLNOVD	m^{-3}	0	—	—	Coefficient for the length dependence of effective doping of overlap region for drain side
59	PWNOVD	m^{-3}	0	—	—	Coefficient for the width dependence of effective doping of overlap region for drain side
60	PLWNOVD	m^{-3}	0	—	—	Coefficient for the length times width dependence of effective doping of overlap region for drain side

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No.	Name	Unit	Default	Min.	Max.	Description
DIBL Parameters						
61	POCF	V^{-1}	0	—	—	Coefficient for the geometry independent part of DIBL parameter
62	PLCF	V^{-1}	0	—	—	Coefficient for the length dependence of DIBL parameter
63	PWCF	V^{-1}	0	—	—	Coefficient for the width dependence of DIBL parameter
64	PLWCF	V^{-1}	0	—	—	Coefficient for the length times width dependence of DIBL parameter
65	POCFB	V^{-1}	0	—	—	Coefficient for the geometry independent part of back-bias dependence of CF
Mobility Parameters						
66	POBETN	$m^2/V/s$	$7 \cdot 10^{-2}$	—	—	Coefficient for the geometry independent part of product of channel aspect ratio and zero-field mobility at TR
67	PLBETN	$m^2/V/s$	0	—	—	Coefficient for the length dependence of product of channel aspect ratio and zero-field mobility at TR
68	PWBETN	$m^2/V/s$	0	—	—	Coefficient for the width dependence of product of channel aspect ratio and zero-field mobility at TR
69	PLWBETN	$m^2/V/s$	0	—	—	Coefficient for the length times width dependence of product of channel aspect ratio and zero-field mobility at TR
70	POSTBET	—	1	—	—	Coefficient for the geometry independent part of temperature dependence of BETN
71	PLSTBET	—	0	—	—	Coefficient for the length dependence of temperature dependence of BETN
72	PWSTBET	—	0	—	—	Coefficient for the width dependence of temperature dependence of BETN
73	PLWSTBET	—	0	—	—	Coefficient for the length times width dependence of temperature dependence of BETN
74	POMUE	m/V	$5 \cdot 10^{-1}$	—	—	Coefficient for the geometry independent part of mobility reduction coefficient at TR
75	PLMUE	m/V	0	—	—	Coefficient for the length dependence of mobility reduction coefficient at TR
76	PWMUE	m/V	0	—	—	Coefficient for the width dependence of mobility reduction coefficient at TR
77	PLWMUE	m/V	0	—	—	Coefficient for the length times width dependence of mobility reduction coefficient at TR
78	POSTMUE	—	0	—	—	Coefficient for the geometry independent part of temperature dependence of MUE

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No.	Name	Unit	Default	Min.	Max.	Description
79	POTHEMU	–	1.5	–	–	Coefficient for the geometry independent part of mobility reduction exponent at TR
80	POSTHEMU	–	1.5	–	–	Coefficient for the geometry independent part of temperature dependence of THEMU
81	POCS	–	0	–	–	Coefficient for the geometry independent part of Coulomb scattering parameter at TR
82	PLCS	–	0	–	–	Coefficient for the length dependence of Coulomb scattering parameter at TR
83	PWCS	–	0	–	–	Coefficient for the width dependence of Coulomb scattering parameter at TR
84	PLWCS	–	0	–	–	Coefficient for the length times width dependence of Coulomb scattering parameter at TR
85	POSTCS	–	0	–	–	Coefficient for the geometry independent part of temperature dependence of CS
86	POXCOR	V ⁻¹	0	–	–	Coefficient for the geometry independent part of non-universality parameter
87	PLXCOR	V ⁻¹	0	–	–	Coefficient for the length dependence of non-universality parameter
88	PWXCOR	V ⁻¹	0	–	–	Coefficient for the width dependence of non-universality parameter
89	PLWXCOR	V ⁻¹	0	–	–	Coefficient for the length times width dependence of non-universality parameter
90	POSTXCOR	–	0	–	–	Coefficient for the geometry independent part of temperature dependence of XCOR
91	POFETA	–	1	–	–	Coefficient for the geometry independent part of effective field parameter
Series Resistance Parameters						
92	PORS	Ω	30	–	–	Coefficient for the geometry independent part of source/drain series resistance at TR
93	PLRS	Ω	0	–	–	Coefficient for the length dependence of source/drain series resistance at TR
94	PWRS	Ω	0	–	–	Coefficient for the width dependence of source/drain series resistance at TR
95	PLWRS	Ω	0	–	–	Coefficient for the length times width dependence of source/drain series resistance at TR
96	POSTRS	–	1	–	–	Coefficient for the geometry independent part of temperature dependence of RS
97	PORSB	V ⁻¹	0	–	–	Coefficient for the geometry independent part of back-bias dependence of RS

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No.	Name	Unit	Default	Min.	Max.	Description
98	PORSG	V^{-1}	0	—	—	Coefficient for the geometry independent part of gate-bias dependence of RS
Velocity Saturation Parameters						
99	POTHSAT	V^{-1}	1	—	—	Coefficient for the geometry independent part of velocity saturation parameter at TR
100	PLTHESAT	V^{-1}	0	—	—	Coefficient for the length dependence of velocity saturation parameter at TR
101	PWTHESAT	V^{-1}	0	—	—	Coefficient for the width dependence of velocity saturation parameter at TR
102	PLWTHESAT	V^{-1}	0	—	—	Coefficient for the length times width dependence of velocity saturation parameter at TR
103	POSTHSAT	—	1	—	—	Coefficient for the geometry independent part of temperature dependence of THE-SAT
104	PLSTHSAT	—	0	—	—	Coefficient for the length dependence of temperature dependence of THESAT
105	PWSTHSAT	—	0	—	—	Coefficient for the width dependence of temperature dependence of THESAT
106	PLWSTHSAT	—	0	—	—	Coefficient for the length times width dependence of temperature dependence of THESAT
107	POTHSATB	V^{-1}	0	—	—	Coefficient for the geometry independent part of back-bias dependence of velocity saturation
108	PLTHESATB	V^{-1}	0	—	—	Coefficient for the length dependence of back-bias dependence of velocity saturation
109	PWTHESATB	V^{-1}	0	—	—	Coefficient for the width dependence of back-bias dependence of velocity saturation
110	PLWTHESATB	V^{-1}	0	—	—	Coefficient for the length times width dependence of back-bias dependence of velocity saturation
111	POTHSATG	V^{-1}	0	—	—	Coefficient for the geometry independent part of gate-bias dependence of velocity saturation
112	PLTHESATG	V^{-1}	0	—	—	Coefficient for the length dependence of gate-bias dependence of velocity saturation
113	PWTHESATG	V^{-1}	0	—	—	Coefficient for the width dependence of gate-bias dependence of velocity saturation
114	PLWTHESATG	V^{-1}	0	—	—	Coefficient for the length times width dependence of gate-bias dependence of velocity saturation
Saturation Voltage Parameters						
115	POAX	—	3	—	—	Coefficient for the geometry independent part of linear/saturation transition factor

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No.	Name	Unit	Default	Min.	Max.	Description
116	PLAX	–	0	–	–	Coefficient for the length dependence of linear/saturation transition factor
117	PWAX	–	0	–	–	Coefficient for the width dependence of linear/saturation transition factor
118	PLWAX	–	0	–	–	Coefficient for the length times width dependence of linear/saturation transition factor
Channel Length Modulation (CLM) Parameters						
119	POALP	–	10^{-2}	–	–	Coefficient for the geometry independent part of CLM pre-factor
120	PLALP	–	0	–	–	Coefficient for the length dependence of CLM pre-factor
121	PWALP	–	0	–	–	Coefficient for the width dependence of CLM pre-factor
122	PLWALP	–	0	–	–	Coefficient for the length times width dependence of CLM pre-factor
123	POALP1	V	0	–	–	Coefficient for the geometry independent part of CLM enhancement factor above threshold
124	PLALP1	V	0	–	–	Coefficient for the length dependence of CLM enhancement factor above threshold
125	PWALP1	V	0	–	–	Coefficient for the width dependence of CLM enhancement factor above threshold
126	PLWALP1	V	0	–	–	Coefficient for the length times width dependence of CLM enhancement factor above threshold
127	POALP2	V^{-1}	0	–	–	Coefficient for the geometry independent part of CLM enhancement factor below threshold
128	PLALP2	V^{-1}	0	–	–	Coefficient for the length dependence of CLM enhancement factor below threshold
129	PWALP2	V^{-1}	0	–	–	Coefficient for the width dependence of CLM enhancement factor below threshold
130	PLWALP2	V^{-1}	0	–	–	Coefficient for the length times width dependence of CLM enhancement factor below threshold
131	POVP	V	$5 \cdot 10^{-2}$	–	–	Coefficient for the geometry independent part of CLM logarithmic dependence parameter
Impact Ionization (II) Parameters						
132	POA1	–	1	–	–	Coefficient for the geometry independent part of impact-ionization pre-factor
133	PLA1	–	0	–	–	Coefficient for the length dependence of impact-ionization pre-factor

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No.	Name	Unit	Default	Min.	Max.	Description
134	PWA1	–	0	–	–	Coefficient for the width dependence of impact-ionization pre-factor
135	PLWA1	–	0	–	–	Coefficient for the length times width dependence of impact-ionization pre-factor
136	POA2	V	10	–	–	Coefficient for the geometry independent part of impact-ionization exponent at TR
137	POSTA2	V	0	–	–	Coefficient for the geometry independent part of temperature dependence of A2
138	POA3	–	1	–	–	Coefficient for the geometry independent part of saturation-voltage dependence of II
139	PLA3	–	0	–	–	Coefficient for the length dependence of saturation-voltage dependence of II
140	PWA3	–	0	–	–	Coefficient for the width dependence of saturation-voltage dependence of II
141	PLWA3	–	0	–	–	Coefficient for the length times width dependence of saturation-voltage dependence of II
142	POA4	$V^{-0.5}$	0	–	–	Coefficient for the geometry independent part of back-bias dependence of II
143	PLA4	$V^{-0.5}$	0	–	–	Coefficient for the length dependence of back-bias dependence of II
144	PWA4	$V^{-0.5}$	0	–	–	Coefficient for the width dependence of back-bias dependence of II
145	PLWA4	$V^{-0.5}$	0	–	–	Coefficient for the length times width dependence of back-bias dependence of II
Gate Current Parameters						
146	POGCO	–	0	–	–	Coefficient for the geometry independent part of gate tunneling energy adjustment
147	POIGINV	A	0	–	–	Coefficient for the geometry independent part of gate channel current pre-factor
148	PLIGINV	A	0	–	–	Coefficient for the length dependence of gate channel current pre-factor
149	PWIGINV	A	0	–	–	Coefficient for the width dependence of gate channel current pre-factor
150	PLWIGINV	A	0	–	–	Coefficient for the length times width dependence of gate channel current pre-factor
151	POIGOV	A	0	–	–	Coefficient for the geometry independent part of gate overlap current pre-factor
152	PLIGOV	A	0	–	–	Coefficient for the length dependence of gate overlap current pre-factor
153	PWIGOV	A	0	–	–	Coefficient for the width dependence of gate overlap current pre-factor
154	PLWIGOV	A	0	–	–	Coefficient for the length times width dependence of gate overlap current pre-factor

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No.	Name	Unit	Default	Min.	Max.	Description
155	POSTIG	–	2	–	–	Coefficient for the geometry independent part of temperature dependence of gate current
156	POGC2	–	$3.75 \cdot 10^{-1}$	–	–	Coefficient for the geometry independent part of gate current slope factor
157	POGC3	–	$6.3 \cdot 10^{-2}$	–	–	Coefficient for the geometry independent part of gate current curvature factor
158	POCHIB	V	3.1	–	–	Coefficient for the geometry independent part of tunneling barrier height
Gate-Induced Drain Leakage (GIDL) Parameters						
159	POAGIDL	A/V^3	0	–	–	Coefficient for the geometry independent part of GIDL pre-factor
160	PLAGIDL	A/V^3	0	–	–	Coefficient for the length dependence of GIDL pre-factor
161	PWAGIDL	A/V^3	0	–	–	Coefficient for the width dependence of GIDL pre-factor
162	PLWAGIDL	A/V^3	0	–	–	Coefficient for the length times width dependence of GIDL pre-factor
163	POAGIDLD	A/V^3	0	–	–	Coefficient for the geometry independent part of GIDL pre-factor for drain side
164	PLAGIDLD	A/V^3	0	–	–	Coefficient for the length dependence of GIDL pre-factor for drain side
165	PWAGIDLD	A/V^3	0	–	–	Coefficient for the width dependence of GIDL pre-factor for drain side
166	PLWAGIDLD	A/V^3	0	–	–	Coefficient for the length times width dependence of GIDL pre-factor for drain side
167	POBGIDL	V	41	–	–	Coefficient for the geometry independent part of GIDL probability factor at TR
168	POBGIDLD	V	41	–	–	Coefficient for the geometry independent part of GIDL probability factor at TR for drain side
169	POSTBGIDL	V/K	0	–	–	Coefficient for the geometry independent part of temperature dependence of BGIDL
170	POSTBGIDLD	V/K	0	–	–	Coefficient for the geometry independent part of temperature dependence of BGIDL for drain side
171	POCGIDL	–	0	–	–	Coefficient for the geometry independent part of back-bias dependence of GIDL
172	POCGIDLD	–	0	–	–	Coefficient for the geometry independent part of back-bias dependence of GIDL for drain side
Charge Model Parameters						

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No.	Name	Unit	Default	Min.	Max.	Description
173	POCOX	F	10^{-14}	—	—	Coefficient for the geometry independent part of oxide capacitance for intrinsic channel
174	PLCOX	F	0	—	—	Coefficient for the length dependence of oxide capacitance for intrinsic channel
175	PWCOX	F	0	—	—	Coefficient for the width dependence of oxide capacitance for intrinsic channel
176	PLWCOX	F	0	—	—	Coefficient for the length times width dependence of oxide capacitance for intrinsic channel
177	POCGOV	F	10^{-15}	—	—	Coefficient for the geometry independent part of oxide capacitance for gate-drain/source overlap
178	PLCGOV	F	0	—	—	Coefficient for the length dependence of oxide capacitance for gate-drain/source overlap
179	PWCGOV	F	0	—	—	Coefficient for the width dependence of oxide capacitance for gate-drain/source overlap
180	PLWCGOV	F	0	—	—	Coefficient for the length times width dependence of oxide capacitance for gate-drain/source overlap
181	POCGOVD	F	10^{-15}	—	—	Coefficient for the geometry independent part of oxide capacitance for gate-drain/source overlap for drain side
182	PLCGOVD	F	0	—	—	Coefficient for the length dependence of oxide capacitance for gate-drain/source overlap for drain side
183	PWCGOVD	F	0	—	—	Coefficient for the width dependence of oxide capacitance for gate-drain/source overlap for drain side
184	PLWCGOVD	F	0	—	—	Coefficient for the length times width dependence of oxide capacitance for gate-drain/source overlap for drain side
185	POCGBOV	F	0	—	—	Coefficient for the geometry independent part of oxide capacitance for gate-bulk overlap
186	PLCGBOV	F	0	—	—	Coefficient for the length dependence of oxide capacitance for gate-bulk overlap
187	PWCGBOV	F	0	—	—	Coefficient for the width dependence of oxide capacitance for gate-bulk overlap
188	PLWCGBOV	F	0	—	—	Coefficient for the length times width dependence of oxide capacitance for gate-bulk overlap
189	POCFR	F	0	—	—	Coefficient for the geometry independent part of outer fringe capacitance

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No.	Name	Unit	Default	Min.	Max.	Description
190	PLCFR	F	0	—	—	Coefficient for the length dependence of outer fringe capacitance
191	PWCFR	F	0	—	—	Coefficient for the width dependence of outer fringe capacitance
192	PLWCFR	F	0	—	—	Coefficient for the length times width dependence of outer fringe capacitance
193	POCFRD	F	0	—	—	Coefficient for the geometry independent part of outer fringe capacitance for drain side
194	PLCFRD	F	0	—	—	Coefficient for the length dependence of outer fringe capacitance for drain side
195	PWCFRD	F	0	—	—	Coefficient for the width dependence of outer fringe capacitance for drain side
196	PLWCFRD	F	0	—	—	Coefficient for the length times width dependence of outer fringe capacitance for drain side
Noise Model Parameters						
197	POFNT	—	1	—	—	Coefficient for the geometry independent part of thermal noise coefficient
198	POFNTEXC	—	0	—	—	Coefficient for the geometry independent part of excess noise
199	PLFNTEXC	—	0	—	—	Coefficient for the length dependence of excess noise
200	PWFNTEXC	—	0	—	—	Coefficient for the width dependence of excess noise
201	PLWFNTEXC	—	0	—	—	Coefficient for the length times width dependence of excess noise
202	PONFA	V^{-1}/m^4	$8 \cdot 10^{22}$	—	—	Coefficient for the geometry independent part of first coefficient of flicker noise
203	PLNFA	V^{-1}/m^4	0	—	—	Coefficient for the length dependence of first coefficient of flicker noise
204	PWNFA	V^{-1}/m^4	0	—	—	Coefficient for the width dependence of first coefficient of flicker noise
205	PLWNFA	V^{-1}/m^4	0	—	—	Coefficient for the length times width dependence of first coefficient of flicker noise
206	PONFB	V^{-1}/m^2	$3 \cdot 10^7$	—	—	Coefficient for the geometry independent part of second coefficient of flicker noise
207	PLNFB	V^{-1}/m^2	0	—	—	Coefficient for the length dependence of second coefficient of flicker noise
208	PWNFB	V^{-1}/m^2	0	—	—	Coefficient for the width dependence of second coefficient of flicker noise
209	PLWNFB	V^{-1}/m^2	0	—	—	Coefficient for the length times width dependence of second coefficient of flicker noise

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No.	Name	Unit	Default	Min.	Max.	Description
210	PONFC	V ⁻¹	0	—	—	Coefficient for the geometry independent part of third coefficient of flicker noise
211	PLNFC	V ⁻¹	0	—	—	Coefficient for the length dependence of third coefficient of flicker noise
212	PWNFC	V ⁻¹	0	—	—	Coefficient for the width dependence of third coefficient of flicker noise
213	PLWNFC	V ⁻¹	0	—	—	Coefficient for the length times width dependence of third coefficient of flicker noise
214	POEF	—	1.0	—	—	Coefficient for the geometry independent part of flicker noise frequency exponent
Other Parameters						
215	DTA	K	0	—	—	temperature offset w.r.t. ambient circuit temperature

2.5.5 Parameters for stress model

The stress model of BSIM4.4.0 has been adopted in PSP with as little modifications as possible. Parameter names have been copied, but they have been subjected to PSP conventions by replacing every zero by an ‘O’. Moreover, the parameters **STK2** and **LODK2** are not available in PSP. Except for these changes, stress parameters determined for BSIM can be directly applied in PSP. Some trivial conversion of parameters BSIM→PSP is still necessary, see [2].

The parameters in this section are part of PSP’s global parameter set (both geometrical and binning).

No.	Name	Unit	Default	Min.	Max.	Description
0	SAREF	m	10^{-6}	10^{-9}	–	Reference distance between OD edge to Poly from one side
1	SBREF	m	10^{-6}	10^{-9}	–	Reference distance between OD edge to Poly from other side
2	WLOD	m	0	–	–	Width parameter
3	KUO	m	0	–	–	Mobility degradation/enhancement coefficient
4	KVSAT	m	0	–1	1	Saturation velocity degradation/enhancement parameter
5	TKUO	–	0	–	–	Temperature coefficient of KUO
6	LKUO	$m^{LLODKUO}$	0	–	–	Length dependence of KUO
7	WKUO	$m^{WLODKUO}$	0	–	–	Width dependence of KUO
8	PKUO	$m^{LLODKUO+WLODKUO}$	0	–	–	Cross-term dependence of KUO
9	LLODKUO	–	0	0	–	Length parameter for mobility stress effect
10	WLODKUO	–	0	0	–	Width parameter for mobility stress effect
11	KVTHO	V _m	0	–	–	Threshold shift parameter
12	LKVTHO	$m^{LLODVTH}$	0	–	–	Length dependence of KVTHO
13	WKVTHO	$m^{WLODVTH}$	0	–	–	Width dependence of KVTHO
14	PKVTHO	$m^{LLODVTH+WLODVTH}$	0	–	–	Cross-term dependence of KVTHO
15	LLODVTH	–	0	0	–	Length parameter for threshold voltage stress effect
16	WLODVTH	–	0	0	–	Width parameter for threshold voltage stress effect
17	STETAO	m	0	–	–	ETAO shift factor related to threshold voltage change
18	LODETAO	–	1	0	–	ETAO shift modification factor

2.5.6 Parameters for well proximity effect model

The WPE model of BSIM4.5.0 has been adopted in PSP with as little modifications as possible. Parameter names have been copied, but they have been subjected to PSP conventions by replacing every zero by an 'O'. Moreover, the parameter **K2WE** is not available in PSP. Except for some trivial conversion of parameters BSIM→PSP [2], WPE parameters from BSIM can be used directly in PSP. The WPE parameters have both geometrical and binning rules included as explained in Section 3.6.2. Consequently one of the following parameter sets can be used depending on which scaling rule is selected.

The parameters in the following table are part of PSP's global parameter set.

No.	Name	Unit	Default	Min.	Max.	Description
0	SCREF	m	$1 \cdot 10^{-6}$	0	–	Distance between OD-edge and well edge of a reference device
1	WEB	–	0	–	–	Coefficient for SCB
2	WEC	–	0	–	–	Coefficient for SCC
3	KVTHOWEO	–	0	–	–	Geometry independent threshold shift parameter
4	KVTHOWEL	–	0	–	–	Length dependence of threshold shift parameter
5	KVTHOWEW	–	0	–	–	Width dependence of threshold shift parameter
6	KVTHOWELW	–	0	–	–	Area dependence of threshold shift parameter
7	KUOWEO	–	0	–	–	Geometry independent mobility degradation factor
8	KUOWEL	–	0	–	–	Length dependence of mobility degradation factor
9	KUOWEW	–	0	–	–	Width dependence of mobility degradation factor
10	KUOWELW	–	0	–	–	Area dependence of mobility degradation factor

The parameters in the following table are part of PSP's binning parameter set.

No.	Name	Unit	Default	Min.	Max.	Description
0	SCREF	m	$1 \cdot 10^{-6}$	0	–	Distance between OD-edge and well edge of a reference device
1	WEB	–	0	–	–	Coefficient for SCB
2	WEC	–	0	–	–	Coefficient for SCC
3	POKVTHOWE	–	0	–	–	Coefficient for the geometry independent part of threshold shift parameter
4	PLKVTHOWE	–	0	–	–	Coefficient for the length dependence of threshold shift parameter
5	PWKVTHOWE	–	0	–	–	Coefficient for the width dependence of threshold shift parameter

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No.	Name	Unit	Default	Min.	Max.	Description
6	PLWKVTHOWE	–	0	–	–	Coefficient for the length times width dependence of threshold shift parameter
7	POKUOWE	–	0	–	–	Coefficient for the geometry independent part of mobility degradation factor
8	PLKUOWE	–	0	–	–	Coefficient for the length dependence of mobility degradation factor
9	PWKUOWE	–	0	–	–	Coefficient for the width dependence of mobility degradation factor
10	PLWKUOWE	–	0	–	–	Coefficient for the length times width dependence of mobility degradation factor

2.5.7 Parameters for local model

The set of local parameters valid for an individual transistor with a specific channel width and length are given in the table below. Since the local parameter set is valid for one device with a specific geometry, it does not contain the channel length and width as instance parameters.

No.	Name	Unit	Default	Min.	Max.	Description
0	LEVEL	–	102	–	–	Model selection parameter; see Sec. 6.1
1	TYPE	–	1	–1	1	Channel type parameter; 1 ↔ NMOS, –1 ↔ PMOS ⁷
2	TR	°C	21	–273	–	Reference temperature
Switch Parameters						
3	PARAMCHK	–	0	–	–	Level of clip-warning info ⁸
4	SWGATE	–	0	0	1	Flag for gate current (0 ↔ “off”)
5	SWIMPACT	–	0	0	1	Flag for impact ionization current (0 ↔ “off”)
6	SWGIDL	–	0	0	1	Flag for GIDL/GISL current (0 ↔ “off”)
7	SWJUNCAP	–	0	0	3	Flag for JUNCAP (0 ↔ “off”); see Sec. 2.5.2
8	SWJUNASYM	–	0	–	–	Flag for asymmetric junctions (0 ↔ “off”) ⁹
9	QMC	–	1	0	–	Quantum-mechanical correction factor
Process Parameters						
10	VFB	V	–1	–	–	Flat-band voltage at TR
11	STVFB	V/K	$5 \cdot 10^{-4}$	–	–	Temperature dependence of VFB
12	TOX	m	$2 \cdot 10^{-9}$	10^{-10}	–	Gate oxide thickness
13	EPSROX	–	3.9	1	–	Relative permittivity of gate dielectric
14	NEFF	m^{-3}	$5 \cdot 10^{23}$	10^{20}	10^{26}	Substrate doping
15	VNSUB	V	0	–	–	Effective doping bias-dependence parameter
16	NSLP	V	0.05	10^{-3}	–	Effective doping bias-dependence parameter
17	DNSUB	V^{-1}	0	0	1	Effective doping bias-dependence parameter
18	DPHIB	V	0	–	–	Offset of φ_B
19	NP	m^{-3}	10^{26}	0	–	Gate poly-silicon doping
20	CT	–	0	0	–	Interface states factor
21	TOXOV	m	$2 \cdot 10^{-9}$	10^{-10}	–	Overlap oxide thickness
22	TOXOVD	m	$2 \cdot 10^{-9}$	10^{-10}	–	Overlap oxide thickness for drain side
23	NOV	m^{-3}	$5 \cdot 10^{25}$	10^{20}	10^{27}	Effective doping of overlap region
24	NOVD	m^{-3}	$5 \cdot 10^{25}$	10^{20}	10^{27}	Effective doping of overlap region for drain side
DIBL Parameters						
25	CF	V^{-1}	0	0	–	DIBL parameter

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⁷See Section 6.3.1 for more information on usage of **TYPE** in various simulators.

⁸Only in SiMKit-version of PSP. See Section 6.5.4 for more information.

⁹See Section 3.7 for more information on usage of **SWJUNASYM**.

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No.	Name	Unit	Default	Min.	Max.	Description
26	CFB	V^{-1}	0	0	1	Back-bias dependence of CF
Mobility Parameters						
27	BETN	$m^2/V/s$	$7 \cdot 10^{-2}$	0	—	Product of channel aspect ratio and zero-field mobility at TR
28	STBET	—	1	—	—	Temperature dependence of BETN
29	MUE	m/V	0.5	0	—	Mobility reduction coefficient at TR
30	STMUE	—	0	—	—	Temperature dependence of MUE
31	THEMU	—	1.5	0	—	Mobility reduction exponent at TR
32	STTHEMU	—	1.5	—	—	Temperature dependence of THEMU
33	CS	—	0	0	—	Coulomb scattering parameter at TR
34	STCS	—	0	—	—	Temperature dependence of CS
35	XCOR	V^{-1}	0	0	—	Non-universality parameter
36	STXCOR	—	0	—	—	Temperature dependence of XCOR
37	FETA	—	1	0	—	Effective field parameter
Series Resistance Parameters						
38	RS	Ω	30	0	—	Source/drain series resistance at TR
39	STRS	—	1	—	—	Temperature dependence of RS
40	RSB	V^{-1}	0	−0.5	1	Back-bias dependence of RS
41	RSG	V^{-1}	0	−0.5	—	Gate-bias dependence of RS
Velocity Saturation Parameters						
42	THESAT	V^{-1}	1	0	—	Velocity saturation parameter at TR
43	STTHESAT	—	1	—	—	Temperature dependence of THESAT
44	THESATB	V^{-1}	0	−0.5	1	Back-bias dependence of velocity saturation
45	THESATG	V^{-1}	0	−0.5	—	Gate-bias dependence of velocity saturation
Saturation Voltage Parameter						
46	AX	—	3	2	—	Linear/saturation transition factor
Channel Length Modulation (CLM) Parameters						
47	ALP	—	0.01	0	—	CLM pre-factor
48	ALP1	V	0	0	—	CLM enhancement factor above threshold
49	ALP2	V^{-1}	0	0	—	CLM enhancement factor below threshold
50	VP	V	0.05	10^{-10}	—	CLM logarithmic dependence parameter
Impact Ionization (II) Parameters						
51	A1	—	1	0	—	Impact-ionization pre-factor
52	A2	V	10	0	—	Impact-ionization exponent at TR
53	STA2	V	0	—	—	Temperature dependence of A2
54	A3	—	1	0	—	Saturation-voltage dependence of II
55	A4	$V^{-\frac{1}{2}}$	0	0	—	Back-bias dependence of II
Gate Current Parameters						

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No.	Name	Unit	Default	Min.	Max.	Description
56	GCO	–	0	–10	10	Gate tunnelling energy adjustment
57	IGINV	A	0	0	–	Gate channel current pre-factor
58	IGOV	A	0	0	–	Gate overlap current pre-factor
59	IGOVD	A	0	0	–	Gate overlap current pre-factor for drain side
60	STIG	–	2	–	–	Temperature dependence of gate current
61	GC2	–	0.375	0	10	Gate current slope factor
62	GC3	–	0.063	–2	2	Gate current curvature factor
63	CHIB	V	3.1	1	–	Tunnelling barrier height
Gate-Induced Drain Leakage (GIDL) Parameters						
64	AGIDL	A/V ³	0	0	–	GIDL pre-factor
65	AGIDLD	A/V ³	0	0	–	GIDL pre-factor for drain side
66	BGIDL	V	41	0	–	GIDL probability factor at TR
67	BGIDLD	V	41	0	–	GIDL probability factor at TR for drain side
68	STBGIDL	V/K	0	–	–	Temperature dependence of BGIDL
69	STBGIDLD	V/K	0	–	–	Temperature dependence of BGIDL for drain side
70	CGIDL	–	0	–	–	Back-bias dependence of GIDL
71	CGIDLD	–	0	–	–	Back-bias dependence of GIDL for drain side
Charge Model Parameters						
72	COX	F	10 ^{–14}	0	–	Oxide capacitance for intrinsic channel
73	CGOV	F	10 ^{–15}	0	–	Oxide capacitance for gate–drain/source overlap
74	CGOVD	F	10 ^{–15}	0	–	Oxide capacitance for gate–drain/source overlap for drain side
75	CGBOV	F	0	0	–	Oxide capacitance for gate–bulk overlap
76	CFR	F	0	0	–	Outer fringe capacitance
77	CFRD	F	0	0	–	Outer fringe capacitance for drain side
Noise Model Parameters						
78	FNT	–	1.0	0	–	Thermal noise coefficient
79	FNTEXC	–	0	0	–	Excess noise coefficient
80	NFA	V ^{–1} /m ⁴	8 · 10 ²²	0	–	First coefficient of flicker noise
81	NFB	V ^{–1} /m ²	3 · 10 ⁷	0	–	Second coefficient of flicker noise
82	NFC	V ^{–1}	0	0	–	Third coefficient of flicker noise
83	EF	–	1.0	0	–	Flicker noise frequency exponent
Other Parameters						
84	DTA	K	0	–	–	Temperature offset w.r.t. ambient circuit temperature

2.5.8 Parameters for source-bulk and drain-bulk junction model

The JUNCAP2 parameters are part of both the global and the local parameter sets. The last column of **Asym.** shows for which value of **SWJUNASYM** the listed parameter is enabled: i.e., when **SWJUNASYM** = 0, parameters No. 3-45 are used for both source-bulk and drain-bulk junctions and parameters No. 46-88 are ignored; when **SWJUNASYM** = 1, parameters No. 3-45 are used for source-bulk junction and No. 46-88 are used for drain-bulk junction; parameters No. 0-2 are used in both situations.

No.	Name	Unit	Default	Min.	Max.	Description	Asym.
0	TRJ	°C	21	T_{\min}	–	Reference temperature	0, 1
1	SWJUNEXP	–	0	0	1	Flag for JUNCAP2 Express; 0 ↔ full JUNCAP2 model, 1 ↔ Express model	0, 1
2	IMAX	A	1000	10^{-12}	–	Maximum current up to which forward current behaves exponentially	0, 1
Capacitance Parameters							
3	CJORBOT	F/m ²	10^{-3}	10^{-12}	–	Zero-bias capacitance per unit-of-area of bottom component for source-bulk junction	0, 1
4	CJORSTI	F/m	10^{-9}	10^{-18}	–	Zero-bias capacitance per unit-of-length of STI-edge component for source-bulk junction	0, 1
5	CJORGAT	F/m	10^{-9}	10^{-18}	–	Zero-bias capacitance per unit-of-length of gate-edge component for source-bulk junction	0, 1
6	VBIRBOT	V	1	$V_{\text{bi,low}}$	–	Built-in voltage at the reference temperature of bottom component for source-bulk junction	0, 1
7	VBIRSTI	V	1	$V_{\text{bi,low}}$	–	Built-in voltage at the reference temperature of STI-edge component for source-bulk junction	0, 1
8	VBIRGAT	V	1	$V_{\text{bi,low}}$	–	Built-in voltage at the reference temperature of gate-edge component for source-bulk junction	0, 1
9	PBOT	–	0.5	0.05	0.95	Grading coefficient of bottom component for source-bulk junction	0, 1
10	PSTI	–	0.5	0.05	0.95	Grading coefficient of STI-edge component for source-bulk junction	0, 1
11	PGAT	–	0.5	0.05	0.95	Grading coefficient of gate-edge component for source-bulk junction	0, 1
Ideal-current Parameters							
12	PHIGBOT	V	1.16	–	–	Zero-temperature bandgap voltage of bottom component for source-bulk junction	0, 1
13	PHIGSTI	V	1.16	–	–	Zero-temperature bandgap voltage of STI-edge component for source-bulk junction	0, 1

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No.	Name	Unit	Default	Min.	Max.	Description	Asym.
14	PHIGGAT	V	1.16	—	—	Zero-temperature bandgap voltage of gate-edge component for source-bulk junction	0, 1
15	IDSATRBOT	A/m ²	10 ⁻¹²	0	—	Saturation current density at the reference temperature of bottom component for source-bulk junction	0, 1
16	IDSATRSTI	A/m	10 ⁻¹⁸	0	—	Saturation current density at the reference temperature of STI-edge component for source-bulk junction	0, 1
17	IDSATRGAT	A/m	10 ⁻¹⁸	0	—	Saturation current density at the reference temperature of gate-edge component for source-bulk junction	0, 1
Shockley-Read-Hall Parameters							
18	CSRHBOT	A/m ³	10 ²	0	—	Shockley-Read-Hall prefactor of bottom component for source-bulk junction	0, 1
19	CSRHSTI	A/m ²	10 ⁻⁴	0	—	Shockley-Read-Hall prefactor of STI-edge component for source-bulk junction	0, 1
20	CSRHGAT	A/m ²	10 ⁻⁴	0	—	Shockley-Read-Hall prefactor of gate-edge component for source-bulk junction	0, 1
21	XJUNSTI	m	10 ⁻⁷	10 ⁻⁹	—	Junction depth of STI-edge component for source-bulk junction	0, 1
22	XJUNGAT	m	10 ⁻⁷	10 ⁻⁹	—	Junction depth of gate-edge component for source-bulk junction	0, 1
Trap-assisted Tunneling Parameters							
23	CTATBOT	A/m ³	10 ²	0	—	Trap-assisted tunneling prefactor of bottom component for source-bulk junction	0, 1
24	CTATSTI	A/m ²	10 ⁻⁴	0	—	Trap-assisted tunneling prefactor of STI-edge component for source-bulk junction	0, 1
25	CTATGAT	A/m ²	10 ⁻⁴	0	—	Trap-assisted tunneling prefactor of gate-edge component for source-bulk junction	0, 1
26	MEFFTATBOT	—	0.25	.01	—	Effective mass (in units of m_0) for trap-assisted tunneling of bottom component for source-bulk junction	0, 1
27	MEFFTATSTI	—	0.25	.01	—	Effective mass (in units of m_0) for trap-assisted tunneling of STI-edge component for source-bulk junction	0, 1

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No.	Name	Unit	Default	Min.	Max.	Description	Asym.
28	MEFFTATGAT	—	0.25	.01	—	Effective mass (in units of m_0) for trap-assisted tunneling of gate-edge component for source-bulk junction	0, 1
Band-to-band Tunneling Parameters							
29	CBBTBOT	AV^{-3}	10^{-12}	0	—	Band-to-band tunneling prefactor of bottom component for source-bulk junction	0, 1
30	CBBTSTI	$AV^{-3}m$	10^{-18}	0	—	Band-to-band tunneling prefactor of STI-edge component for source-bulk junction	0, 1
31	CBBTGAT	$AV^{-3}m$	10^{-18}	0	—	Band-to-band tunneling prefactor of gate-edge component for source-bulk junction	0, 1
32	FBBTRBOT	Vm^{-1}	10^9	—	—	Normalization field at the reference temperature for band-to-band tunneling of bottom component for source-bulk junction	0, 1
33	FBBTRSTI	Vm^{-1}	10^9	—	—	Normalization field at the reference temperature for band-to-band tunneling of STI-edge component for source-bulk junction	0, 1
34	FBBTRGAT	Vm^{-1}	10^9	—	—	Normalization field at the reference temperature for band-to-band tunneling of gate-edge component for source-bulk junction	0, 1
35	STFBBTBOT	K^{-1}	-10^{-3}	—	—	Temperature scaling parameter for band-to-band tunneling of bottom component for source-bulk junction	0, 1
36	STFBBTSTI	K^{-1}	-10^{-3}	—	—	Temperature scaling parameter for band-to-band tunneling of STI-edge component for source-bulk junction	0, 1
37	STFBBTGAT	K^{-1}	-10^{-3}	—	—	Temperature scaling parameter for band-to-band tunneling of gate-edge component for source-bulk junction	0, 1
Avalanche and Breakdown Parameters							
38	VBRBOT	V	10	0.1	—	Breakdown voltage of bottom component for source-bulk junction	0, 1
39	VBRSTI	V	10	0.1	—	Breakdown voltage of STI-edge component for source-bulk junction	0, 1

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No.	Name	Unit	Default	Min.	Max.	Description	Asym.
40	VBRGAT	V	10	0.1	–	Breakdown voltage of gate-edge component for source-bulk junction	0, 1
41	PBRBOT	V	4	0.1	–	Breakdown onset tuning parameter of bottom component for source-bulk junction	0, 1
42	PBRSTI	V	4	0.1	–	Breakdown onset tuning parameter of STI-edge component for source-bulk junction	0, 1
43	PBRGAT	V	4	0.1	–	Breakdown onset tuning parameter of gate-edge component for source-bulk junction	0, 1
JUNCAP Express Parameters							
44	VJUNREF	V	2.5	0.5	–	Typical maximum source-bulk junction voltage; usually about $2 \cdot V_{\text{sup}}$	0, 1
45	FJUNQ	V	0.03	0	–	Fraction below which source-bulk junction capacitance components are neglected	0, 1
Capacitance Parameters							
46	CJORBOTD	F/m ²	10 ⁻³	10 ⁻¹²	–	Zero-bias capacitance per unit-of-area of bottom component for drain-bulk junction	1
47	CJORSTID	F/m	10 ⁻⁹	10 ⁻¹⁸	–	Zero-bias capacitance per unit-of-length of STI-edge component for drain-bulk junction	1
48	CJORGATD	F/m	10 ⁻⁹	10 ⁻¹⁸	–	Zero-bias capacitance per unit-of-length of gate-edge component for drain-bulk junction	1
49	VBIRBOTD	V	1	$V_{\text{bi,low}}$	–	Built-in voltage at the reference temperature of bottom component for drain-bulk junction	1
50	VBIRSTID	V	1	$V_{\text{bi,low}}$	–	Built-in voltage at the reference temperature of STI-edge component for drain-bulk junction	1
51	VBIRGATD	V	1	$V_{\text{bi,low}}$	–	Built-in voltage at the reference temperature of gate-edge component for drain-bulk junction	1
52	PBOTD	–	0.5	0.05	0.95	Grading coefficient of bottom component for drain-bulk junction	1
53	PSTID	–	0.5	0.05	0.95	Grading coefficient of STI-edge component for drain-bulk junction	1
54	PGATD	–	0.5	0.05	0.95	Grading coefficient of gate-edge component for drain-bulk junction	1
Ideal-current Parameters							

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No.	Name	Unit	Default	Min.	Max.	Description	Asym.
55	PHIGBOTD	V	1.16	—	—	Zero-temperature bandgap voltage of bottom component for drain-bulk junction	1
56	PHIGSTID	V	1.16	—	—	Zero-temperature bandgap voltage of STI-edge component for drain-bulk junction	1
57	PHIGGATD	V	1.16	—	—	Zero-temperature bandgap voltage of gate-edge component for drain-bulk junction	1
58	IDSATRBOTD	A/m ²	10 ⁻¹²	0	—	Saturation current density at the reference temperature of bottom component for drain-bulk junction	1
59	IDSATRSTID	A/m	10 ⁻¹⁸	0	—	Saturation current density at the reference temperature of STI-edge component for drain-bulk junction	1
60	IDSATRGATD	A/m	10 ⁻¹⁸	0	—	Saturation current density at the reference temperature of gate-edge component for drain-bulk junction	1
Shockley-Read-Hall Parameters							
61	CSRHBOTD	A/m ³	10 ²	0	—	Shockley-Read-Hall prefactor of bottom component for drain-bulk junction	1
62	CSRHSTID	A/m ²	10 ⁻⁴	0	—	Shockley-Read-Hall prefactor of STI-edge component for drain-bulk junction	1
63	CSRHGATD	A/m ²	10 ⁻⁴	0	—	Shockley-Read-Hall prefactor of gate-edge component for drain-bulk junction	1
64	XJUNSTID	m	10 ⁻⁷	10 ⁻⁹	—	Junction depth of STI-edge component for drain-bulk junction	1
65	XJUNGATD	m	10 ⁻⁷	10 ⁻⁹	—	Junction depth of gate-edge component for drain-bulk junction	1
Trap-assisted Tunneling Parameters							
66	CTATBOTD	A/m ³	10 ²	0	—	Trap-assisted tunneling prefactor of bottom component for drain-bulk junction	1
67	CTATSTID	A/m ²	10 ⁻⁴	0	—	Trap-assisted tunneling prefactor of STI-edge component for drain-bulk junction	1
68	CTATGATD	A/m ²	10 ⁻⁴	0	—	Trap-assisted tunneling prefactor of gate-edge component for drain-bulk junction	1
69	MEFFTATBOTD	—	0.25	.01	—	Effective mass (in units of m_0) for trap-assisted tunneling of bottom component for drain-bulk junction	1

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No.	Name	Unit	Default	Min.	Max.	Description	Asym.
70	MEFFTATSTID	–	0.25	.01	–	Effective mass (in units of m_0) for trap-assisted tunneling of STI-edge component for drain-bulk junction	1
71	MEFFTATGATD	–	0.25	.01	–	Effective mass (in units of m_0) for trap-assisted tunneling of gate-edge component for drain-bulk junction	1
Band-to-band Tunneling Parameters							
72	CBBTBOTD	AV^{-3}	10^{-12}	0	–	Band-to-band tunneling prefactor of bottom component for drain-bulk junction	1
73	CBBTSTID	$AV^{-3}m$	10^{-18}	0	–	Band-to-band tunneling prefactor of STI-edge component for drain-bulk junction	1
74	CBBTGATD	$AV^{-3}m$	10^{-18}	0	–	Band-to-band tunneling prefactor of gate-edge component for drain-bulk junction	1
75	FBBTBOTD	Vm^{-1}	10^9	–	–	Normalization field at the reference temperature for band-to-band tunneling of bottom component for drain-bulk junction	1
76	FBBTSTID	Vm^{-1}	10^9	–	–	Normalization field at the reference temperature for band-to-band tunneling of STI-edge component for drain-bulk junction	1
77	FBBTGATD	Vm^{-1}	10^9	–	–	Normalization field at the reference temperature for band-to-band tunneling of gate-edge component for drain-bulk junction	1
78	STFBBTBOTD	K^{-1}	-10^{-3}	–	–	Temperature scaling parameter for band-to-band tunneling of bottom component for drain-bulk junction	1
79	STFBBTSTID	K^{-1}	-10^{-3}	–	–	Temperature scaling parameter for band-to-band tunneling of STI-edge component for drain-bulk junction	1
80	STFBBTGATD	K^{-1}	-10^{-3}	–	–	Temperature scaling parameter for band-to-band tunneling of gate-edge component for drain-bulk junction	1
Avalanche and Breakdown Parameters							
81	VBRBOTD	V	10	0.1	–	Breakdown voltage of bottom component for drain-bulk junction	1
82	VBRSTID	V	10	0.1	–	Breakdown voltage of STI-edge component for drain-bulk junction	1
83	VBRGATD	V	10	0.1	–	Breakdown voltage of gate-edge component for drain-bulk junction	1

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No.	Name	Unit	Default	Min.	Max.	Description	Asym.
84	PBRBOTD	V	4	0.1	—	Breakdown onset tuning parameter of bottom component for drain-bulk junction	1
85	PBRSTID	V	4	0.1	—	Breakdown onset tuning parameter of STI-edge component for drain-bulk junction	1
86	PBRGATD	V	4	0.1	—	Breakdown onset tuning parameter of gate-edge component for drain-bulk junction	1
JUNCAP Express Parameters							
87	VJUNREFD	V	2.5	0.5	—	Typical maximum drain-bulk junction voltage; usually about $2 \cdot V_{\text{SUP}}$	1
88	FJUNQD	V	0.03	0	—	Fraction below which drain-bulk junction capacitance components are neglected	1

2.5.9 Parameters for parasitic resistances

The parameters in the following table are part of PSP's global and binning parameter sets.

No.	Name	Unit	Default	Min.	Max.	Description
0	RGO	Ω	0	–	–	Gate resistance R_{gate}
1	RINT	Ω/\square	0	0	–	Contact resistance between silicide and ploy
2	RVPOLY	Ω/\square	0	0	–	Vertical poly resistance
3	RSHG	Ω/\square	0	0	–	Gate electrode diffusion sheet resistance
4	DLSIL	m	0	–	–	Silicide extension over the physical gate length
5	RBULKO	Ω	0	–	–	Bulk resistance R_{bulk}
6	RWELLO	Ω	0	–	–	Well resistance R_{well}
7	RJUNSO	Ω	0	–	–	Source-side bulk resistance R_{juns}
8	RJUNDO	Ω	0	–	–	Drain-side bulk resistance R_{jund}

The parameters in the following table are part of PSP's local parameter set.

No.	Name	Unit	Default	Min.	Max.	Description
0	RG	Ω	0	0	–	Gate resistance R_{gate}
1	RBULK	Ω	0	0	–	Bulk resistance R_{bulk}
2	RWELL	Ω	0	0	–	Well resistance R_{well}
3	RJUNS	Ω	0	0	–	Source-side bulk resistance R_{juns}
4	RJUND	Ω	0	0	–	Drain-side bulk resistance R_{jund}

2.5.10 Parameters for NQS

The parameters in the following table are part of PSP-NQS's global and binning parameter sets.

No.	Name	Unit	Default	Min.	Max.	Description
0	SWNQS	–	0	0	9	Switch for NQS effects / number of collocation points
1	MUNQSO	–	1	–	–	Relative mobility for NQS modeling

The parameters in the following table are part of PSP-NQS's local parameter set.

No.	Name	Unit	Default	Min.	Max.	Description
0	SWNQS	–	0	0	9	Switch for NQS effects / number of collocation points
1	MUNQS	–	1	0	–	Relative mobility for NQS modeling

Section 3

Geometry dependence and Other effects

3.1 Introduction

The physical geometry scaling rules of PSP (Section 3.2) have been developed to give a good description over the whole geometry range of CMOS technologies. As an alternative, the binning-rules can be used (Section 3.3) to allow for a more phenomenological geometry dependency. (Note that the user has to choose between the two options; the geometrical scaling rules and the binning scaling rules cannot be used at the same time.) In both cases, the result is a local parameter set (for a transistor of the specified L and W), which is fed into the local model.

Stress and well proximity effects are included in PSP. Use of the stress model (Section 3.5) and/or well proximity effect model (Section 3.6) leads to modification of some of the local parameters calculated from the geometrical or binning scaling rules.

3.2 Geometrical scaling rules

The physical scaling rules to calculate the local parameters from a global parameter set are given in this section.

Note: After calculation of the local parameters (and possible application of the stress equations in Section 3.5), clipping is applied according to Section 2.5.7.

Effective length and width

$$W_f = \frac{W}{\mathbf{NF}} \quad (3.1)$$

$$L_{\text{EN}} = 10^{-6} \quad (3.2)$$

$$W_{\text{EN}} = 10^{-6} \quad (3.3)$$

$$\Delta L_{\text{PS}} = \mathbf{LVARO} \cdot \left(1 + \mathbf{LVARL} \cdot \frac{L_{\text{EN}}}{L}\right) \cdot \left(1 + \mathbf{LVARW} \cdot \frac{W_{\text{EN}}}{W_f}\right) \quad (3.4)$$

$$\Delta W_{\text{OD}} = \mathbf{WVARO} \cdot \left(1 + \mathbf{WVARL} \cdot \frac{L_{\text{EN}}}{L}\right) \cdot \left(1 + \mathbf{WVARW} \cdot \frac{W_{\text{EN}}}{W_f}\right) \quad (3.5)$$

$$\mathbf{EPSROX} = \mathbf{EPSROXO} \quad (3.15)$$

$$N_{\text{sub0,eff}} = \mathbf{NSUBO} \cdot \text{MAX} \left(\left[1 + \mathbf{NSUBW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \ln \left(1 + \frac{W_{\text{E}}}{\mathbf{WSEGP}} \right) \right], 10^{-3} \right) \quad (3.16)$$

$$N_{\text{pck,eff}} = \mathbf{NPCK} \cdot \text{MAX} \left(\left[1 + \mathbf{NPCKW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \ln \left(1 + \frac{W_{\text{E}}}{\mathbf{WSEGP}} \right) \right], 10^{-3} \right) \quad (3.17)$$

$$L_{\text{pck,eff}} = \mathbf{LPCK} \cdot \text{MAX} \left(\left[1 + \mathbf{LPCKW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \ln \left(1 + \frac{W_{\text{E}}}{\mathbf{WSEGP}} \right) \right], 10^{-3} \right) \quad (3.18)$$

$$a = 7.5 \cdot 10^{10} \quad (3.19)$$

$$b = \sqrt{N_{\text{sub0,eff}} + 0.5 \cdot N_{\text{pck,eff}}} - \sqrt{N_{\text{sub0,eff}}} \quad (3.20)$$

$$N_{\text{sub}} = \begin{cases} N_{\text{sub0,eff}} + N_{\text{pck,eff}} \cdot \left[2 - \frac{L_{\text{E}}}{L_{\text{pck,eff}}} \right] & \text{for } L_{\text{E}} < L_{\text{pck,eff}} \\ N_{\text{sub0,eff}} + N_{\text{pck,eff}} \cdot \frac{L_{\text{pck,eff}}}{L_{\text{E}}} & \text{for } L_{\text{pck,eff}} \leq L_{\text{E}} \leq 2 \cdot L_{\text{pck,eff}} \\ \left[\sqrt{N_{\text{sub0,eff}}} + a \cdot \ln \left(1 + 2 \cdot \frac{L_{\text{pck,eff}}}{L_{\text{E}}} \cdot \left[\exp \left(\frac{b}{a} \right) - 1 \right] \right) \right]^2 & \text{for } L_{\text{E}} > 2 \cdot L_{\text{pck,eff}} \end{cases} \quad (3.21)$$

$$\mathbf{NEFF} = N_{\text{sub}} \cdot \left(1 - \mathbf{FOL1} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} - \mathbf{FOL2} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}} \right]^2 \right) \quad (3.22)$$

$$\mathbf{VNSUB} = \mathbf{VNSUBO} \quad (3.23)$$

$$\mathbf{NSLP} = \mathbf{NSLPO} \quad (3.24)$$

$$\mathbf{DNSUB} = \mathbf{DNSUBO} \quad (3.25)$$

$$\mathbf{DPHIB} = \left(\mathbf{DPHIBO} + \mathbf{DPHIBL} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}} \right]^{\mathbf{DPHIBLEXP}} \right) \cdot \left(1 + \mathbf{DPHIBW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right) \cdot \left(1 + \mathbf{DPHIBLW} \cdot \frac{W_{\text{EN}} \cdot L_{\text{EN}}}{W_{\text{E}} \cdot L_{\text{E}}} \right) \quad (3.26)$$

$$\mathbf{NP} = \mathbf{NPO} \cdot \text{MAX} \left(10^{-6}, 1 + \mathbf{NPL} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right) \quad (3.27)$$

$$\mathbf{CT} = \left(\mathbf{CTO} + \mathbf{CTL} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}} \right]^{\mathbf{CTLEXP}} \right) \cdot \left(1 + \mathbf{CTW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right) \cdot \left(1 + \mathbf{CTLW} \cdot \frac{W_{\text{EN}} \cdot L_{\text{EN}}}{W_{\text{E}} \cdot L_{\text{E}}} \right) \quad (3.28)$$

$$\mathbf{TOXOV} = \mathbf{TOXOVO} \quad (3.29)$$

$$\mathbf{TOXOVD} = \mathbf{TOXOVDO} \quad (3.30)$$

$$\mathbf{NOV} = \mathbf{NOVO} \quad (3.31)$$

$$\mathbf{NOVD} = \mathbf{NOVDO} \quad (3.32)$$

DIBL Parameters

$$\mathbf{CF} = \mathbf{CFL} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}} \right]^{\mathbf{CFLEXP}} \cdot \left(1 + \mathbf{CFW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right) \quad (3.33)$$

$$\mathbf{CFB} = \mathbf{CFBO} \quad (3.34)$$

Mobility Parameters

$$F_{\beta 1, \text{eff}} = \mathbf{FBET1} \cdot \left(1 + \mathbf{FBET1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right) \quad (3.35)$$

$$L_{\text{P1,eff}} = \mathbf{LP1} \cdot \text{MAX} \left(\left[1 + \mathbf{LP1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right], 10^{-3} \right) \quad (3.36)$$

$$G_{\text{P,E}} = 1 + F_{\beta 1, \text{eff}} \cdot \frac{L_{\text{P1,eff}}}{L_{\text{E}}} \cdot \left[1 - \exp \left(-\frac{L_{\text{E}}}{L_{\text{P1,eff}}} \right) \right] \quad (3.37)$$

$$+ \mathbf{FBET2} \cdot \frac{\mathbf{LP2}}{L_{\text{E}}} \cdot \left[1 - \exp \left(-\frac{L_{\text{E}}}{\mathbf{LP2}} \right) \right]$$

$$G_{\text{W,E}} = 1 + \mathbf{BETW1} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \mathbf{BETW2} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \ln \left(1 + \frac{W_{\text{E}}}{\mathbf{WBET}} \right) \quad (3.38)$$

$$\mathbf{BETN} = \frac{\mathbf{UO}}{G_{\text{P,E}}} \cdot \frac{W_{\text{E}}}{L_{\text{E}}} \cdot G_{\text{W,E}} \quad (3.39)$$

$$\mathbf{STBET} = \mathbf{STBETO} \cdot \left(1 + \mathbf{STBETL} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right) \cdot \left(1 + \mathbf{STBETW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right) \cdot \left(1 + \mathbf{STBETLW} \cdot \frac{W_{\text{EN}} \cdot L_{\text{EN}}}{W_{\text{E}} \cdot L_{\text{E}}} \right)$$

$$\mathbf{MUE} = \mathbf{MUEO} \cdot \left[1 + \mathbf{MUEW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right] \quad (3.40)$$

$$\mathbf{STMUE} = \mathbf{STMUEO} \quad (3.41)$$

$$\mathbf{THEMU} = \mathbf{THEMUO} \quad (3.42)$$

$$\mathbf{STTHEMU} = \mathbf{STTHEMUO} \quad (3.43)$$

$$\mathbf{CS} = \left(\mathbf{CSO} + \mathbf{CSL} \cdot \left[\frac{L_{EN}}{L_E} \right]^{\mathbf{CSLEXP}} \right) \cdot \left(1 + \mathbf{CSW} \cdot \frac{W_{EN}}{W_E} \right) \cdot \left(1 + \mathbf{CSLW} \cdot \frac{W_{EN} \cdot L_{EN}}{W_E \cdot L_E} \right) \quad (3.44)$$

$$\mathbf{STCS} = \mathbf{STCSO} \quad (3.45)$$

$$\mathbf{XCOR} = \mathbf{XCORO} \cdot \left(1 + \mathbf{XCORL} \cdot \frac{L_{EN}}{L_E} \right) \cdot \left(1 + \mathbf{XCORW} \cdot \frac{W_{EN}}{W_E} \right) \cdot \left(1 + \mathbf{XCORLW} \cdot \frac{W_{EN} \cdot L_{EN}}{W_E \cdot L_E} \right) \quad (3.46)$$

$$\mathbf{STXCOR} = \mathbf{STXCORO} \quad (3.47)$$

$$\mathbf{FETA} = \mathbf{FETAO} \quad (3.48)$$

Series Resistance Parameters

$$\mathbf{RS} = \mathbf{RSW1} \cdot \frac{W_{EN}}{W_E} \cdot \left[1 + \mathbf{RSW2} \cdot \frac{W_{EN}}{W_E} \right] \quad (3.49)$$

$$\mathbf{STRS} = \mathbf{STRSO} \quad (3.50)$$

$$\mathbf{RSB} = \mathbf{RSBO} \quad (3.51)$$

$$\mathbf{RSG} = \mathbf{RSGO} \quad (3.52)$$

Velocity Saturation Parameters

$$\mathbf{THESAT} = \left(\mathbf{THESATO} + \mathbf{THESATL} \cdot \frac{G_{W,E}}{G_{P,E}} \cdot \left[\frac{L_{EN}}{L_E} \right]^{\mathbf{THESATLEXP}} \right) \cdot \left(1 + \mathbf{THESATW} \cdot \frac{W_{EN}}{W_E} \right) \cdot \left(1 + \mathbf{THESATLW} \cdot \frac{W_{EN} \cdot L_{EN}}{W_E \cdot L_E} \right) \quad (3.53)$$

$$\mathbf{STTHESAT} = \mathbf{STTHESATO} \cdot \left(1 + \mathbf{STTHESATL} \cdot \frac{L_{EN}}{L_E} \right) \cdot \left(1 + \mathbf{STTHESATW} \cdot \frac{W_{EN}}{W_E} \right) \cdot \left(1 + \mathbf{STTHESATLW} \cdot \frac{W_{EN} \cdot L_{EN}}{W_E \cdot L_E} \right) \quad (3.54)$$

$$\mathbf{THESATB} = \mathbf{THESATBO} \quad (3.55)$$

$$\mathbf{THESATG} = \mathbf{THESATGO} \quad (3.56)$$

Saturation Voltage Parameter

$$\mathbf{AX} = \frac{\mathbf{AXO}}{1 + \mathbf{AXL} \cdot \frac{L_{EN}}{L_E}} \quad (3.57)$$

Channel Length Modulation (CLM) Parameters

$$\mathbf{ALP} = \mathbf{ALPL} \cdot \left[\frac{L_{EN}}{L_E} \right]^{\mathbf{ALPLEXP}} \cdot \left(1 + \mathbf{ALPW} \cdot \frac{W_{EN}}{W_E} \right) \quad (3.58)$$

$$\mathbf{ALP1} = \frac{\mathbf{ALP1L1} \cdot \left[\frac{L_{EN}}{L_E} \right]^{\mathbf{ALP1LEXP}}}{1 + \mathbf{ALP1L2} \cdot \left[\frac{L_{EN}}{L_E} \right]^{\mathbf{ALP1LEXP+1}}} \cdot \left(1 + \mathbf{ALP1W} \cdot \frac{W_{EN}}{W_E} \right) \quad (3.59)$$

$$\mathbf{ALP2} = \frac{\mathbf{ALP2L1} \cdot \left[\frac{L_{EN}}{L_E} \right]^{\mathbf{ALP2LEXP}}}{1 + \mathbf{ALP2L2} \cdot \left[\frac{L_{EN}}{L_E} \right]^{\mathbf{ALP2LEXP+1}}} \cdot \left(1 + \mathbf{ALP2W} \cdot \frac{W_{EN}}{W_E} \right) \quad (3.60)$$

$$\mathbf{VP} = \mathbf{VPO} \quad (3.61)$$

Impact Ionization (II) Parameters

$$\mathbf{A1} = \mathbf{A1O} \cdot \left(1 + \mathbf{A1L} \cdot \frac{L_{EN}}{L_E} \right) \cdot \left(1 + \mathbf{A1W} \cdot \frac{W_{EN}}{W_E} \right) \quad (3.62)$$

$$\mathbf{A2} = \mathbf{A2O} \quad (3.63)$$

$$\mathbf{STA2} = \mathbf{STA2O} \quad (3.64)$$

$$\mathbf{A3} = \mathbf{A3O} \cdot \left(1 + \mathbf{A3L} \cdot \frac{L_{EN}}{L_E} \right) \cdot \left(1 + \mathbf{A3W} \cdot \frac{W_{EN}}{W_E} \right) \quad (3.65)$$

$$\mathbf{A4} = \mathbf{A4O} \cdot \left(1 + \mathbf{A4L} \cdot \frac{L_{EN}}{L_E} \right) \cdot \left(1 + \mathbf{A4W} \cdot \frac{W_{EN}}{W_E} \right) \quad (3.66)$$

Gate Current Parameters

$$\mathbf{GCO} = \mathbf{GCOO} \quad (3.67)$$

$$\mathbf{IGINV} = \mathbf{IGINVLW} \cdot \frac{W_E \cdot L_E}{W_{EN} \cdot L_{EN}} \quad (3.68)$$

$$\mathbf{IGOV} = \mathbf{IGOVW} \cdot \frac{W_E \cdot \mathbf{LOV}}{W_{EN} \cdot L_{EN}} \quad (3.69)$$

$$\mathbf{IGOVD} = \mathbf{IGOVDW} \cdot \frac{W_E \cdot \mathbf{LOVD}}{W_{EN} \cdot L_{EN}} \quad (3.70)$$

$$\mathbf{STIG} = \mathbf{STIGO} \quad (3.71)$$

$$\mathbf{GC2 = GC2O} \quad (3.72)$$

$$\mathbf{GC3 = GC3O} \quad (3.73)$$

$$\mathbf{CHIB = CHIBO} \quad (3.74)$$

Gate-Induced Drain Leakage (GIDL) Parameters

$$\mathbf{AGIDL = AGIDLW} \cdot \frac{W_E \cdot \mathbf{LOV}}{W_{EN} \cdot L_{EN}} \quad (3.75)$$

$$\mathbf{AGIDL D = AGIDL DW} \cdot \frac{W_E \cdot \mathbf{LOVD}}{W_{EN} \cdot L_{EN}} \quad (3.76)$$

$$\mathbf{BGIDL = BGIDLO} \quad (3.77)$$

$$\mathbf{BGIDL D = BGIDL DO} \quad (3.78)$$

$$\mathbf{STBGIDL = STBGIDLO} \quad (3.79)$$

$$\mathbf{STBGIDL D = STBGIDL DO} \quad (3.80)$$

$$\mathbf{CGIDL = CGIDLO} \quad (3.81)$$

$$\mathbf{CGIDL D = CGIDL DO} \quad (3.82)$$

Charge Model Parameters

$$\epsilon_{ox} = \epsilon_0 \cdot \mathbf{EPSROX} \quad (3.83)$$

$$\mathbf{COX} = \epsilon_{ox} \cdot \frac{W_{E,CV} \cdot L_{E,CV}}{\mathbf{TOX}} \quad (3.84)$$

$$\mathbf{CGOV} = \epsilon_{ox} \cdot \frac{W_{E,CV} \cdot \mathbf{LOV}}{\mathbf{TOXOV}} \quad (3.85)$$

$$\mathbf{CGOVD} = \epsilon_{ox} \cdot \frac{W_{E,CV} \cdot \mathbf{LOVD}}{\mathbf{TOXOVD}} \quad (3.86)$$

$$\mathbf{CGBOV} = \mathbf{CGBOVL} \cdot \frac{L_{G,CV}}{L_{EN}} \quad (3.87)$$

$$\mathbf{CFR} = \mathbf{CFRW} \cdot \frac{W_{G,CV}}{W_{EN}} \quad (3.88)$$

$$\mathbf{CFRD} = \mathbf{CFRDW} \cdot \frac{W_{G,CV}}{W_{EN}} \quad (3.89)$$

Thermal Noise Model Parameters

Note that the equation below makes use of the value of **BETN** calculated in Eq. (3.39). Because **BETN** is roughly proportional to W_E/L_E , the resulting **FNTEXC** is roughly proportional to $1/L_E^2$. In addition, it will inherit some minor L - and W -dependence from **BETN**.

$$\mathbf{FNTEXC} = \mathbf{FNTEXCL} \cdot \mathbf{BETN}^2 \cdot \left[\frac{W_{EN}}{W_E} \right]^2 \quad (3.90)$$

Flicker Noise Model Parameters

$$L_{noi} = \text{MAX} \left(1 - \frac{2 \cdot \mathbf{LINTNOI}}{L_E}, 10^{-3} \right) \quad (3.91)$$

$$L_{red} = \frac{1}{L_{noi}^{ALPNOI}} \quad (3.92)$$

$$\mathbf{NFA} = L_{red} \cdot \mathbf{NFALW} \cdot \frac{W_{EN} \cdot L_{EN}}{W_E \cdot L_E} \quad (3.93)$$

$$\mathbf{NFB} = L_{red} \cdot \mathbf{NFBLW} \cdot \frac{W_{EN} \cdot L_{EN}}{W_E \cdot L_E} \quad (3.94)$$

$$\mathbf{NFC} = L_{red} \cdot \mathbf{NFCLW} \cdot \frac{W_{EN} \cdot L_{EN}}{W_E \cdot L_E} \quad (3.95)$$

$$\mathbf{EF} = \mathbf{EFO} \quad (3.96)$$

WPE parameters

$$\begin{aligned} K_{vthowe} = \mathbf{KVTHOWEO} + \mathbf{KVTHOWEL} \cdot \frac{L_{EN}}{L_E} + \mathbf{KVTHOWEW} \cdot \frac{W_{EN}}{W_E} \\ + \mathbf{KVTHOWELW} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \end{aligned} \quad (3.97)$$

$$\begin{aligned} K_{uowe} = \mathbf{KUOWEO} + \mathbf{KUOWEL} \cdot \frac{L_{EN}}{L_E} + \mathbf{KUOWEW} \cdot \frac{W_{EN}}{W_E} \\ + \mathbf{KUOWELW} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \end{aligned} \quad (3.98)$$

3.3 Binning equations

The binning equations are provided as a (phenomenological) alternative to the physical scaling equations for computing local parameters. The physical geometrical scaling rules have been developed to give a good description over the whole geometry range of CMOS technologies. For processes under development, however, it is sometimes useful to have more flexible scaling relations. In that case one could opt for a binning strategy, where the accuracy with geometry is mostly determined by the number of bins used. The physical scaling rules of Section 3.2 are generally not suitable for binning strategies, since they may result in discontinuities in local parameter values at the bin boundaries. Consequently, special binning geometrical scaling relations have been developed, which guarantee continuity of the resulting local model parameters at the bin boundaries.

Only four different types of binning scaling rules are used, which are based on first order developments of the geometrical scaling rules in terms of L_E , $1/L_E$, W_E , and $1/W_E$ (examples below are for a fictitious parameter **YYY**):

1. Type I

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWYYY} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWYYY} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.99)$$

2. Type II

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_E}{L_{EN}} + \mathbf{PWYYY} \cdot \frac{W_E}{W_{EN}} + \mathbf{PLWYYY} \cdot \frac{L_E \cdot W_E}{L_{EN} \cdot W_{EN}} \quad (3.100)$$

3. Type III

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWYYY} \cdot \frac{W_E}{W_{EN}} + \mathbf{PLWYYY} \cdot \frac{W_E \cdot L_{EN}}{W_{EN} \cdot L_E} \quad (3.101)$$

4. Type IV (no binning)

$$\mathbf{YYY} = \mathbf{POYYY} \quad (3.102)$$

In Table 3.1 a survey of the binning type used for each local parameter is given. In some cases where the geometrical scaling rule is constant, the binning rule is chosen to be more flexible.

When using the binning rules above, the binning parameters for one bin can be directly calculated from the local parameter sets of the four corner devices of the bin (see Sec. 7.6). This results in a *separate parameter set for each bin*. The binning scheme ensures that the local parameters are exactly reproduced at the bin corners and that no humps occur in the local parameter values across bin boundaries.

Note: After calculation of the local parameters from the binning rules (and possible application of the stress equations in Section 3.5), clipping is applied according to Section 2.5.7.

Table 3.1: Overview of local parameters and binning type. The third column indicates whether there is a physical geometrical scaling rule for the local parameters.

#	parameter	physical scaling	binning	#	parameter	physical scaling	binning
0	LEVEL	no	no	42	STTHESAT	yes	type I
1	TYPE	no	no	43	THESATB	no	type I
2	TR	no	no	44	THESATG	no	type I
3	SWIGATE	no	no	45	AX	yes	type I
4	SWIMPACT	no	no	46	ALP	yes	type I
5	SWGIDL	no	no	47	ALP1	yes	type I
6	SWJUNCAP	no	no	48	ALP2	yes	type I
7	SWJUNASYM	no	no	49	VP	no	no
8	QMC	no	no	50	A1	yes	type I
9	VFB	yes	type I	51	A2	no	no
10	STVFB	yes	type I	52	STA2	no	no
11	TOX	no	no	53	A3	yes	type I
12	EPSROX	no	no	54	A4	yes	type I
13	NEFF	yes	type I	55	GCO	no	no
14	VNSUB	no	no	56	IGINV	yes	type II
15	NSLP	no	no	57	IGOV	yes	type III
16	DNSUB	no	no	58	IGOVD	yes	type III
17	DPHIB	yes	type I	59	STIG	no	no
18	NP	yes	type I	60	GC2	no	no
19	CT	yes	type I	61	GC3	no	no
20	TOXOV	no	no	62	CHIB	no	no
21	TOXOVD	no	no	63	AGIDL	yes	type III
22	NOV	no	type I	64	AGIDLD	yes	type III
23	NOVD	no	type I	65	BGIDL	no	no
24	CF	yes	type I	66	BGIDLD	no	no
25	CFB	no	no	67	STBGIDL	no	no
26	BETN	yes	type III	68	STBGIDLD	no	no
27	STBET	yes	type I	69	CGIDL	no	no
28	MUE	yes	type I	70	CGIDLD	no	no
29	STMUE	no	no	71	COX	yes	type II
30	THEMU	no	no	72	CGOV	yes	type III
31	STTHEMU	no	no	73	CGOVD	yes	type III
32	CS	yes	type I	74	CGBOV	yes	type II
33	STCS	no	no	75	CFR	yes	type III
34	XCOR	yes	type I	76	CFRD	yes	type III
35	STXCOR	no	no	77	FNT	no	no
36	FETA	no	no	78	FNTEXC	yes	type I
37	RS	yes	type I	79	NFA	yes	type I
38	STRS	no	no	80	NFB	yes	type I
39	RSB	no	no	81	NFC	yes	type I
40	RSG	no	no	82	EF	no	no
41	THESAT	yes	type I	83	DTA	no	no

Effective length and width

$$L_{EN} = 10^{-6} \quad (3.103)$$

$$W_{EN} = 10^{-6} \quad (3.104)$$

$$\Delta L_{PS} = \mathbf{LVARO} \cdot \left(1 + \mathbf{LVARL} \cdot \frac{L_{EN}}{L} \right) \quad (3.105)$$

$$\Delta W_{OD} = \mathbf{WVARO} \cdot \left(1 + \mathbf{WVARW} \cdot \frac{W_{EN}}{W_f} \right) \quad (3.106)$$

$$L_E = L - \Delta L = L + \Delta L_{PS} - 2 \cdot \mathbf{LAP} \quad (3.107)$$

$$W_E = W_f - \Delta W = W_f + \Delta W_{OD} - 2 \cdot \mathbf{WOT} \quad (3.108)$$

$$L_{E,CV} = L + \Delta L_{PS} - 2 \cdot \mathbf{LAP} + \mathbf{DLQ} \quad (3.109)$$

$$W_{E,CV} = W_f + \Delta W_{OD} - 2 \cdot \mathbf{WOT} + \mathbf{DWQ} \quad (3.110)$$

$$L_{G,CV} = L + \Delta L_{PS} + \mathbf{DLQ} \quad (3.111)$$

$$W_{G,CV} = W_f + \Delta W_{OD} + \mathbf{DWQ} \quad (3.112)$$

Note: If the calculated L_E , W_E , $L_{E,CV}$, $W_{E,CV}$, $L_{G,CV}$, or $W_{G,CV}$ is smaller than 1 nm (10^{-9} m), the value is clipped to this lower bound of 1 nm.

Process Parameters

$$\mathbf{VFB} = \mathbf{POVFB} + \mathbf{PLVFB} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWVFB} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWVFB} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.113)$$

$$\mathbf{STVFB} = \mathbf{POSTVFB} + \mathbf{PLSTVFB} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWSTVFB} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWSTVFB} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.114)$$

$$\mathbf{TOX} = \mathbf{POTOX} \quad (3.115)$$

$$\mathbf{EPSROX} = \mathbf{POEPSROX} \quad (3.116)$$

$$\mathbf{NEFF} = \mathbf{PONEFF} + \mathbf{PLNEFF} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWNEFF} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWNEFF} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.117)$$

$$\mathbf{VNSUB} = \mathbf{POVNSUB} \quad (3.118)$$

$$\mathbf{NSLP} = \mathbf{PONS LP} \quad (3.119)$$

$$\mathbf{DNSUB} = \mathbf{PODNSUB} \quad (3.120)$$

$$\mathbf{DPHIB} = \mathbf{PODPHIB} + \mathbf{PLDPHIB} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWDPHIB} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWDPHIB} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.121)$$

$$\mathbf{NP} = \mathbf{PONP} + \mathbf{PLNP} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWNP} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWNP} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.122)$$

$$\mathbf{CT} = \mathbf{POCT} + \mathbf{PLCT} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWCT} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWCT} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.123)$$

$$\mathbf{TOXOV} = \mathbf{POTOXOV} \quad (3.124)$$

$$\mathbf{TOXOVD} = \mathbf{POTOXOVD} \quad (3.125)$$

$$\mathbf{NOV} = \mathbf{PONOV} + \mathbf{PLNOV} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWNOV} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWNOV} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.126)$$

$$\mathbf{NOVD} = \mathbf{PONOVD} + \mathbf{PLNOVD} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWNOVD} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWNOVD} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.127)$$

DIBL Parameters

$$\mathbf{CF} = \mathbf{POCF} + \mathbf{PLCF} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWCF} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWCF} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.128)$$

$$\mathbf{CFB} = \mathbf{POCFB} \quad (3.129)$$

Mobility Parameters

$$\mathbf{BETN} = \mathbf{POBETN} + \mathbf{PLBETN} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWBETN} \cdot \frac{W_E}{W_{EN}} + \mathbf{PLWBETN} \cdot \frac{W_E \cdot L_{EN}}{W_{EN} \cdot L_E} \quad (3.130)$$

$$\mathbf{STBET} = \mathbf{POSTBET} + \mathbf{PLSTBET} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWSTBET} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWSTBET} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.131)$$

$$\mathbf{MUE} = \mathbf{POMUE} + \mathbf{PLMUE} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWMUE} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWMUE} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.132)$$

$$\mathbf{STMUE} = \mathbf{POSTMUE} \quad (3.133)$$

$$\mathbf{THEMU} = \mathbf{POTHEMU} \quad (3.134)$$

$$\mathbf{STTHEMU} = \mathbf{POSTTHEMU} \quad (3.135)$$

$$\mathbf{CS} = \mathbf{POCS} + \mathbf{PLCS} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWCS} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWCS} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.136)$$

$$\mathbf{STCS} = \mathbf{POSTCS} \quad (3.137)$$

$$\mathbf{XCOR} = \mathbf{POXCOR} + \mathbf{PLXCOR} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWXCOR} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWXCOR} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.138)$$

$$\mathbf{STXCOR} = \mathbf{POSTXCOR} \quad (3.139)$$

$$\mathbf{FETA} = \mathbf{POFETA} \quad (3.140)$$

Series Resistance Parameters

$$\mathbf{RS} = \mathbf{PORS} + \mathbf{PLRS} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWRS} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWRS} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.141)$$

$$\mathbf{STRS} = \mathbf{POSTRS} \quad (3.142)$$

$$\mathbf{RSB} = \mathbf{PORSB} \quad (3.143)$$

$$\mathbf{RSG} = \mathbf{PORSG} \quad (3.144)$$

Velocity Saturation Parameters

$$\begin{aligned} \text{THESAT} = & \text{POTHE SAT} + \text{PLTHE SAT} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \\ & + \text{PWTHE SAT} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWTHE SAT} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \end{aligned} \quad (3.145)$$

$$\begin{aligned} \text{STTHE SAT} = & \text{POSTTHE SAT} + \text{PLSTTHE SAT} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \\ & + \text{PWSTTHE SAT} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWSTTHE SAT} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \end{aligned} \quad (3.146)$$

$$\begin{aligned} \text{THESATB} = & \text{POTHE SATB} + \text{PLTHE SATB} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \\ & + \text{PWTHE SATB} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWTHE SATB} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \end{aligned} \quad (3.147)$$

$$\begin{aligned} \text{THESATG} = & \text{POTHE SATG} + \text{PLTHE SATG} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \\ & + \text{PWTHE SATG} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWTHE SATG} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \end{aligned} \quad (3.148)$$

Saturation Voltage Parameters

$$\text{AX} = \text{POAX} + \text{PLAX} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \text{PWAX} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWAX} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.149)$$

Channel Length Modulation (CLM) Parameters

$$\text{ALP} = \text{POALP} + \text{PLALP} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \text{PWALP} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWALP} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.150)$$

$$\text{ALP1} = \text{POALP1} + \text{PLALP1} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \text{PWALP1} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWALP1} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.151)$$

$$\text{ALP2} = \text{POALP2} + \text{PLALP2} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \text{PWALP2} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWALP2} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.152)$$

$$\text{VP} = \text{POVP} \quad (3.153)$$

Impact Ionization (II) Parameters

$$\text{A1} = \text{POA1} + \text{PLA1} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \text{PWA1} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \text{PLWA1} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.154)$$

$$\text{A2} = \text{POA2} \quad (3.155)$$

$$\text{STA2} = \text{POSTA2} \quad (3.156)$$

$$\mathbf{A3} = \mathbf{POA3} + \mathbf{PLA3} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWA3} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWA3} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.157)$$

$$\mathbf{A4} = \mathbf{POA4} + \mathbf{PLA4} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWA4} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWA4} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.158)$$

Gate Current Parameters

$$\mathbf{GCO} = \mathbf{POGCO} \quad (3.159)$$

$$\begin{aligned} \mathbf{GINV} = \mathbf{POGINV} + \mathbf{PLGINV} \cdot \frac{L_E}{L_{EN}} \\ + \mathbf{PWGINV} \cdot \frac{W_E}{W_{EN}} + \mathbf{PLWGINV} \cdot \frac{L_E \cdot W_E}{L_{EN} \cdot W_{EN}} \end{aligned} \quad (3.160)$$

$$\mathbf{IGOV} = \mathbf{POIGOV} + \mathbf{PLIGOV} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWIGOV} \cdot \frac{W_E}{W_{EN}} + \mathbf{PLWIGOV} \cdot \frac{W_E \cdot L_{EN}}{W_{EN} \cdot L_E} \quad (3.161)$$

$$\mathbf{IGOVD} = \mathbf{POIGOVD} + \mathbf{PLIGOVD} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWIGOVD} \cdot \frac{W_E}{W_{EN}} + \mathbf{PLWIGOVD} \cdot \frac{W_E \cdot L_{EN}}{W_{EN} \cdot L_E} \quad (3.162)$$

$$\mathbf{STIG} = \mathbf{POSTIG} \quad (3.163)$$

$$\mathbf{GC2} = \mathbf{POGC2} \quad (3.164)$$

$$\mathbf{GC3} = \mathbf{POGC3} \quad (3.165)$$

$$\mathbf{CHIB} = \mathbf{POCHIB} \quad (3.166)$$

Gate-Induced Drain Leakage (GIDL) Parameters

$$\begin{aligned} \mathbf{AGIDL} = \mathbf{POAGIDL} + \mathbf{PLAGIDL} \cdot \frac{L_{EN}}{L_E} \\ + \mathbf{PWAGIDL} \cdot \frac{W_E}{W_{EN}} + \mathbf{PLWAGIDL} \cdot \frac{W_E \cdot L_{EN}}{W_{EN} \cdot L_E} \end{aligned} \quad (3.167)$$

$$\begin{aligned} \mathbf{AGIDL D} = \mathbf{POAGIDL D} + \mathbf{PLAGIDL D} \cdot \frac{L_{EN}}{L_E} \\ + \mathbf{PWAGIDL D} \cdot \frac{W_E}{W_{EN}} + \mathbf{PLWAGIDL D} \cdot \frac{W_E \cdot L_{EN}}{W_{EN} \cdot L_E} \end{aligned} \quad (3.168)$$

$$\mathbf{BGIDL} = \mathbf{POBGIDL} \quad (3.169)$$

$$\mathbf{BGIDL D} = \mathbf{POBGIDL D} \quad (3.170)$$

$$\mathbf{STBGIDL} = \mathbf{POSTBGIDL} \quad (3.171)$$

$$\mathbf{STBGIDL D} = \mathbf{POSTBGIDL D} \quad (3.172)$$

$$\mathbf{CGIDL} = \mathbf{POCGIDL} \quad (3.173)$$

$$\mathbf{CGIDL D} = \mathbf{POCGIDL D} \quad (3.174)$$

Charge Model Parameters

$$\mathbf{COX} = \mathbf{POCOX} + \mathbf{PLCOX} \cdot \frac{L_{E,CV}}{L_{EN}} + \mathbf{PWCOX} \cdot \frac{W_{E,CV}}{W_{EN}} + \mathbf{PLWCOX} \cdot \frac{L_{E,CV} \cdot W_{E,CV}}{L_{EN} \cdot W_{EN}} \quad (3.175)$$

$$\begin{aligned} \mathbf{CGOV} = \mathbf{POCGOV} + \mathbf{PLCGOV} \cdot \frac{L_{EN}}{L_{E,CV}} \\ + \mathbf{PWCGOV} \cdot \frac{W_{E,CV}}{W_{EN}} + \mathbf{PLWCGOV} \cdot \frac{W_{E,CV} \cdot L_{EN}}{W_{EN} \cdot L_{E,CV}} \end{aligned} \quad (3.176)$$

$$\begin{aligned} \mathbf{CGOVD} = \mathbf{POCGOVD} + \mathbf{PLCGOVD} \cdot \frac{L_{EN}}{L_{E,CV}} \\ + \mathbf{PWCGOVD} \cdot \frac{W_{E,CV}}{W_{EN}} + \mathbf{PLWCGOVD} \cdot \frac{W_{E,CV} \cdot L_{EN}}{W_{EN} \cdot L_{E,CV}} \end{aligned} \quad (3.177)$$

$$\begin{aligned} \mathbf{CGBOV} = \mathbf{POCGBOV} + \mathbf{PLCGBOV} \cdot \frac{L_{G,CV}}{L_{EN}} \\ + \mathbf{PWCGBOV} \cdot \frac{W_{G,CV}}{W_{EN}} + \mathbf{PLWCGBOV} \cdot \frac{L_{G,CV} \cdot W_{G,CV}}{L_{EN} \cdot W_{EN}} \end{aligned} \quad (3.178)$$

$$\mathbf{CFR} = \mathbf{POCFR} + \mathbf{PLCFR} \cdot \frac{L_{EN}}{L_{G,CV}} + \mathbf{PWCFR} \cdot \frac{W_{G,CV}}{W_{EN}} + \mathbf{PLWCFR} \cdot \frac{W_{G,CV} \cdot L_{EN}}{W_{EN} \cdot L_{G,CV}} \quad (3.179)$$

$$\mathbf{CFRD} = \mathbf{POCFRD} + \mathbf{PLCFRD} \cdot \frac{L_{EN}}{L_{G,CV}} + \mathbf{PWCFRD} \cdot \frac{W_{G,CV}}{W_{EN}} + \mathbf{PLWCFRD} \cdot \frac{W_{G,CV} \cdot L_{EN}}{W_{EN} \cdot L_{G,CV}} \quad (3.180)$$

Thermal Noise Model Parameters

$$\mathbf{FNT} = \mathbf{POFNT} \quad (3.181)$$

$$\begin{aligned} \mathbf{FNTEXC} = \left[\frac{L_{EN}}{L_E} \right]^2 \cdot \left(\mathbf{POFNTEXC} + \mathbf{PLFNTEXC} \cdot \frac{L_{EN}}{L_E} \right. \\ \left. + \mathbf{PWFNTEXC} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWFNTEXC} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \right) \end{aligned} \quad (3.182)$$

Flicker Noise Model Parameters

$$\mathbf{NFA} = \mathbf{PONFA} + \mathbf{PLNFA} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWNFA} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWNFA} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.183)$$

$$\mathbf{NFB} = \mathbf{PONFB} + \mathbf{PLNFB} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWNFB} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWNFB} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.184)$$

$$\mathbf{NFC} = \mathbf{PONFC} + \mathbf{PLNFC} \cdot \frac{L_{EN}}{L_E} + \mathbf{PWNFC} \cdot \frac{W_{EN}}{W_E} + \mathbf{PLWNFC} \cdot \frac{L_{EN} \cdot W_{EN}}{L_E \cdot W_E} \quad (3.185)$$

$$\mathbf{EF} = \mathbf{POEF} \quad (3.186)$$

WPE parameters

$$\begin{aligned}
 K_{\text{vthowe}} = & \mathbf{POKVTHOWE} + \mathbf{PLKVTHOWE} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \mathbf{PWKVTHOWE} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \\
 & + \mathbf{PLWKVTHOWE} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.187)
 \end{aligned}$$

$$\begin{aligned}
 K_{\text{uowe}} = & \mathbf{POKUOWE} + \mathbf{PLKUOWE} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \mathbf{PWKUOWE} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \\
 & + \mathbf{PLWKUOWE} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.188)
 \end{aligned}$$

3.4 Parasitic resistances

PSP model contains a network of parasitic elements: a gate resistance and four bulk resistances. Note that the junction diodes are no longer directly connected to the bulk terminal of the intrinsic MOS-transistor. The complete circuit is shown in Fig. 3.2. At this moment, only the gate resistance is scaled with geometry (facilitating the implementation of multi-finger devices).

$$L_f = L + \Delta L_{PS} \quad (3.189)$$

$$L_{sil,f} = L_f + \mathbf{DLSIL} \quad (3.190)$$

$$W_{E,f} = W_f + \Delta W_{OD} \quad (3.191)$$

$$X_{GWE} = \mathbf{XGW} - 0.5 \cdot \Delta W_{OD} \quad (3.192)$$

$$\mathbf{RG} = \mathbf{RGO} + \frac{1}{\mathbf{NF}} \cdot \left[\frac{\mathbf{RSHG} \cdot \left(\frac{W_{E,f}}{3 \cdot \mathbf{NGCON}} + X_{GWE} \right)}{\mathbf{NGCON} \cdot L_{sil,f}} + \frac{\mathbf{RINT} + \mathbf{RVPOLY}}{W_{E,f} \cdot L_f} \right] \quad (3.193)$$

$$\mathbf{RBULK} = \mathbf{RBULKO} \quad (3.194)$$

$$\mathbf{RWELL} = \mathbf{RWELLO} \quad (3.195)$$

$$\mathbf{RJUNS} = \mathbf{RJUNSO} \quad (3.196)$$

$$\mathbf{RJUND} = \mathbf{RJUNDO} \quad (3.197)$$

Note: The values of L_f , $L_{sil,f}$, $W_{E,f}$ and X_{GWE} are clipped to a minimum value of 1 nm. The calculated local parameters are subject to the boundaries specified in Section 2.5.9.

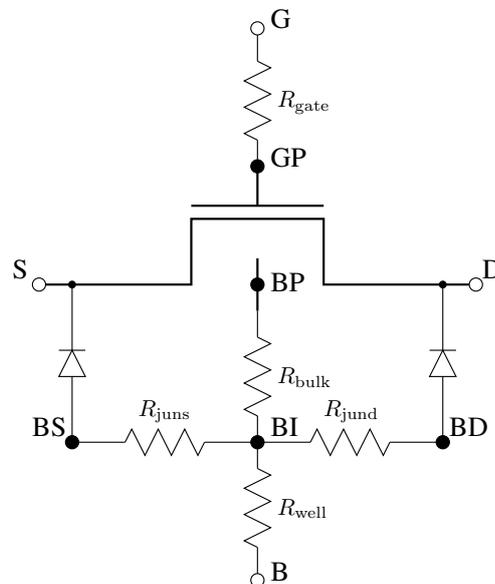


Figure 3.2: Parasitics circuit

3.5 Stress effects

The stress model of BSIM4.4.0 [3] has been adopted in PSP without any modifications, except for two changes: (1) in the original BSIM parameter names all zeros have been replaced by “O”s, in order to comply with PSP conventions and (2) the BSIM parameters *STK2* and *LODK2* are not available in PSP. Some trivial conversion of parameters BSIM→PSP is still necessary, see [2].

The local PSP parameters affected by the stress equations are **BETN**, **THESAT**, **VFB**, and **CF**.

Calculation of **SA** and **SB** for irregular layouts is given in Section B.1.

Note:

- After modification of the local parameters by the stress equations, clipping is applied according to Section 2.5.7.
- If both **SA** and **SB** are set to 0, the stress-equations are *not* computed.

3.5.1 Layout effects for multi-finger devices

For multi-finger devices, effective values **SA_{eff}** and **SB_{eff}** for the instance parameters are calculated (see Fig. 3.3).

$$\frac{1}{\mathbf{SA}_{\text{eff}} + 0.5 \cdot L} = \frac{1}{\mathbf{NF}} \cdot \sum_{i=0}^{\mathbf{NF}-1} \frac{1}{\mathbf{SA} + 0.5 \cdot L + i \cdot (\mathbf{SD} + L)} \quad (3.198)$$

$$\frac{1}{\mathbf{SB}_{\text{eff}} + 0.5 \cdot L} = \frac{1}{\mathbf{NF}} \cdot \sum_{i=0}^{\mathbf{NF}-1} \frac{1}{\mathbf{SB} + 0.5 \cdot L + i \cdot (\mathbf{SD} + L)} \quad (3.199)$$

3.5.2 Layout effects for regular shapes

$$R_A = \frac{1}{\mathbf{SA}_{\text{eff}} + 0.5 \cdot L} \quad (3.200)$$

$$R_B = \frac{1}{\mathbf{SB}_{\text{eff}} + 0.5 \cdot L} \quad (3.201)$$

$$R_{A,\text{ref}} = \frac{1}{\mathbf{SAREF} + 0.5 \cdot L} \quad (3.202)$$

$$R_{B,\text{ref}} = \frac{1}{\mathbf{SBREF} + 0.5 \cdot L} \quad (3.203)$$

3.5.3 Parameter modifications

Mobility-related equations

$$K_{u0} = \left(1 + \frac{\mathbf{LKUO}}{(L + \Delta L_{\text{PS}})^{\mathbf{LLODKUO}}} + \frac{\mathbf{WKUO}}{(W_f + \Delta W_{\text{OD}} + \mathbf{WLOD})^{\mathbf{WLODKUO}}} + \frac{\mathbf{PKUO}}{(L + \Delta L_{\text{PS}})^{\mathbf{LLODKUO}} \cdot (W_f + \Delta W_{\text{OD}} + \mathbf{WLOD})^{\mathbf{WLODKUO}}} \right) \cdot \left[1 + \mathbf{TKUO} \cdot \left(\frac{T_{\text{KD}}}{T_{\text{KR}}} - 1 \right) \right] \quad (3.204)$$

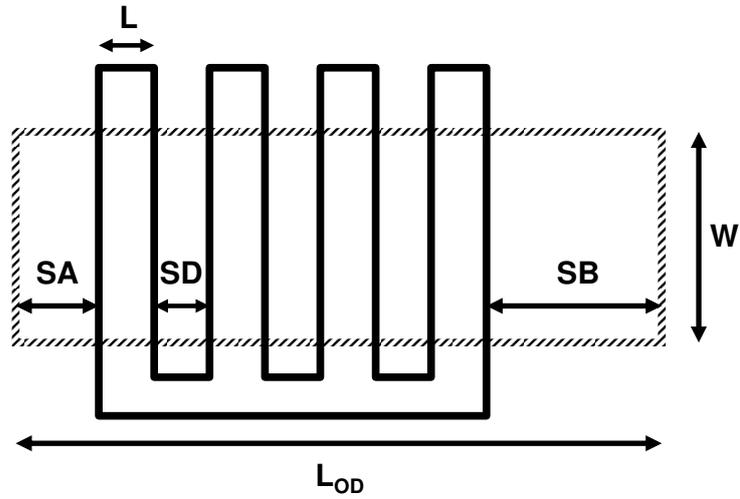


Figure 3.3: A typical layout of multi-finger devices with an additional instance parameters SD .

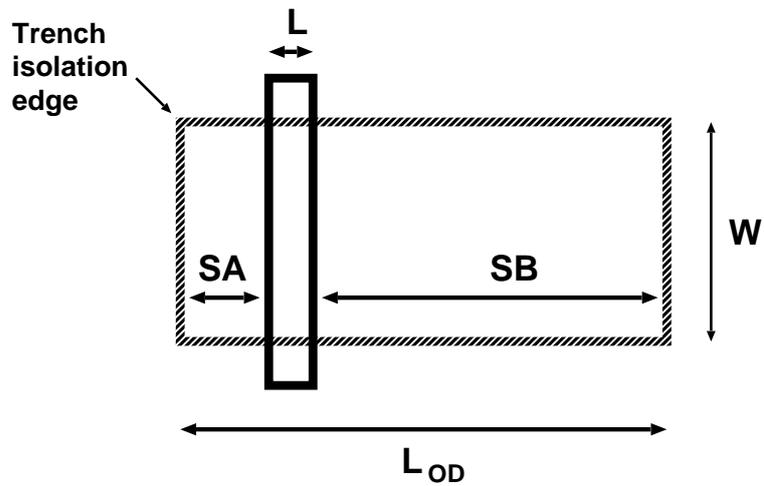


Figure 3.4: Typical layout of a MOSFET. Note that $L_{OD} = SA + SB + L$, where OD is the active region definition.

$$\rho_{\beta} = \frac{\mathbf{KUO}}{K_{u0}} \cdot (R_A + R_B) \quad (3.205)$$

$$\rho_{\beta,\text{ref}} = \frac{\mathbf{KUO}}{K_{u0}} \cdot (R_{A,\text{ref}} + R_{B,\text{ref}}) \quad (3.206)$$

$$\mathbf{BETN} = \frac{1 + \rho_{\beta}}{1 + \rho_{\beta,\text{ref}}} \cdot \mathbf{BETN}_{\text{ref}} \quad (3.207)$$

$$\mathbf{THESAT} = \frac{1 + \rho_{\beta}}{1 + \rho_{\beta,\text{ref}}} \cdot \frac{1 + \mathbf{KVSAT} \cdot \rho_{\beta,\text{ref}}}{1 + \mathbf{KVSAT} \cdot \rho_{\beta}} \cdot \mathbf{THESAT}_{\text{ref}} \quad (3.208)$$

Threshold-voltage-related equations

$$K_{\text{vth0}} = 1 + \frac{\mathbf{LKVTHO}}{(L + \Delta L_{\text{PS}})^{\mathbf{LLODVTH}}} + \frac{\mathbf{WKVTHO}}{(W_f + \Delta W_{\text{OD}} + \mathbf{WLOD})^{\mathbf{WLODVTH}}} + \frac{\mathbf{PKVTHO}}{(L + \Delta L_{\text{PS}})^{\mathbf{LLODVTH}} \cdot (W_f + \Delta W_{\text{OD}} + \mathbf{WLOD})^{\mathbf{WLODVTH}}} \quad (3.209)$$

$$\Delta R = R_A + R_B - R_{A,\text{ref}} - R_{B,\text{ref}} \quad (3.210)$$

$$\mathbf{VFB} = \mathbf{VFB}_{\text{ref}} + \mathbf{KVTHO} \cdot \frac{\Delta R}{K_{\text{vth0}}} \quad (3.211)$$

$$\mathbf{CF} = \mathbf{CF}_{\text{ref}} + \mathbf{STETAO} \cdot \frac{\Delta R}{K_{\text{vth0}}^{\mathbf{LODETAO}}} \quad (3.212)$$

3.6 Well proximity effects

The well proximity effect (WPE) model from BSIM4.5.0 [4, 5, 6] has been adopted in PSP with two changes relative to BSIM4.5.0: (1) in the original BSIM parameter names all zeros have been replaced by 'O's in order to comply with PSP naming convention and (2) the BSIM parameter *K2WE* is not available in PSP. Except for some trivial conversion of parameters BSIM→PSP [2], WPE parameters from BSIM can be used directly in PSP.

The local PSP parameters affected by the WPE equations are **VFB** and **BETN**.

How to calculate **SCA**, **SCB**, and **SCC** is shown in Section B.2.

Note:

- After modification of the local parameters by the WPE equations, clipping is applied according to Section 2.5.7.
- If **SCA**, **SCB**, **SCC** and **SC** are all set to 0, the WPE equations are *not* computed.

3.6.1 Parameters for pre-layout simulation

If **SCA** = **SCB** = **SCC** = 0 and **SC** > 0, **SCA**, **SCB**, and **SCC** will be computed from **SC** according to Eqs. (B.9)–(B.11), as shown below. Here, **SC** should be taken as the distance to the nearest well edge (see Fig. 3.5). If any of the parameters **SCA**, **SCB**, or **SCC** is positive, all three values as supplied will be used and **SC** will be ignored.

If **SCA** = **SCB** = **SCC** = 0 and **SC** > 0

$$\mathbf{SCA} = \frac{\mathbf{SCREF}^2}{W_f} \cdot \left(\frac{1}{\mathbf{SC}} - \frac{1}{\mathbf{SC} + W_f} \right) \quad (3.213)$$

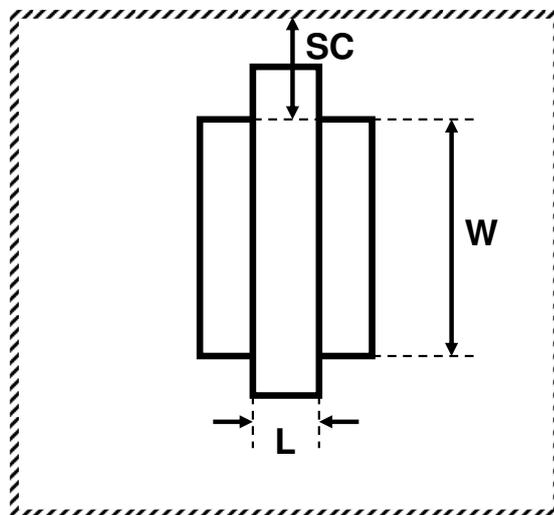


Figure 3.5: A layout of MOS devices for pre-layout simulation using estimated value for **SC**.

$$\begin{aligned} \mathbf{SCB} = \frac{1}{W_f \cdot \mathbf{SCREF}} \cdot & \left[\frac{\mathbf{SCREF}}{10} \cdot \mathbf{SC} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}}\right) + \frac{\mathbf{SCREF}^2}{100} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}}\right) \right. \\ & - \frac{\mathbf{SCREF}}{10} \cdot (\mathbf{SC} + W_f) \cdot \exp\left(-10 \cdot \frac{\mathbf{SC} + W_f}{\mathbf{SCREF}}\right) \\ & \left. - \frac{\mathbf{SCREF}^2}{100} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC} + W_f}{\mathbf{SCREF}}\right) \right] \quad (3.214) \end{aligned}$$

$$\begin{aligned} \mathbf{SCC} = \frac{1}{W_f \cdot \mathbf{SCREF}} \cdot & \left[\frac{\mathbf{SCREF}}{20} \cdot \mathbf{SC} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}}\right) + \frac{\mathbf{SCREF}^2}{400} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}}\right) \right. \\ & - \frac{\mathbf{SCREF}}{20} \cdot (\mathbf{SC} + W_f) \cdot \exp\left(-20 \cdot \frac{\mathbf{SC} + W_f}{\mathbf{SCREF}}\right) \\ & \left. - \frac{\mathbf{SCREF}^2}{400} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC} + W_f}{\mathbf{SCREF}}\right) \right] \quad (3.215) \end{aligned}$$

3.6.2 Calculation of parameter modifications

The calculation of K_{vthowe} and K_{uowe} is given in Section 3.2 (global model) or 3.3 (binning model).

$$\mathbf{VFB} = \mathbf{VFB}_{ref} + K_{vthowe} \cdot (\mathbf{SCA} + \mathbf{WEB} \cdot \mathbf{SCB} + \mathbf{WEC} \cdot \mathbf{SCC}) \quad (3.216)$$

$$\mathbf{BETN} = \mathbf{BETN}_{ref} \cdot [1 + K_{uowe} \cdot (\mathbf{SCA} + \mathbf{WEB} \cdot \mathbf{SCB} + \mathbf{WEC} \cdot \mathbf{SCC})] \quad (3.217)$$

3.7 Asymmetric junctions

From PSP 102.3 onwards, asymmetric junction can be modeled in PSP. This includes asymmetric source-bulk and drain-bulk junctions, GIDL/GISL, overlap gate currents, overlap capacitances and outer fringe capacitances. The asymmetric junction model can be switched on by means of the parameter **SWJUNASYM**. Note that if **SWJUNASYM** = 1, the new parameters for the drain side are used all together. Those whose values are not explicitly specified in the model card are set to their default value, *not* to their counterparts for the source side. In other words, it is not possible to activate the parameters for the drain side on a one-by-one basis. The physical scaling and binning rules to calculate the related local parameters for the drain side are given in Section 3.2 and 3.3.

If **SWJUNASYM** = 0, the related parameters for the drain side are ignored. Effectively, the following assignments are applied before evaluation of the calculations described in Section 4.

If **SWJUNASYM** = 0:

$$\mathbf{TOXOVD} = \mathbf{TOXOV} \quad (3.218)$$

$$\mathbf{NOVD} = \mathbf{NOV} \quad (3.219)$$

$$\mathbf{AGIDLD} = \mathbf{AGIDL} \quad (3.220)$$

$$\mathbf{BGIDLD} = \mathbf{BGIDL} \quad (3.221)$$

$$\mathbf{STBGIDLD} = \mathbf{STBGIDL} \quad (3.222)$$

$$\mathbf{CGIDLD} = \mathbf{CGIDL} \quad (3.223)$$

$$\mathbf{IGOVD} = \mathbf{IGOV} \quad (3.224)$$

$$\mathbf{CGOVD} = \mathbf{CGOV} \quad (3.225)$$

$$\mathbf{CFRD} = \mathbf{CFR} \quad (3.226)$$

Section 4

PSP Model Equations

4.1 Internal Parameters (including Temperature Scaling)

In this section, bias-independent internal parameters will be calculated, including temperature scaling. These parameters are computed from local parameters. Local parameters are (as usual) denoted by capital characters in bold font, whereas the internal parameters are denoted by symbols in bold font.

Transistor temperature

$$T_{KR} = T_0 + \mathbf{TR} \quad (4.1)$$

$$T_{KD} = T_0 + T_A + \mathbf{DTA} \quad (4.2)$$

$$\Delta T = T_{KD} - T_{KR} \quad (4.3)$$

$$\phi_T = \frac{k_B \cdot T_{KD}}{q} \quad (4.4)$$

Local process parameters

$$\phi_T^* = \phi_T \cdot \left(1 + \mathbf{CT} \cdot \frac{T_{KR}}{T_{KD}} \right) \quad (4.5)$$

$$\mathbf{V}_{FB} = \mathbf{VFB} + \mathbf{STVFB} \cdot \Delta T + \mathbf{DELVTO} \quad (4.6)$$

$$E_g/q = 1.179 - 9.025 \cdot 10^{-5} \cdot T_{KD} - 3.05 \cdot 10^{-7} \cdot T_{KD}^2 \quad (4.7)$$

$$r_T = (1.045 + 4.5 \cdot 10^{-4} \cdot T_{KD}) \cdot (0.523 + 1.4 \cdot 10^{-3} \cdot T_{KD} - 1.48 \cdot 10^{-6} \cdot T_{KD}^2) \quad (4.8)$$

$$n_i = 2.5 \cdot 10^{25} \cdot r_T^{3/4} \cdot (T_{KD}/300)^{3/2} \cdot \exp\left(-\frac{E_g/q}{2 \cdot \phi_T}\right) \quad (4.9)$$

$$\phi_B^{cl} = \text{MAX}(\mathbf{DPHIB} + 2 \cdot \phi_T \cdot \ln[\mathbf{NEFF}/n_i], 0.05) \quad (4.10)$$

$$\epsilon_{ox} = \mathbf{EPSROX} \cdot \epsilon_0 \quad (4.11)$$

$$C_{ox} = \epsilon_{ox}/\mathbf{TOX} \quad (4.12)$$

$$\epsilon_{Si} = \epsilon_{r,Si} \cdot \epsilon_0 \quad (4.13)$$

$$\gamma_0 = \sqrt{2 \cdot q \cdot \epsilon_{Si} \cdot \mathbf{NEFF}}/C_{ox} \quad (4.14)$$

$$G_0^{cl} = \gamma_0/\sqrt{\phi_T} \quad (4.15)$$

Polysilicon depletion parameter

$$k_P = \begin{cases} \text{if } NP = 0 & \left\{ \begin{array}{l} k_P = 0 \end{array} \right. \\ \text{if } NP > 0 & \left\{ \begin{array}{l} NP_1 = \text{MAX}(NP, 8 \cdot 10^7 / \mathbf{TOX}^2) \\ NP_2 = \text{MAX}(NP_1, 5 \cdot 10^{24}) \\ k_P = 2 \cdot \phi_T \cdot C_{\text{ox}}^2 / (q \cdot \epsilon_{\text{Si}} \cdot NP_2) \end{array} \right. \end{cases} \quad (4.16)$$

Quantum-mechanical correction parameters

$$q_{\text{lim}} = 10 \cdot \phi_T \quad (4.17)$$

$$q_q = \begin{cases} 0.4 \cdot \mathbf{QMC} \cdot QM_N \cdot C_{\text{ox}}^{2/3} & \text{for NMOS} \\ 0.4 \cdot \mathbf{QMC} \cdot QM_P \cdot C_{\text{ox}}^{2/3} & \text{for PMOS} \end{cases} \quad (4.18)$$

$$q_{b0} = \gamma_0 \cdot \sqrt{\phi_B^{\text{cl}}} \quad (4.19)$$

$$\phi_B = \phi_B^{\text{cl}} + 0.75 \cdot q_q \cdot q_{b0}^{2/3} \quad (4.20)$$

$$\mathbf{G}_0 = G_0^{\text{cl}} \cdot \left(1 + q_q \cdot q_{b0}^{-1/3}\right) \quad (4.21)$$

 V_{SB} -clipping parameters

$$\phi_X = 0.95 \cdot \phi_B \quad (4.22)$$

$$a_\phi = 2.5 \cdot 10^{-3} \cdot \phi_B^2 \quad (4.23)$$

$$b_\phi = 2.5 \cdot 10^{-3} \cdot \phi_B^2 \quad (4.24)$$

$$\phi_X^* = 0.5 \cdot \sqrt{b_\phi} \quad (4.25)$$

$$\phi_X^* = \text{MINA}(\phi_X - \phi_X^*, 0, a_\phi) \quad (4.26)$$

Local process parameters in gate overlap regions

$$\gamma_{\text{ov}} = \sqrt{2 \cdot q \cdot \epsilon_{\text{Si}} \cdot \mathbf{NOV} \cdot \mathbf{TOXOV}} / \epsilon_{\text{ox}} \quad (4.27)$$

$$\gamma_{\text{dov}} = \sqrt{2 \cdot q \cdot \epsilon_{\text{Si}} \cdot \mathbf{NOVD} \cdot \mathbf{TOXOVD}} / \epsilon_{\text{ox}} \quad (4.28)$$

$$\mathbf{G}_{\text{ov}} = \gamma_{\text{ov}} / \sqrt{\phi_T} \quad (4.29)$$

$$\mathbf{G}_{\text{dov}} = \gamma_{\text{dov}} / \sqrt{\phi_T} \quad (4.30)$$

$$\xi_{\text{ov}} = 1 + \mathbf{G}_{\text{ov}} / \sqrt{2} \quad (4.31)$$

$$\xi_{\text{dov}} = 1 + \mathbf{G}_{\text{dov}} / \sqrt{2} \quad (4.32)$$

$$x_{\text{mrgov}} = 10^{-5} \cdot \xi_{\text{ov}} \quad (4.33)$$

$$x_{\text{mrgdov}} = 10^{-5} \cdot \xi_{\text{dov}} \quad (4.34)$$

Mobility parameters

$$\beta = \mathbf{FACTUO} \cdot \mathbf{BETN} \cdot C_{\text{ox}} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\mathbf{STBET}} \quad (4.35)$$

$$\theta_{\mu} = \mathbf{THEMU} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\mathbf{STTHEMU}} \quad (4.36)$$

$$\mu_{\text{E}} = \mathbf{MUE} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\mathbf{STMUE}} \quad (4.37)$$

$$X_{\text{cor}} = \mathbf{XCOR} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\mathbf{STXCOR}} \quad (4.38)$$

$$C_{\text{S}} = \mathbf{CS} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\mathbf{STCS}} \quad (4.39)$$

$$E_{\text{eff0}} = 10^{-8} \cdot C_{\text{ox}}/\epsilon_{\text{Si}} \quad (4.40)$$

$$\eta_{\mu} = \begin{cases} 1/2 \cdot \mathbf{FETA} & \text{for NMOS} \\ 1/3 \cdot \mathbf{FETA} & \text{for PMOS} \end{cases} \quad (4.41)$$

Series resistance parameter

$$R_{\text{s}} = \mathbf{RS} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\mathbf{STRS}} \quad (4.42)$$

$$\theta_{\text{R}} = 2 \cdot \beta \cdot R_{\text{s}} \quad (4.43)$$

Velocity saturation parameter

$$\theta_{\text{sat}} = \mathbf{THESAT} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\mathbf{STTHESAT}} \quad (4.44)$$

Impact-ionization parameter

$$a_2 = \mathbf{A2} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\mathbf{STA2}} \quad (4.45)$$

Gate current parameters

$$I_{\text{GINV}} = \mathbf{IGINV} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\mathbf{STIG}} \quad (4.46)$$

$$I_{\text{GOV}} = \mathbf{IGOV} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\mathbf{STIG}} \quad (4.47)$$

$$I_{\text{GOVD}} = \mathbf{IGOVD} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\mathbf{STIG}} \quad (4.48)$$

$$B = \frac{4}{3} \cdot \frac{\mathbf{TOX}}{\hbar} \cdot \sqrt{2 \cdot q \cdot m_0 \cdot \mathbf{CHIB}} = 6.830909 \cdot 10^9 \cdot \mathbf{TOX} \cdot \sqrt{\mathbf{CHIB}} \quad (4.49)$$

$$B_{\text{ov}} = B \cdot \mathbf{TOXOV}/\mathbf{TOX} \quad (4.50)$$

$$B_{\text{ovd}} = B \cdot \mathbf{TOXOVD}/\mathbf{TOX} \quad (4.51)$$

$$GC_{\text{Q}} = \begin{cases} -0.99 \cdot \frac{\mathbf{GC2}}{2 \cdot \mathbf{GC3}} & \text{for } \mathbf{GC3} < 0 \\ 0 & \text{for } \mathbf{GC3} \geq 0 \end{cases} \quad (4.52)$$

$$\alpha_{\text{b}} = \frac{E_{\text{g}}/q + \phi_{\text{B}}}{2} \quad (4.53)$$

$$D_{\text{ch}} = \mathbf{GCO} \cdot \phi_{\text{T}}^* \quad (4.54)$$

$$D_{\text{ov}} = \mathbf{GCO} \cdot \phi_{\text{T}} \quad (4.55)$$

Gate-induced drain leakage parameters

$$A_{\text{GIDL}} = \text{AGIDL} \cdot \left(\frac{2 \cdot 10^{-9}}{\text{TOXOV}} \right)^2 \quad (4.56)$$

$$A_{\text{GIDL D}} = \text{AGIDL D} \cdot \left(\frac{2 \cdot 10^{-9}}{\text{TOXOVD}} \right)^2 \quad (4.57)$$

$$B_{\text{GIDL}} = \text{BGIDL} \cdot \text{MAX}([1 + \text{STBGIDL} \cdot \Delta T], 0) \cdot \left(\frac{\text{TOXOV}}{2 \cdot 10^{-9}} \right) \quad (4.58)$$

$$B_{\text{GIDL D}} = \text{BGIDL D} \cdot \text{MAX}([1 + \text{STBGIDL D} \cdot \Delta T], 0) \cdot \left(\frac{\text{TOXOVD}}{2 \cdot 10^{-9}} \right) \quad (4.59)$$

Noise parameter

$$N_{\text{T}} = \text{FNT} \cdot 4 \cdot k_{\text{B}} \cdot T_{\text{KD}} \quad (4.60)$$

Additional internal parameters

$$x_1 = 1.25 \quad (4.61)$$

$$x_{\text{g1}} = x_1 + G_{\text{ov}} \cdot \sqrt{\exp(-x_1) + x_1 - 1} \quad (4.62)$$

$$x_{\text{dg1}} = x_1 + G_{\text{dov}} \cdot \sqrt{\exp(-x_1) + x_1 - 1} \quad (4.63)$$

4.2 Current Model

In this section, the model equations of the PSP-model are given. Use is made of the applied terminal bias values V_{GS} , V_{DS} and V_{SB} , the local parameters listed in Section 2.5.7 and the internal parameters introduced in Section 4.1. Local parameters are denoted by capital characters in bold font, whereas internal (bias-independent) parameters are denoted by symbols in bold font.

The definitions of the auxiliary functions $\text{MINA}(\cdot)$, $\text{MAXA}(\cdot)$, $\chi(\cdot)$ and $\sigma_{1,2}(\cdot)$ can be found in Appendix A.

4.2.1 Conditioning of Terminal Voltages

$$\phi_V = \text{MINA}(V_{SB}, V_{SB} + V_{DS}, \mathbf{b}_\phi) + \phi_X \quad (4.64)$$

$$V_{SB}^* = V_{SB} - \text{MINA}(\phi_V, 0, \mathbf{a}_\phi) + \phi_X^* \quad (4.65)$$

$$V_{DB}^* = V_{DS} + V_{SB}^* \quad (4.66)$$

$$V_{dsx} = \sqrt{V_{DS}^2 + 0.01} - 0.1 \quad (4.67)$$

$$V_{sbx} = V_{SB}^* + \frac{V_{DS} - V_{dsx}}{2} \quad (4.68)$$

Drain-induced barrier lowering:

$$\Delta V_G = \mathbf{CF} \cdot V_{dsx} \cdot (1 + \mathbf{CFB} \cdot V_{sbx}) \quad (4.69)$$

$$V_{GB}^* = V_{GS} + V_{SB}^* + \Delta V_G - V_{FB} \quad (4.70)$$

$$x_g = V_{GB}^* / \phi_T^* \quad (4.71)$$

4.2.2 Bias-Dependent Body Factor

$$D_{\text{nsb}} = \mathbf{DNSUB} \cdot \text{MAXA}(0, V_{GS} + V_{SB} - \mathbf{VNSUB}, \mathbf{NSLP}) \quad (4.72)$$

$$G = \mathbf{G}_0 \cdot \sqrt{1 + D_{\text{nsb}}} \quad (4.73)$$

4.2.3 Surface Potential at Source Side and Related Variables

$$\xi = 1 + G / \sqrt{2} \quad (4.74)$$

$$x_{\text{ns}} = \frac{\phi_B + V_{SB}^*}{\phi_T^*} \quad (4.75)$$

$$\Delta_{\text{ns}} = \exp(-x_{\text{ns}}) \quad (4.76)$$

$$x_{\text{mrg}} = 10^{-5} \cdot \xi \quad (4.77)$$

$$\text{if } x_g < -x_{\text{mrg}} \left\{ \begin{array}{l} y_g = -x_g \\ z = 1.25 \cdot y_g / \xi \\ \eta = [z + 10 - \sqrt{(z - 6)^2 + 64}] / 2 \\ a = (y_g - \eta)^2 + G^2 \cdot (\eta + 1) \\ c = 2 \cdot (y_g - \eta) - G^2 \\ \tau = -\eta + \ln(a/G^2) \\ y_0 = \sigma_1(a, c, \tau, \eta) \\ \Delta_0 = \exp(y_0) \\ p = 2 \cdot (y_g - y_0) + G^2 \cdot [\Delta_0 - 1 + \Delta_{\text{ns}} \cdot (1 - \chi'(y_0) - 1/\Delta_0)] \\ q = (y_g - y_0)^2 + G^2 \cdot [y_0 - \Delta_0 + 1 + \Delta_{\text{ns}} \cdot (1 + \chi(y_0) - 1/\Delta_0 - 2 \cdot y_0)] \\ x_s = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot \{2 - G^2 \cdot [\Delta_0 + \Delta_{\text{ns}} \cdot (1/\Delta_0 - \chi''(y_0))]\}}} \end{array} \right. \quad (4.78)$$

$$\text{if } |x_g| \leq x_{\text{mrg}} \left\{ \begin{array}{l} x_s = \frac{x_g}{\xi} \cdot \left[1 + G \cdot x_g \cdot \frac{1 - \Delta_{\text{ns}}}{\xi^2 \cdot 6 \cdot \sqrt{2}} \right] \end{array} \right. \quad (4.79)$$

$$\text{if } x_g > x_{\text{mrg}} \left\{ \begin{array}{l} \hat{x}_{g1} = \mathbf{x}_1 + G \cdot \sqrt{\exp(-\mathbf{x}_1) + \mathbf{x}_1 - 1} \\ \bar{x} = \frac{x_g}{\xi} \cdot [1 + x_g \cdot (\xi \cdot \mathbf{x}_1 - \hat{x}_{g1}) / \hat{x}_{g1}^2] \\ x_0 = x_g + G^2/2 - G \cdot \sqrt{x_g + G^2/4 - 1 + \exp(-\bar{x})} \\ b_x = x_{\text{ns}} + 3 \\ \eta = \text{MINA}(x_0, b_x, 5) - (b_x - \sqrt{b_x^2 + 5}) / 2 \\ a = (x_g - \eta)^2 - G^2 \cdot [\exp(-\eta) + \eta - 1 - \Delta_{\text{ns}} \cdot (\eta + 1 + \chi(\eta))] \\ b = 1 - G^2/2 \cdot [\exp(-\eta) - \Delta_{\text{ns}} \cdot \chi''(\eta)] \\ c = 2 \cdot (x_g - \eta) + G^2 \cdot [1 - \exp(-\eta) - \Delta_{\text{ns}} \cdot (1 + \chi'(\eta))] \\ \tau = x_{\text{ns}} - \eta + \ln(a/G^2) \\ y_0 = \sigma_2(a, b, c, \tau, \eta) \\ \Delta_0 = \exp(y_0) \\ p = 2 \cdot (x_g - y_0) + G^2 \cdot [1 - 1/\Delta_0 + \Delta_{\text{ns}} \cdot (\Delta_0 - 1 - \chi'(y_0))] \\ q = (x_g - y_0)^2 - G^2 \cdot [y_0 + 1/\Delta_0 - 1 + \Delta_{\text{ns}} \cdot (\Delta_0 - y_0 - 1 - \chi(y_0))] \\ x_s = y_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot \{2 - G^2 \cdot [1/\Delta_0 + \Delta_{\text{ns}} \cdot (\Delta_0 - \chi''(y_0))]\}}} \end{array} \right. \quad (4.80)$$

Eqs. (4.81)-(4.83) are only calculated for $x_g > 0$.

$$E_s = \exp(-x_s) \quad (4.81)$$

$$D_s = [1/E_s - x_s - 1 - \chi(x_s)] \cdot \Delta_{ns} \quad (4.82)$$

$$P_s = x_s - 1 + E_s \quad (4.83)$$

$$x_{gs} = \begin{cases} x_g - x_s & \text{for } x_g \leq 0 \\ G \cdot \sqrt{D_s + P_s} & \text{for } x_g > 0 \end{cases} \quad (4.84)$$

$$\psi_{ss} = \phi_{\mathbf{T}}^* \cdot x_s \quad (4.85)$$

4.2.4 Drain Saturation Voltage

Eqs. (4.86)-(4.106) are only calculated for $x_g > 0$.

$$q_{is} = \frac{G^2 \cdot \phi_{\mathbf{T}}^* \cdot D_s}{x_{gs} + G \cdot \sqrt{P_s}} \quad (4.86)$$

$$\alpha_s = 1 + \frac{G \cdot (1 - E_s)}{2 \cdot \sqrt{P_s}} \quad (4.87)$$

$$q_{bs} = \phi_{\mathbf{T}}^* \cdot G \cdot \sqrt{P_s} \quad (4.88)$$

$$\rho_b = \begin{cases} 1 + \mathbf{RSB} \cdot V_{s\text{bx}} & \text{for } \mathbf{RSB} \geq 0 \\ \frac{1}{1 - \mathbf{RSB} \cdot V_{s\text{bx}}} & \text{for } \mathbf{RSB} < 0 \end{cases} \quad (4.89)$$

$$\rho_{g,s} = \begin{cases} \frac{1}{1 + \mathbf{RSG} \cdot q_{is}} & \text{for } \mathbf{RSG} \geq 0 \\ 1 - \mathbf{RSG} \cdot q_{is} & \text{for } \mathbf{RSG} < 0 \end{cases} \quad (4.90)$$

$$\rho_s = \theta_{\mathbf{R}} \cdot \rho_b \cdot \rho_{g,s} \cdot q_{is} \quad (4.91)$$

$$\mu_x = \frac{1 + \mathbf{X}_{\text{cor}} \cdot V_{s\text{bx}}}{1 + 0.2 \cdot \mathbf{X}_{\text{cor}} \cdot V_{s\text{bx}}} \quad (4.92)$$

$$E_{\text{eff},s} = \mathbf{E}_{\text{eff}0} \cdot (q_{bs} + \eta_{\mu} \cdot q_{is}) \quad (4.93)$$

$$G_{\text{mob},s} = \frac{1 + (\mu_{\mathbf{E}} \cdot E_{\text{eff},s})^{\theta_{\mu}} + C_{\mathbf{S}} \cdot \left(\frac{q_{bs}}{q_{is} + q_{bs}} \right)^2 + \rho_s}{\mu_x} \quad (4.94)$$

$$\xi_{\text{tb}} = \begin{cases} 1 + \mathbf{THESATB} \cdot V_{s\text{bx}} & \text{for } \mathbf{THESATB} \geq 0 \\ \frac{1}{1 - \mathbf{THESATB} \cdot V_{s\text{bx}}} & \text{for } \mathbf{THESATB} < 0 \end{cases} \quad (4.95)$$

$$w_{\text{sat},s} = \frac{100 \cdot q_{is} \cdot \xi_{\text{tb}}}{100 + q_{is} \cdot \xi_{\text{tb}}} \quad (4.96)$$

$$\theta_{\text{sat},s}^* = \begin{cases} \frac{\theta_{\text{sat}}}{G_{\text{mob},s}} \cdot (1 + \mathbf{THESATG} \cdot w_{\text{sat},s}) & \text{for } \mathbf{THESATG} \geq 0 \\ \frac{\theta_{\text{sat}}}{G_{\text{mob},s}} \cdot \frac{1}{1 - \mathbf{THESATG} \cdot w_{\text{sat},s}} & \text{for } \mathbf{THESATG} < 0 \end{cases} \quad (4.97)$$

$$\phi_{\infty} = q_{\text{is}}/\alpha_s + \phi_{\mathbf{T}}^* \quad (4.98)$$

$$y_{\text{sat}} = \begin{cases} \theta_{\text{sat},s}^* \cdot \phi_{\infty}/\sqrt{2} & \text{for NMOS} \\ \frac{\theta_{\text{sat},s}^* \cdot \phi_{\infty}/\sqrt{2}}{\sqrt{1 + \theta_{\text{sat},s}^* \cdot \phi_{\infty}/\sqrt{2}}} & \text{for PMOS} \end{cases} \quad (4.99)$$

$$z_a = \frac{2}{1 + \sqrt{1 + 4 \cdot y_{\text{sat}}}} \quad (4.100)$$

$$\phi_0 = \phi_{\infty} \cdot z_a \cdot \left[1 + 0.86 \cdot z_a \cdot y_{\text{sat}} \cdot \frac{1 - z_a^2 \cdot y_{\text{sat}}}{1 + 4 \cdot z_a^3 \cdot y_{\text{sat}}^2} \right] \quad (4.101)$$

$$a_{\text{sat}} = x_{\text{gs}} + G^2/2 \quad (4.102)$$

$$\phi_2 = \frac{\phi_{\mathbf{T}}^* \cdot 0.98 \cdot G^2 \cdot D_s}{a_{\text{sat}} + \sqrt{a_{\text{sat}}^2 - 0.98 \cdot G^2 \cdot D_s}} \quad (4.103)$$

$$\phi_{\text{sat}} = \frac{2 \cdot \phi_0 \cdot \phi_2}{\phi_0 + \phi_2 + \sqrt{(\phi_0 + \phi_2)^2 - 3.96 \cdot \phi_0 \cdot \phi_2}} \quad (4.104)$$

$$V_{\text{dsat}} = \phi_{\text{sat}} - \phi_{\mathbf{T}}^* \cdot \ln \left[1 + \frac{\phi_{\text{sat}} \cdot (\phi_{\text{sat}} - 2 \cdot a_{\text{sat}} \cdot \phi_{\mathbf{T}}^*)}{G^2 \cdot D_s \cdot \phi_{\mathbf{T}}^{*2}} \right] \quad (4.105)$$

$$V_{\text{dse}} = \frac{V_{\text{DS}}}{\left[1 + (V_{\text{DS}}/V_{\text{dsat}})^{\mathbf{AX}} \right]^{1/\mathbf{AX}}} \quad (4.106)$$

4.2.5 Surface Potential at Drain Side and Related Variables

Eqs. (4.107)-(4.116) are only calculated for $x_g > 0$.

$$x_{\text{nd}} = \frac{\phi_{\mathbf{B}} + V_{\text{SB}}^* + V_{\text{dse}}}{\phi_{\mathbf{T}}^*} \quad (4.107)$$

$$k_{\text{ds}} = \exp\left(-V_{\text{dse}}/\phi_{\mathbf{T}}^*\right) \quad (4.108)$$

$$\Delta_{\text{nd}} = \Delta_{\text{ns}} \cdot k_{\text{ds}} \quad (4.109)$$

$$\text{if } x_g \leq x_{\text{mrg}} \left\{ x_{\text{d}} = \frac{x_g}{\xi} \cdot \left[1 + G \cdot x_g \cdot \frac{1 - \Delta_{\text{nd}}}{\xi^2 \cdot 6 \cdot \sqrt{2}} \right] \right. \quad (4.110)$$

$$\text{if } x_g > x_{\text{mrg}} \left\{ \begin{array}{l} b_x = x_{\text{nd}} + 3.0 \\ \eta = \text{MINA}(x_0, b_x, 5) - (b_x - \sqrt{b_x^2 + 5}) / 2 \\ a = (x_g - \eta)^2 - G^2 \cdot [\exp(-\eta) + \eta - 1 - \Delta_{\text{nd}} \cdot (\eta + 1 + \chi(\eta))] \\ b = 1 - G^2 / 2 \cdot [\exp(-\eta) - \Delta_{\text{nd}} \cdot \chi''(\eta)] \\ c = 2 \cdot (x_g - \eta) + G^2 \cdot [1 - \exp(-\eta) - \Delta_{\text{nd}} \cdot (1 + \chi'(\eta))] \\ \tau = x_{\text{nd}} - \eta + \ln(a/G^2) \\ y_0 = \sigma_2(a, b, c, \tau, \eta) \\ \Delta_0 = \exp(y_0) \\ p = 2 \cdot (x_g - y_0) + G^2 \cdot [1 - 1/\Delta_0 + \Delta_{\text{nd}} \cdot (\Delta_0 - 1 - \chi'(y_0))] \\ q = (x_g - y_0)^2 - G^2 \cdot [y_0 + 1/\Delta_0 - 1 + \Delta_{\text{nd}} \cdot (\Delta_0 - y_0 - 1 - \chi(y_0))] \\ x_d = y_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot \{2 - G^2 \cdot [1/\Delta_0 + \Delta_{\text{nd}} \cdot (\Delta_0 - \chi''(y_0))]\}}} \end{array} \right. \quad (4.111)$$

$$x_{\text{ds}} = x_d - x_s \quad (4.112)$$

$$\text{if } x_{\text{ds}} < 10^{-10} \left\{ \begin{array}{l} p = 2 \cdot x_{\text{gs}} + G^2 \cdot [1 - E_s + \Delta_{\text{nd}} \cdot (1/E_s - 1 - \chi'(x_s))] \\ q = G^2 \cdot (1 - k_{\text{ds}}) \cdot D_s \\ \xi = 1 - G^2 / 2 \cdot [E_s + \Delta_{\text{nd}} (1/E_s - \chi''(x_s))] \\ x_{\text{ds}} = \frac{2 \cdot q}{p + \sqrt{p^2 - 4 \cdot \xi \cdot q}} \\ x_d = x_s + x_{\text{ds}} \end{array} \right. \quad (4.113)$$

$$E_d = \exp(-x_d) \quad (4.114)$$

$$D_d = (1/E_d - x_d - 1 - \chi(x_d)) \cdot \Delta_{\text{nd}} \quad (4.115)$$

$$\Delta\psi = \phi_{\mathbf{T}}^* \cdot x_{\text{ds}} \quad (4.116)$$

$$\psi_{\text{sd}} = \phi_{\mathbf{T}}^* \cdot x_d \quad (4.117)$$

4.2.6 Mid-Point Surface Potential and Related Variables

$$\text{if } x_g > 0 \left\{ \begin{array}{l} x_m = (x_s + x_d) / 2 \\ E_m = \sqrt{E_s \cdot E_d} \\ \bar{D} = (D_s + D_d) / 2 \\ D_m = \bar{D} + x_{\text{ds}}^2 / 8 \cdot (E_m - 2/G^2) \\ P_m = x_m - 1 + E_m \\ x_{\text{gm}} = G \cdot \sqrt{D_m + P_m} \end{array} \right. \quad (4.118)$$

$$\text{if } x_g \leq 0 \begin{cases} x_m = x_s \\ x_{gm} = x_g - x_s \end{cases} \quad (4.119)$$

4.2.7 Polysilicon Depletion

Eqs. (4.120)-(4.134) are only calculated for $k_p > 0$ and $x_g > 0$ (otherwise $\eta_p = 1$):

$$x_m^{(0)} = x_m, \quad x_{ds}^{(0)} = x_{ds}, \quad D_m^{(0)} = D_m, \quad E_m^{(0)} = E_m, \quad (4.120)$$

$$d_0 = 1 - E_m^{(0)} + 2 \cdot x_{gm}/G^2 \quad (4.121)$$

$$\eta_p = 1/\sqrt{1 + k_p \cdot x_{gm}} \quad (4.122)$$

$$x_{pm} = k_p \cdot \left[\frac{\eta_p \cdot x_{gm}}{1 + \eta_p} \right]^2 \cdot \frac{D_m^{(0)}}{D_m^{(0)} + P_m} \quad (4.123)$$

$$p = 2 \cdot (x_{gm} - x_{pm}) + G^2 \cdot (1 - E_m^{(0)} + D_m^{(0)}) \quad (4.124)$$

$$q = x_{pm} \cdot (x_{pm} - 2 \cdot x_{gm}) \quad (4.125)$$

$$\xi_p = 1 - G^2/2 \cdot (E_m^{(0)} + D_m^{(0)}) \quad (4.126)$$

$$u_p = \frac{p \cdot q}{p^2 - \xi_p \cdot q} \quad (4.127)$$

$$x_m = x_m^{(0)} + u_p \quad (4.128)$$

$$E_m = E_m^{(0)} \cdot \exp(-u_p) \quad (4.129)$$

$$D_m = D_m^{(0)} \cdot \exp(u_p) \quad (4.130)$$

$$P_m = x_m - 1 + E_m \quad (4.131)$$

$$x_{gm} = G \cdot \sqrt{D_m + P_m} \quad (4.132)$$

$$x_{ds} = x_{ds}^{(0)} \cdot \frac{\exp(u_p) \cdot [\bar{D} + d_0]}{1 - E_m + 2 \cdot x_{gm} \cdot \eta_p/G^2 + \exp(u_p) \cdot \bar{D}} \quad (4.133)$$

$$\Delta\psi = \phi_T^* \cdot x_{ds} \quad (4.134)$$

4.2.8 Potential Mid-Point Inversion Charge and Related Variables

Eqs. (4.135)-(4.142) are only calculated for $x_g > 0$.

$$q_{im} = \frac{G^2 \cdot \phi_T^* \cdot D_m}{x_{gm} + G \cdot \sqrt{P_m}} \quad (4.135)$$

$$\alpha_m = \eta_p + \frac{G \cdot (1 - E_m)}{2 \cdot \sqrt{P_m}} \quad (4.136)$$

$$q_{im}^* = q_{im} + \phi_T^* \cdot \alpha_m \quad (4.137)$$

$$q_{bm} = \phi_T^* \cdot G \cdot \sqrt{P_m} \quad (4.138)$$

Series resistance:

$$\rho_g = \begin{cases} \frac{1}{1 + \mathbf{RSG} \cdot q_{im}} & \text{for } \mathbf{RSG} \geq 0 \\ 1 - \mathbf{RSG} \cdot q_{im} & \text{for } \mathbf{RSG} < 0 \end{cases} \quad (4.139)$$

$$\rho_s = \theta_R \cdot \rho_b \cdot \rho_g \cdot q_{im} \quad (4.140)$$

Mobility reduction:

$$E_{eff} = E_{eff0} \cdot (q_{bm} + \eta_\mu \cdot q_{im}) \quad (4.141)$$

$$G_{mob} = \frac{1 + (\mu_E \cdot E_{eff})^{\theta_\mu} + C_S \cdot \left(\frac{q_{bm}}{q_{im} + q_{bm}}\right)^2 + \rho}{\mu_x} \quad (4.142)$$

4.2.9 Drain-Source Channel Current

Eqs. (4.143)-(4.154) are only calculated for $x_g > 0$:

Channel length modulation:

$$R_1 = q_{im}/q_{im}^* \quad (4.143)$$

$$R_2 = \phi_T^* \cdot \alpha_m / q_{im}^* \quad (4.144)$$

$$T_1 = \ln \left(\frac{1 + \frac{V_{DS} - \Delta\psi}{\mathbf{VP}}}{1 + \frac{V_{dse} - \Delta\psi}{\mathbf{VP}}} \right) \quad (4.145)$$

$$T_2 = \ln \left(1 + \frac{V_{dsx}}{\mathbf{VP}} \right) \quad (4.146)$$

$$\Delta L/L = \mathbf{ALP} \cdot T_1 \quad (4.147)$$

$$G_{\Delta L} = \frac{1}{1 + \Delta L/L + (\Delta L/L)^2} \quad (4.148)$$

$$\Delta L_1/L = \left[\mathbf{ALP} + \frac{\mathbf{ALP1}}{q_{im}^*} \cdot R_1 \right] \cdot T_1 + \mathbf{ALP2} \cdot q_{bm} \cdot R_2^2 \cdot T_2 \quad (4.149)$$

$$F_{\Delta L} = [1 + \Delta L_1/L + (\Delta L_1/L)^2] \cdot G_{\Delta L} \quad (4.150)$$

Velocity saturation:

$$w_{\text{sat}} = \frac{100 \cdot q_{\text{im}} \cdot \xi_{\text{tb}}}{100 + q_{\text{im}} \cdot \xi_{\text{tb}}} \quad (4.151)$$

$$\theta_{\text{sat}}^* = \begin{cases} \frac{\theta_{\text{sat}}}{G_{\text{mob},s} \cdot G_{\Delta L}} \cdot (1 + \mathbf{THESATG} \cdot w_{\text{sat}}) & \text{for } \mathbf{THESATG} \geq 0 \\ \frac{\theta_{\text{sat}}}{G_{\text{mob},s} \cdot G_{\Delta L}} \cdot \frac{1}{1 - \mathbf{THESATG} \cdot w_{\text{sat}}} & \text{for } \mathbf{THESATG} < 0 \end{cases} \quad (4.152)$$

$$z_{\text{sat}} = \begin{cases} (\theta_{\text{sat}}^* \cdot \Delta\psi)^2 & \text{for NMOS} \\ \frac{(\theta_{\text{sat}}^* \cdot \Delta\psi)^2}{1 + \theta_{\text{sat}}^* \cdot \Delta\psi} & \text{for PMOS} \end{cases} \quad (4.153)$$

$$G_{\text{vsat}} = \frac{G_{\text{mob}} \cdot G_{\Delta L}}{2} \cdot (1 + \sqrt{1 + 2 \cdot z_{\text{sat}}}) \quad (4.154)$$

Drain-Source channel current:

$$I_{\text{DS}} = \begin{cases} 0 & \text{for } x_g \leq 0 \\ \beta \cdot F_{\Delta L} \cdot \frac{q_{\text{im}}^*}{G_{\text{vsat}}} \cdot \Delta\psi & \text{for } x_g > 0 \end{cases} \quad (4.155)$$

4.2.10 Auxiliary Variables for Calculation of Intrinsic Charges and Gate Current

Eqs. (4.156)-(4.158) are only calculated for $x_g > 0$.

$$V_{\text{oxm}} = \phi_{\text{T}}^* \cdot x_{\text{gm}} \quad (4.156)$$

$$\alpha_{\text{m}}' = \alpha_{\text{m}} \cdot \left[1 + \frac{z_{\text{sat}}}{2} \cdot \left(\frac{G_{\text{mob}} \cdot G_{\Delta L}}{G_{\text{vsat}}} \right)^2 \right] \quad (4.157)$$

$$H = \frac{G_{\text{mob}} \cdot G_{\Delta L}}{G_{\text{vsat}}} \cdot \frac{q_{\text{im}}^*}{\alpha_{\text{m}}'} \quad (4.158)$$

4.2.11 Impact Ionization or Weak-Avalanche

The equations in this Section are only calculated when $\mathbf{SWIMPACT} = 1$ and $x_g > 0$.

$$a_2^* = a_2 \cdot \left[1 + \mathbf{A4} \cdot \left(\sqrt{V_{\text{SB}}^* + \phi_{\text{B}}} - \sqrt{\phi_{\text{B}}} \right) \right] \quad (4.159)$$

$$\Delta V_{\text{sat}} = V_{\text{DS}} - \mathbf{A3} \cdot \Delta\psi \quad (4.160)$$

$$M_{\text{avl}} = \begin{cases} 0 & \text{for } \Delta V_{\text{sat}} \leq 0 \\ \mathbf{A1} \cdot \Delta V_{\text{sat}} \cdot \exp\left(-\frac{a_2^*}{\Delta V_{\text{sat}}}\right) & \text{for } \Delta V_{\text{sat}} > 0 \end{cases} \quad (4.161)$$

$$I_{\text{avl}} = M_{\text{avl}} \cdot I_{\text{DS}} \quad (4.162)$$

4.2.12 Surface Potential in Gate Overlap Regions

$$x_{\text{sov}}(x_g) = \begin{cases} \text{if } x_g < -x_{\text{mrgov}} \left\{ \begin{array}{l} y_g = -x_g \\ z = x_1 \cdot y_g / \xi_{\text{ov}} \\ \eta = \left[z + 10 - \sqrt{(z - 6)^2 + 64} \right] / 2 \\ a = (y_g - \eta)^2 + G_{\text{ov}}^2 \cdot (\eta + 1) \\ c = 2 \cdot (y_g - \eta) - G_{\text{ov}}^2 \\ \tau = -\eta + \ln(a / G_{\text{ov}}^2) \\ y_0 = \sigma_1(a, c, \tau, \eta) \\ \Delta_0 = \exp(y_0) \\ p = 2 \cdot (y_g - y_0) + G_{\text{ov}}^2 \cdot (\Delta_0 - 1) \\ q = (y_g - y_0)^2 + G_{\text{ov}}^2 \cdot (y_0 - \Delta_0 + 1) \\ x_{\text{sov}} = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot (2 - G_{\text{ov}}^2 \cdot \Delta_0)}} \end{array} \right. \\ \text{if } |x_g| < x_{\text{mrgov}} \left\{ x_{\text{sov}} = x_g / \xi_{\text{ov}} \right. \\ \text{if } x_g > x_{\text{mrgov}} \left\{ \begin{array}{l} \bar{x} = x_g / \xi_{\text{ov}} \cdot \left[1 + x_g \cdot (\xi_{\text{ov}} \cdot x_1 - x_{g1}) / x_{g1}^2 \right] \\ \omega = 1 - \exp(-\bar{x}) \\ x_0 = x_g + G_{\text{ov}}^2 / 2 - G_{\text{ov}} \cdot \sqrt{x_g + G_{\text{ov}}^2 / 4 - \omega} \\ \Delta_0 = \exp(-x_0) \\ p = 2 \cdot (x_g - x_0) + G_{\text{ov}}^2 \cdot (1 - \Delta_0) \\ q = (x_g - x_0)^2 - G_{\text{ov}}^2 \cdot (x_0 + \Delta_0 - 1) \\ x_{\text{sov}} = x_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot (2 - G_{\text{ov}}^2 \cdot \Delta_0)}} \end{array} \right. \end{cases} \quad (4.163)$$

$$x_{\text{dov}}(x_g) = \begin{cases} \text{if } x_g < -x_{\text{mrgdov}} \left\{ \begin{array}{l} y_g = -x_g \\ z = \mathbf{x}_1 \cdot y_g / \xi_{\text{dov}} \\ \eta = \left[z + 10 - \sqrt{(z - 6)^2 + 64} \right] / 2 \\ a = (y_g - \eta)^2 + \mathbf{G}_{\text{dov}}^2 \cdot (\eta + 1) \\ c = 2 \cdot (y_g - \eta) - \mathbf{G}_{\text{dov}}^2 \\ \tau = -\eta + \ln(a / \mathbf{G}_{\text{dov}}^2) \\ y_0 = \sigma_1(a, c, \tau, \eta) \\ \Delta_0 = \exp(y_0) \\ p = 2 \cdot (y_g - y_0) + \mathbf{G}_{\text{dov}}^2 \cdot (\Delta_0 - 1) \\ q = (y_g - y_0)^2 + \mathbf{G}_{\text{dov}}^2 \cdot (y_0 - \Delta_0 + 1) \\ x_{\text{dov}} = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot (2 - \mathbf{G}_{\text{dov}}^2 \cdot \Delta_0)}} \end{array} \right. \\ \text{if } |x_g| < x_{\text{mrgdov}} \left\{ x_{\text{dov}} = x_g / \xi_{\text{dov}} \right. \\ \text{if } x_g > x_{\text{mrgdov}} \left\{ \begin{array}{l} \bar{x} = x_g / \xi_{\text{dov}} \cdot \left[1 + x_g \cdot (\xi_{\text{dov}} \cdot \mathbf{x}_1 - x_{\text{dg1}}) / x_{\text{dg1}}^2 \right] \\ \omega = 1 - \exp(-\bar{x}) \\ x_0 = x_g + \mathbf{G}_{\text{dov}}^2 / 2 - \mathbf{G}_{\text{dov}} \cdot \sqrt{x_g + \mathbf{G}_{\text{dov}}^2 / 4 - \omega} \\ \Delta_0 = \exp(-x_0) \\ p = 2 \cdot (x_g - x_0) + \mathbf{G}_{\text{dov}}^2 \cdot (1 - \Delta_0) \\ q = (x_g - x_0)^2 - \mathbf{G}_{\text{dov}}^2 \cdot (x_0 + \Delta_0 - 1) \\ x_{\text{dov}} = x_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot (2 - \mathbf{G}_{\text{dov}}^2 \cdot \Delta_0)}} \end{array} \right. \end{cases} \quad (4.164)$$

$$\psi_{\text{sov}} = -\phi_{\mathbf{T}} \cdot x_{\text{sov}} \left(-\frac{V_{\text{GS}}}{\phi_{\mathbf{T}}} \right) \quad (4.165)$$

$$\psi_{\text{dov}} = -\phi_{\mathbf{T}} \cdot x_{\text{dov}} \left(-\frac{V_{\text{GS}} - V_{\text{DS}}}{\phi_{\mathbf{T}}} \right) \quad (4.166)$$

$$V_{\text{ov0}} = V_{\text{GS}} - \psi_{\text{sov}} \quad (4.167)$$

$$V_{\text{ovL}} = V_{\text{GS}} - V_{\text{DS}} - \psi_{\text{dov}} \quad (4.168)$$

4.2.13 Gate Current

The equations in this Section are only calculated when **SWIGATE** = 1.

Source/Drain gate overlap current:

$$I_{GSov}(V_{GX}, \psi_{ov}, V_{ov}) = \begin{cases} V_{ov}^* = \sqrt{V_{ov}^2 + 10^{-6}} \\ \psi_{tov} = \text{MINA}(0, V_{ov} + D_{ov}, 0.01) \\ z_g = \begin{cases} \text{MINA}\left(\frac{V_{ov}^*}{\mathbf{CHIB}}, \mathbf{GCQ}, 10^{-6}\right) & \text{for } \mathbf{GC3} < 0 \\ \frac{V_{ov}^*}{\mathbf{CHIB}} & \text{for } \mathbf{GC3} \geq 0 \end{cases} \\ \Delta_{Siov} = \exp\left(\frac{3.0 \cdot \phi_T + \psi_{ov} + \psi_{tov}}{\phi_T}\right) \\ F_{Sov} = \ln\left[\frac{1 + \Delta_{Siov}}{1 + \Delta_{Siov} \cdot \exp(-V_{GX}/\phi_T)}\right] \\ I_{Gov} = \mathbf{IGOV} \cdot F_{Sov} \cdot \\ \exp\left(\mathbf{Bov} \cdot \left[-\frac{3}{2} + z_g \cdot (\mathbf{GC2} + \mathbf{GC3} \cdot z_g)\right]\right) \end{cases} \quad (4.169)$$

$$I_{GDov}(V_{GX}, \psi_{ov}, V_{ov}) = \begin{cases} V_{ov}^* = \sqrt{V_{ov}^2 + 10^{-6}} \\ \psi_{tov} = \text{MINA}(0, V_{ov} + D_{ov}, 0.01) \\ z_g = \begin{cases} \text{MINA}\left(\frac{V_{ov}^*}{\mathbf{CHIB}}, \mathbf{GCQ}, 10^{-6}\right) & \text{for } \mathbf{GC3} < 0 \\ \frac{V_{ov}^*}{\mathbf{CHIB}} & \text{for } \mathbf{GC3} \geq 0 \end{cases} \\ \Delta_{Siov} = \exp\left(\frac{3.0 \cdot \phi_T + \psi_{ov} + \psi_{tov}}{\phi_T}\right) \\ F_{Sov} = \ln\left[\frac{1 + \Delta_{Siov}}{1 + \Delta_{Siov} \cdot \exp(-V_{GX}/\phi_T)}\right] \\ I_{Gov} = \mathbf{IGOVD} \cdot F_{Sov} \cdot \\ \exp\left(\mathbf{Bdov} \cdot \left[-\frac{3}{2} + z_g \cdot (\mathbf{GC2} + \mathbf{GC3} \cdot z_g)\right]\right) \end{cases} \quad (4.170)$$

$$I_{GSov} = I_{GSov}(V_{GS}, \psi_{sov}, V_{ov0}) \quad (4.171)$$

$$I_{GDov} = I_{GDov}(V_{GS} - V_{DS}, \psi_{dov}, V_{ovL}) \quad (4.172)$$

Gate-channel current:

$$V_m = V_{SB}^* + \phi_T^* \cdot \left[\frac{x_{ds}}{2} - \ln\left(\frac{1 + \exp(x_{ds} - V_{dse}/\phi_T^*)}{2}\right) \right] \quad (4.173)$$

$$\psi_t = \text{MINA}(0, V_{oxm} + D_{ch}, 0.01) \quad (4.174)$$

$$V_{oxm}^* = \sqrt{V_{oxm}^2 + 10^{-6}} \quad (4.175)$$

$$z_g = \begin{cases} \text{MINA} \left(\frac{V_{\text{oxm}}^*}{\text{CHIB}}, \text{GCQ}, 10^{-6} \right) & \text{for } \text{GC3} < 0 \\ \frac{V_{\text{oxm}}^*}{\text{CHIB}} & \text{for } \text{GC3} \geq 0 \end{cases} \quad (4.176)$$

$$\Delta_{\text{Si}} = \exp \left(x_m - \frac{\alpha_b + V_m - \psi_t}{\phi_T^*} \right) \quad (4.177)$$

$$F_S = \ln \left[\frac{1 + \Delta_{\text{Si}}}{1 + \Delta_{\text{Si}} \cdot \exp \left(-\frac{V_{\text{GS}} + V_{\text{SB}}^* - V_m}{\phi_T^*} \right)} \right] \quad (4.178)$$

$$I_{\text{GCO}} = I_{\text{GINV}} \cdot F_S \cdot \exp \left(B \cdot [-3/2 + z_g \cdot (\text{GC2} + \text{GC3} \cdot z_g)] \right) \quad (4.179)$$

$$\text{if } x_g > 0 \left\{ \begin{array}{l} u_0 = \text{CHIB} / [B \cdot (\text{GC2} + 2 \cdot \text{GC3} \cdot z_g)] \\ x = \Delta\psi / (2 \cdot u_0) \\ b = u_0 / H \\ B_g = b \cdot (1 - b) / 2 \\ A_g = 1/2 - 3 \cdot B_g \\ p_{\text{gc}} = (1 - b) \cdot \frac{\sinh(x)}{x} + b \cdot \cosh(x) \\ p_{\text{gd}} = \frac{p_{\text{gc}}}{2} - B_g \cdot \sinh(x) - A_g \cdot \frac{\sinh(x)}{x} \cdot \left[\coth(x) - \frac{1}{x} \right] \end{array} \right. \quad (4.180)$$

$$\text{if } x_g \leq 0 \left\{ \begin{array}{l} p_{\text{gc}} = 1 \\ p_{\text{gd}} = 1/2 \end{array} \right. \quad (4.181)$$

$$S_g = \frac{1}{2} \cdot \left(1 + \frac{x_g}{\sqrt{x_g^2 + 10^{-6}}} \right) \quad (4.182)$$

$$I_{\text{GC}} = I_{\text{GCO}} \cdot p_{\text{gc}} \cdot S_g \quad (4.183)$$

$$I_{\text{GCD}} = I_{\text{GCO}} \cdot p_{\text{gd}} \cdot S_g \quad (4.184)$$

$$I_{\text{GCS}} = I_{\text{GC}} - I_{\text{GCD}} \quad (4.185)$$

$$I_{\text{GB}} = I_{\text{GCO}} \cdot p_{\text{gc}} \cdot (1 - S_g) \quad (4.186)$$

4.2.14 Gate-Induced Drain/Source Leakage Current

The equations in this section are only calculated when **SWGIDL** = 1.

$$I_{\text{gisl}}(V_{\text{ov}}, V) = \begin{cases} V_{\text{tov}} = \sqrt{V_{\text{ov}}^2 + \mathbf{CGIDL}^2 \cdot V^2 + 10^{-6}} \\ t = V \cdot V_{\text{tov}} \cdot V_{\text{ov}} \\ I_{\text{gisl}} = \begin{cases} -\mathbf{AGIDL} \cdot t \cdot \exp\left(-\frac{\mathbf{BGIDL}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \geq 0 \end{cases} \end{cases} \quad (4.187)$$

$$I_{\text{gidl}}(V_{\text{ov}}, V) = \begin{cases} V_{\text{tov}} = \sqrt{V_{\text{ov}}^2 + \mathbf{CGIDL}^2 \cdot V^2 + 10^{-6}} \\ t = V \cdot V_{\text{tov}} \cdot V_{\text{ov}} \\ I_{\text{gidl}} = \begin{cases} -\mathbf{AGIDL} \cdot t \cdot \exp\left(-\frac{\mathbf{BGIDL}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \geq 0 \end{cases} \end{cases} \quad (4.188)$$

$$I_{\text{gisl}} = I_{\text{gisl}}(V_{\text{ov0}}, V_{\text{SB}}) \quad (4.189)$$

$$I_{\text{gidl}} = I_{\text{gidl}}(V_{\text{ovL}}, V_{\text{DS}} + V_{\text{SB}}) \quad (4.190)$$

4.2.15 Total Terminal Currents

$$I_{\text{D}} = I_{\text{DS}} + I_{\text{avl}} - I_{\text{GDov}} - I_{\text{GCD}} + I_{\text{gidl}} \quad (4.191)$$

$$I_{\text{S}} = -I_{\text{DS}} - I_{\text{GSov}} - I_{\text{GCS}} + I_{\text{gisl}} \quad (4.192)$$

$$I_{\text{G}} = I_{\text{GC}} + I_{\text{GB}} + I_{\text{GDov}} + I_{\text{GSov}} \quad (4.193)$$

$$I_{\text{B}} = -I_{\text{avl}} - I_{\text{GB}} - I_{\text{gidl}} - I_{\text{gisl}} \quad (4.194)$$

4.3 Charge Model

4.3.1 Quantum-Mechanical Corrections

$$q_{\text{eff}} = \begin{cases} V_{\text{oxm}} & \text{for } x_g \leq 0 \\ q_{\text{bm}} + \eta_{\mu} \cdot q_{\text{im}} & \text{for } x_g > 0 \end{cases} \quad (4.195)$$

$$C_{\text{OX}}^{\text{qm}} = \begin{cases} \text{COX} & \text{for } q_q = 0 \\ \frac{\text{COX}}{1 + q_q / (q_{\text{eff}}^2 + q_{\text{im}}^2)^{1/6}} & \text{for } q_q > 0 \end{cases} \quad (4.196)$$

4.3.2 Intrinsic Charge Model

$$\text{if } x_g > 0 \left\{ \begin{array}{l} F_j = \Delta\psi / (2 \cdot H) \\ q_{\Delta L} = (1 - G_{\Delta L}) \cdot (q_{\text{im}} - \alpha_m \cdot \Delta\psi / 2) \\ q_{\Delta L}^* = q_{\Delta L} \cdot (1 + G_{\Delta L}) \\ Q_G^{(i)} = C_{\text{OX}}^{\text{qm}} \cdot \left[V_{\text{oxm}} + \frac{\eta_p \cdot \Delta\psi}{2} \cdot \left(\frac{G_{\Delta L}}{3} \cdot F_j + G_{\Delta L} - 1 \right) \right] \\ Q_I^{(i)} = -C_{\text{OX}}^{\text{qm}} \cdot \left[G_{\Delta L} \cdot \left(q_{\text{im}} + \frac{\alpha_m \cdot \Delta\psi}{6} \cdot F_j \right) + q_{\Delta L} \right] \\ Q_D^{(i)} = -\frac{C_{\text{OX}}^{\text{qm}}}{2} \cdot \left[G_{\Delta L}^2 \cdot \left(q_{\text{im}} + \frac{\alpha_m \cdot \Delta\psi}{6} \cdot F_j \right) \cdot \left[\frac{F_j^2}{5} + F_j - 1 \right] \right] + q_{\Delta L}^* \end{array} \right. \quad (4.197)$$

$$\text{if } x_g \leq 0 \left\{ \begin{array}{l} Q_G^{(i)} = C_{\text{OX}}^{\text{qm}} \cdot V_{\text{oxm}} \\ Q_I^{(i)} = 0 \\ Q_D^{(i)} = 0 \end{array} \right. \quad (4.198)$$

$$Q_S^{(i)} = Q_I^{(i)} - Q_D^{(i)} \quad (4.199)$$

$$Q_B^{(i)} = -Q_I^{(i)} - Q_G^{(i)} \quad (4.200)$$

4.3.3 Extrinsic Charge Model

The charges of the source and drain overlap regions:

$$Q_{\text{sov}} = \text{CGOV} \cdot (V_{\text{GS}} - \psi_{\text{sov}}) \quad (4.201)$$

$$Q_{\text{dov}} = \text{CGOVD} \cdot (V_{\text{GS}} - V_{\text{DS}} - \psi_{\text{dov}}) \quad (4.202)$$

The charge of the bulk overlap region

$$Q_{\text{bov}} = \text{CGBOV} \cdot (V_{\text{GS}} + V_{\text{SB}}) \quad (4.203)$$

Outer fringe charge:

$$Q_{\text{ofs}} = \text{CFR} \cdot V_{\text{GS}} \quad (4.204)$$

$$Q_{\text{ofd}} = \text{CFRD} \cdot (V_{\text{GS}} - V_{\text{DS}}) \quad (4.205)$$

4.3.4 Total Terminal Charges

$$Q_G = Q_G^{(i)} + Q_{\text{sov}} + Q_{\text{dov}} + Q_{\text{ofs}} + Q_{\text{ofd}} + Q_{\text{bov}} \quad (4.206)$$

$$Q_S = Q_S^{(i)} - Q_{\text{sov}} - Q_{\text{ofs}} \quad (4.207)$$

$$Q_D = Q_D^{(i)} - Q_{\text{dov}} - Q_{\text{ofd}} \quad (4.208)$$

$$Q_B = Q_B^{(i)} - Q_{\text{bov}} \quad (4.209)$$

4.4 Noise Model

Eqs. (4.210)-(4.236) are only calculated for $x_g > 0$. In these equations f_{op} represents the operation frequency of the transistor and $j = \sqrt{-1}$.

4.4.1 Flicker noise

$$N^* = \frac{C_{ox}}{q} \cdot \alpha_m \cdot \phi_T \quad (4.210)$$

$$N_m^* = \frac{C_{ox}}{q} \cdot q_{im}^* \quad (4.211)$$

$$\Delta N = \frac{C_{ox}}{q} \cdot \alpha_m \cdot \Delta\psi \quad (4.212)$$

$$S_{fl} = \frac{q \cdot \phi_T^2 \cdot \beta \cdot I_{DS}}{f_{op}^{EF} \cdot C_{ox} \cdot G_{vsat} \cdot N^*} \cdot \left[(\mathbf{NFA} - \mathbf{NFB} \cdot N^* + \mathbf{NFC} \cdot N^{*2}) \cdot \ln \left(\frac{N_m^* + \Delta N/2}{N_m^* - \Delta N/2} \right) + (\mathbf{NFB} + \mathbf{NFC} \cdot [N_m^* - 2 \cdot N^*]) \cdot \Delta N \right] \quad (4.213)$$

4.4.2 Thermal noise

Intrinsic thermal noise

$$H_0 = \frac{q_{im}^*}{\alpha_m} \quad (4.214)$$

$$t_1 = \frac{q_{im}}{q_{im}^*} \quad (4.215)$$

$$t_2 = \left(\frac{\Delta\psi}{12 \cdot H_0} \right)^2 \quad (4.216)$$

$$R = \frac{H_0}{H} - 1 \quad (4.217)$$

$$l_c = 1 - 12 \cdot t_2 \cdot R \quad (4.218)$$

$$g_{ideal} = \frac{\beta \cdot q_{im}^*}{G_{vsat}} \cdot F_{\Delta L} \quad (4.219)$$

$$C_{Geff} = \left(\frac{G_{vsat}}{G_{mob} \cdot G_{\Delta L}} \right)^2 \cdot C_{OX}^{qm} \cdot \eta_p \quad (4.220)$$

$$m_{id,int} = \frac{g_{ideal}}{l_c^2} \cdot [t_1 + 12 \cdot t_2 - 24 \cdot (1 + t_1) \cdot t_2 \cdot R] \quad (4.221)$$

$$m_{ig,int} = \frac{1}{l_c^2 \cdot g_{ideal}} \cdot \left[\frac{t_1}{12} - t_2 \cdot \left(t_1 + \frac{1}{5} - 12 \cdot t_2 \right) - \frac{8}{5} \cdot t_2 \cdot (t_1 + 1 - 12 \cdot t_2) \cdot R \right] \quad (4.222)$$

$$m_{igid,int} = \frac{\sqrt{t_2}}{l_c^2} \cdot \left[1 - 12 \cdot t_2 - \left(t_1 + \frac{96}{5} \cdot t_2 - 12 \cdot t_1 \cdot t_2 \right) \cdot R \right] \quad (4.223)$$

Excess thermal noise

For short (sub-100-nm) devices, it has been shown that the conventional local source for thermal noise gets a field dependent extra term [7, 8] and changes from

$$\langle i_n^2 \rangle = 4 \cdot k \cdot T \cdot g$$

to

$$\langle i_n^2 \rangle = 4 \cdot k \cdot T \cdot g \cdot \left[1 + 3 \cdot \frac{(q \cdot E \cdot \tau)^2}{m^* \cdot k \cdot T} \right] = 4 \cdot k \cdot T \cdot g + 12 \cdot g \cdot m^* \cdot \mu^2 \cdot E^2.$$

Here, g denotes the local channel conductance. Integration along the channel (following the improved Klaassen-Prins method) leads to expressions for the drain-current noise, induced gate noise, and correlation.

Excess thermal noise equations:

$$\theta_{\text{sat,exc}}^* = \begin{cases} \frac{\theta_{\text{sat}}}{G_{\text{mob,dc}}} \cdot (1 + \mathbf{THESATG} \cdot w_{\text{sat}}) & \text{for } \mathbf{THESATG} \geq 0 \\ \frac{\theta_{\text{sat}}}{G_{\text{mob,dc}}} \cdot \frac{1}{1 - \mathbf{THESATG} \cdot w_{\text{sat}}} & \text{for } \mathbf{THESATG} < 0 \end{cases} \quad (4.224)$$

$$z_{\text{sat,exc}} = \begin{cases} (\theta_{\text{sat,exc}}^* \cdot \Delta\psi_{\text{dc}})^2 & \text{for NMOS} \\ \frac{(\theta_{\text{sat,exc}}^* \cdot \Delta\psi_{\text{dc}})^2}{1 + \theta_{\text{sat,exc}}^* \cdot \Delta\psi_{\text{dc}}} & \text{for PMOS} \end{cases} \quad (4.225)$$

$$G_{\text{vsat,exc}} = \frac{G_{\text{mob,dc}}}{2} \cdot (1 + \sqrt{1 + 2 \cdot z_{\text{sat,exc}}}) \quad (4.226)$$

$$g_{\text{fac}} = \frac{G_{\text{mob,dc}}}{G_{\text{vsat,exc}} \cdot l_c} \quad (4.227)$$

$$m_{\text{id,exc}} = \frac{\mathbf{FNTEXC} \cdot m_0}{4 \cdot k_B \cdot T_{\text{KD}}} \cdot g_{\text{fac}}^2 \cdot I_{\text{DS}} \cdot V_{\text{dse,dc}} \quad (4.228)$$

$$m_{\text{ig,exc}} = m_{\text{id,exc}} \cdot \frac{1 + 12 \cdot t_2}{12 \cdot g_{\text{ideal}}^2} \quad (4.229)$$

$$m_{\text{igid,exc}} = -m_{\text{id,exc}} \cdot \frac{\sqrt{t_2} \cdot (1 + R)}{g_{\text{ideal}}} \quad (4.230)$$

Total thermal noise

$$m_{\text{id}} = m_{\text{id,int}} + m_{\text{id,exc}} \quad (4.231)$$

$$m_{\text{ig}} = m_{\text{ig,int}} + m_{\text{ig,exc}} \quad (4.232)$$

$$m_{\text{igid}} = m_{\text{igid,int}} + m_{\text{igid,exc}} \quad (4.233)$$

$$S_{\text{id}} = N_{\text{T}} \cdot m_{\text{id}} \quad (4.234)$$

$$S_{\text{ig}} = N_{\text{T}} \cdot \frac{(2 \cdot \pi \cdot f_{\text{op}} \cdot C_{\text{Geff}})^2 \cdot m_{\text{ig}}}{1 + (2 \cdot \pi \cdot f_{\text{op}} \cdot C_{\text{Geff}} \cdot m_{\text{ig}})^2} \quad (4.235)$$

$$S_{\text{igid}} = N_{\text{T}} \cdot \frac{2 \cdot \pi \cdot j \cdot f_{\text{op}} \cdot C_{\text{Geff}} \cdot m_{\text{igid}}}{1 + 2 \cdot \pi \cdot j \cdot f_{\text{op}} \cdot C_{\text{Geff}} \cdot m_{\text{ig}}} \quad (4.236)$$

Thermal noise for parasitic resistances (see Fig. 3.2)

$$S_{R_G} = 4 \cdot k_B \cdot T_{KD} / R_{\text{gate}} \quad (4.237)$$

$$S_{R_{\text{BULK}}} = 4 \cdot k_B \cdot T_{KD} / R_{\text{bulk}} \quad (4.238)$$

$$S_{R_{\text{WELL}}} = 4 \cdot k_B \cdot T_{KD} / R_{\text{well}} \quad (4.239)$$

$$S_{R_{\text{JUNS}}} = 4 \cdot k_B \cdot T_{KD} / R_{\text{juns}} \quad (4.240)$$

$$S_{R_{\text{JUND}}} = 4 \cdot k_B \cdot T_{KD} / R_{\text{jund}} \quad (4.241)$$

4.4.3 Shot noise

Gate current shot noise:

$$S_{\text{igs}} = 2 \cdot q \cdot (I_{\text{GCS}} + I_{\text{GSov}}) \quad (4.242)$$

$$S_{\text{igd}} = 2 \cdot q \cdot (I_{\text{GCD}} + I_{\text{GDov}}) \quad (4.243)$$

Avalanche current shot noise:

$$S_{\text{avl}} = 2 \cdot q \cdot (1 + M_{\text{avl}}) \cdot I_{\text{avl}} \quad (4.244)$$

Section 5

Non-quasi-static RF model

5.1 Introduction

For high-frequency modeling and fast transient simulations, a special version of the PSP model is available, which enables the simulation of non-quasi-static (NQS) effects, and includes several parasitic resistances.

5.2 NQS-effects

In the PSP-NQS model, NQS-effects are introduced by applying the one-dimensional current continuity equation ($\partial I/\partial y \propto -\partial \rho/\partial t$) to the channel. A full numerical solution of this equation is too inefficient for compact modeling, therefore an approximate technique is used. The channel is partitioned into $N + 1$ sections of equal length by assigning N equidistant *collocation points*. The charge density (per unit channel area) along the channel is then approximated by a cubic spline through these collocation points, assuring that both the charge and its first and second spatial derivatives are continuous along the channel. Within this approximation, the current continuity equation reduces to a system of N coupled first order ordinary differential equations, from which the channel charge at each collocation point can be found:

$$\begin{cases} \frac{dQ_1}{dt} = f_1(Q_1, \dots, Q_N) \\ \vdots \\ \frac{dQ_N}{dt} = f_N(Q_1, \dots, Q_N) \end{cases} \quad (5.1)$$

Here, Q_i is the charge density at the i -th collocation point and f_i are functions, which contain the *complete* PSP-charge model. These equations are implemented by the definition of appropriate subcircuits (see left part of Fig. 5.1) and solved by the circuit simulator. Finally, the four terminal charges are calculated from the channel charges, using the Ward-Dutton partitioning scheme for the source and drain charges.

A full description of the PSP-NQS model is given in Section 5.3. More background information can be found in literature [9, 10].

5.3 NQS Model Equations

In this section, several symbols and notations are used which were defined in Section 4. Moreover, y denotes the (normalized) position along the channel ($y = 0$ is source side, $y = 1$ is drain side), while x denotes the surface potential (normalized to ϕ_T^*) at a certain position.

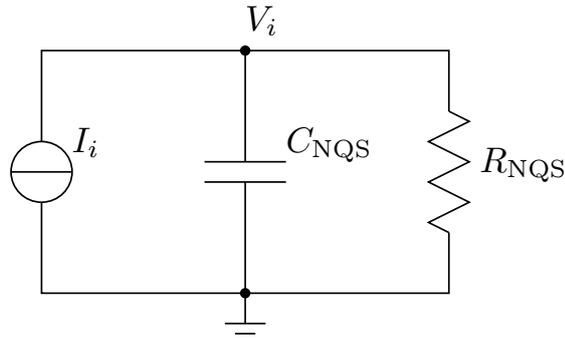


Figure 5.1: The subcircuit used to solve one of the differential equations of Eq. (5.1). The current is set to $I_i = C_{NQS} \cdot f(V_1, \dots, V_N)$, where the voltage V_i represents the charge density Q_i at the i -th collocation point and is solved by the circuit simulator. N of these circuits are defined and they are coupled through the dependence of I_i on the voltages of the other circuits. The resistance R_{NQS} has a very large value and is present only for convergence purposes. *Right:* The full network of parasitic elements in the PSP-NQS model. The large full dots indicate the five additional internal nodes.

5.3.1 Internal constants

Eqs. (5.2)–(5.7) are independent of bias conditions and time. Consequently, they have to be computed only once.

Note: In PSP only $SWNQS = 0, 1, 2, 3, 5, 9$ are allowed!

$$n = SWNQS + 1 \tag{5.2}$$

$$h = 1/n \tag{5.3}$$

The matrix A is a square $(n + 1) \times (n + 1)$ -matrix with elements $A_{i,j}$ ($0 \leq i, j \leq n$), which are used in Eq. 5.25. They are computed using the following algorithm (adapted from [11]):

1. Initial values:

$$A_{i,j} = 0 \quad \text{for } 0 \leq i, j \leq n \tag{5.4}$$

$$v_i = 0 \quad \text{for } 0 \leq i \leq n \tag{5.5}$$

2. First loop:

$$\left. \begin{aligned} p &= 2 + v_{i-1}/2 \\ v_i &= -1/(2 \cdot p) \\ A_{i,i-1} &= 1/h \\ A_{i,i} &= -2/h \\ A_{i,i+1} &= 1/h \\ A_{i,j} &= \frac{1}{p} \cdot (3 \cdot A_{i,j}/h - A_{i-1,j}/2) \end{aligned} \right\} \begin{array}{l} \text{for } i = 1 \dots (n - 1) \\ \text{for } j = 0 \dots n \end{array} \tag{5.6}$$

3. Second loop (back substitution):

$$A_{i,j} = v_i \cdot A_{i+1,j} + A_{i,j} \quad \text{for } j = 0 \dots n \quad \left. \vphantom{A_{i,j}} \right\} \text{for } i = (n-1) \dots 0 \quad (5.7)$$

5.3.2 Position independent quantities

The following quantities depend on the bias conditions, but are constant along the channel:

$$\text{if } x_g > 0 \quad \left\{ \begin{array}{l} y_m = \frac{1}{2} \cdot \left(1 + \frac{\Delta\psi}{4 \cdot H} \right) \\ p_d = \frac{x_{gm}}{x_g - x_m} \\ G_p = G/p_d \end{array} \right. \quad (5.8)$$

$$\text{if } x_g \leq 0 \quad \left\{ \begin{array}{l} y_m = 1/2 \\ p_d = 1 \\ G_p = G \end{array} \right. \quad (5.9)$$

$$a_p = 1 + G_p/\sqrt{2} \quad (5.10)$$

$$p_{mrg} = 10^{-5} \cdot a_p \quad (5.11)$$

5.3.3 Position dependent surface potential and charge

Interpolated (quasi-static) surface potential along the channel:

$$\Psi(y) = x_m + \frac{H}{\phi_T^*} \cdot \left(1 - \sqrt{1 - \frac{2 \cdot \Delta\psi}{H} \cdot (y - y_m)} \right) \quad (5.12)$$

Normalized bulk-charge and its first two derivatives as functions of surface potential:

$$q_b(x) = -\text{sgn}(x) \cdot G_p \cdot \sqrt{\exp(-x) + x - 1} \quad (5.13)$$

$$q_b'(x) = \frac{G_p^2 \cdot [1 - \exp(-x)]}{2 \cdot q_b(x)} \quad (5.14)$$

$$q_b''(x) = -q_b'(x) - \frac{q_b'(x)^2 - G_p^2/2}{q_b(x)} \quad (5.15)$$

Surface potential as a function of normalized inversion charge (note that these equations are identical to Eq. (4.163), despite the different notation and physical background):

$$\Pi(x_g) = \left\{ \begin{array}{l} \text{if } x_g < -p_{\text{mrg}} \\ \text{if } |x_g| \leq p_{\text{mrg}} \\ \text{if } x_g > p_{\text{mrg}} \end{array} \right\} \left\{ \begin{array}{l} y_g = -x_g \\ z = 1.25 \cdot y_g / a_p \\ \eta = \left[z + 10 - \sqrt{(z - 6)^2 + 64} \right] / 2 \\ a = (y_g - \eta)^2 + G_p^2 \cdot (\eta + 1) \\ c = 2 \cdot (y_g - \eta) - G_p^2 \\ \tau = -\eta + \ln(a / G_p^2) \\ y_0 = \sigma_1(a, c, \tau, \eta) \\ \Delta_0 = \exp(y_0) \\ \xi = 1 - G_p^2 \cdot \Delta_0 / 2 \\ p = 2 \cdot (y_g - y_0) + G_p^2 \cdot (\Delta_0 - 1) \\ q = (y_g - y_0)^2 + G_p^2 \cdot (y_0 - \Delta_0 + 1) \\ \Pi = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 4 \cdot q \cdot \xi}} \\ \Pi = \frac{x_g}{a_p} \\ \hat{x}_{g1} = x_1 + G \cdot \sqrt{\exp(-x_1) + x_1 - 1} \\ \bar{x} = \frac{x_g}{a_p} \cdot [1 + x_g \cdot (x_1 \cdot a_p / \hat{x}_{g1} - 1) / \hat{x}_{g1}] \\ x_0 = x_g + G_p^2 / 2 - G_p \cdot \sqrt{x_g + G_p^2 / 4 - 1 + \exp(-\bar{x})} \\ \Delta_0 = \exp(-x_0) \\ \xi = 1 - G_p^2 \cdot \Delta_0 / 2 \\ p = 2 \cdot (x_g - x_0) + G_p^2 \cdot (1 - \Delta_0) \\ q = (x_g - x_0)^2 - G_p^2 \cdot (x_0 + \Delta_0 - 1) \\ \Pi = x_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 4 \cdot q \cdot \xi}} \end{array} \right. \quad (5.16)$$

$$X(x_g, q_{\text{inv}}) = \Pi(x_g + q_{\text{inv}} / p_d) \quad (5.17)$$

Auxiliary functions:

$$q(x) = -p_d \cdot (x_g - x) - q_b(x) \quad (5.18)$$

$$\psi(q, q_{x1}) = \frac{q}{q_{x1}} - 1 \quad (5.19)$$

$$\phi(q, q_{x1}, q_{x2}) = \left(1 - \frac{q \cdot q_{x2}}{q_{x1}^2} \right) / q_{x1} \quad (5.20)$$

Normalized right-hand-side of continuity equation:

$$f(x_g, q, q', q'') = \begin{cases} x_z = X(x_g, q) \\ q_{x1} = \frac{\partial q}{\partial x}(x_z) = p_d - q'_b(x_z) \\ q_{x2} = \frac{\partial^2 q}{\partial x^2}(x_z) = q''_b(x_z) \\ f_0 = \psi(q, q_{x1}) \cdot q'' + \phi(q, q_{x1}, q_{x2}) \cdot q'^2 \\ x_{y1} = \frac{\partial x_z}{\partial y} = q'/q_{x1} \\ z_{\text{sat}} = \begin{cases} \left(\theta_{\text{sat}}^* \cdot \phi_{\mathbf{T}}^* \cdot x_{y1} \right)^2 & \text{for NMOS} \\ \frac{\left(\theta_{\text{sat}}^* \cdot \phi_{\mathbf{T}}^* \cdot x_{y1} \right)^2}{1 + \theta_{\text{sat}}^* \cdot \Delta\psi} & \text{for PMOS} \end{cases} \\ \zeta = \sqrt{1 + 2 \cdot z_{\text{sat}}} \\ F_{\text{vsat}} = 2/(1 + \zeta) \\ f = F_{\text{vsat}} \cdot \left[f_0 - F_{\text{vsat}} \cdot \frac{z_{\text{sat}}}{\zeta} \cdot \psi(q, q_{x1}) \cdot (q'' + x_{y1}^2 \cdot q''_b(x_z)) \right] \end{cases} \quad (5.21)$$

Normalization constant:

$$T_{\text{norm}} = \frac{\mathbf{MUNQS} \cdot \phi_{\mathbf{T}}^* \cdot \beta}{C_{\text{OX}}^{\text{qm}} \cdot G_{\text{mob}} \cdot G_{\Delta L}} \quad (5.22)$$

5.3.4 Cubic spline interpolation

Using cubic spline interpolation, the spatial derivatives $\frac{\partial q_i}{\partial y}(t)$ and $\frac{\partial^2 q_i}{\partial y^2}(t)$ can be expressed as functions of the $q_i(t)$.

$$q''_0 = 0 \quad (5.23)$$

$$q''_n = 0 \quad (5.24)$$

$$q''_i = \sum_{j=0}^n A_{i,j} \cdot q_i \quad \text{for } 1 \leq i \leq n-1 \quad (5.25)$$

$$q'_i = \frac{q_{i+1} - q_i}{h} - \frac{h}{6} \cdot (2 \cdot q''_i + q''_{i+1}) \quad \text{for } 1 \leq i \leq n-1 \quad (5.26)$$

5.3.5 Continuity equation

Initial value for the q_i ($0 \leq i \leq n$). These values are used for the DC operating point.

$$x_{i,0} = \Psi(i \cdot h) \quad (5.27)$$

$$q_{i,0} = q(x_{i,0}) \quad (5.28)$$

Note: $x_{0,0} = x_s$ and $x_{n,0} = x_d$. Moreover, these values coincide with those in the quasi-static part of PSP.

The core of the NQS-model is the solution of $q(y, t)$ from the charge continuity equation along the channel. By approximating the y -dependence by a cubic spline through a number of collocation points, the problem is reduced to solving the $q_i(t)$ from the following set of coupled differential equations.

$$\left\{ \begin{array}{l} \frac{\partial q_i}{\partial t}(t) + T_{\text{norm}} \cdot f\left(x_g, q_i(t), \frac{\partial q_i}{\partial y}(t), \frac{\partial^2 q_i}{\partial y^2}(t)\right) = 0 \\ q_i(0) = q_{i,0} \end{array} \right. \quad \text{for } 1 \leq i \leq n-1 \quad (5.29)$$

Note that the boundary points $q_0(t) = q(x_s) = q_{is}$ and $q_n(t) = q(x_d) = q_{id}$ remain fixed to their quasi-static values; they are not solved from the equation above.

The set of differential equations defined above is solved by the circuit simulator via the subcircuits shown in the left part of Fig. 5.1.

5.3.6 Non-quasi-static terminal charges

Once the q_i are known, the NQS terminal charges can be computed:

$$S_0 = \sum_{i=1}^{n-1} q_i \quad (5.30)$$

$$S_2 = \sum_{i=1}^{n-1} q_i'' \quad (5.31)$$

$$q_I^{\text{NQS}} = \int_0^1 q(y) dy = h \cdot S_0 + \frac{h}{2} \cdot (u_0 + u_n) - \frac{h^3}{12} \cdot S_2 \quad (5.32)$$

$$U_0 = \sum_{i=1}^{n-1} i \cdot q_i \quad (5.33)$$

$$U_2 = \sum_{i=1}^{n-1} i \cdot q_i'' \quad (5.34)$$

$$q_D^{\text{NQS}} = \int_0^1 y \cdot q(y) dy = h^2 \cdot U_0 + \frac{h^2}{6} \cdot [q_0 + (3n-1)u_n] - \frac{h^4}{12} \cdot U_2 \quad (5.35)$$

$$q_S^{\text{NQS}} = q_I^{\text{NQS}} - q_D^{\text{NQS}} \quad (5.36)$$

Currently, only **SWNQS** = 0, 1, 2, 3, 5, 9 are allowed. For odd values of **SWNQS** the gate charge is integrated along the channel using ‘‘Simpson’s rule’’. If **SWNQS** = 2, ‘‘Simpson’s 3/8-rule’’ is used.

- If **SWNQS** is odd (that is, n is even):

$$q_G^{\text{NQS}} = p_d \cdot \left[x_g - \frac{h}{3} \cdot \left(X(x_g, q_0) + 4 \cdot \sum_{i=1}^{n/2} X(x_g, q_{2i-1}) + 2 \cdot \sum_{i=1}^{n/2-1} X(x_g, q_{2i}) + X(x_g, q_n) \right) \right] \quad (5.37)$$

- If **SWNQS** = 2 (that is, $n = 3$):

$$q_G^{\text{NQS}} = p_d \cdot \left[x_g - \frac{3 \cdot h}{8} \cdot (X(x_g, q_0) + 3 \cdot X(x_g, q_1) + 3 \cdot X(x_g, q_2) + X(x_g, q_3)) \right] \quad (5.38)$$

Convert back to conventional units:

$$Q_S^{\text{NQS}} = C_{\text{OX}}^{\text{qm}} \cdot \phi_{\text{T}}^* \cdot q_S^{\text{NQS}} \quad (5.39)$$

$$Q_D^{\text{NQS}} = C_{\text{OX}}^{\text{qm}} \cdot \phi_{\text{T}}^* \cdot q_D^{\text{NQS}} \quad (5.40)$$

$$Q_G^{\text{NQS}} = C_{\text{OX}}^{\text{qm}} \cdot \phi_{\text{T}}^* \cdot q_G^{\text{NQS}} \quad (5.41)$$

$$Q_B^{\text{NQS}} = -(Q_S^{\text{NQS}} + Q_D^{\text{NQS}} + Q_G^{\text{NQS}}) \quad (5.42)$$

Section 6

Embedding

6.1 Model selection

Circuit simulators have different ways for the user to determine which model must be used for simulation. Typically, model selection is either done by *name* or by assigning a value to the parameter **LEVEL**. The method to be used is prescribed by the circuit simulator vendor. If selection is done by name, the value of the parameter **LEVEL** is generally ignored. When Verilog-A code is used, model selection is always done by name.

For the SiMKit and the Verilog-A code provided by the PSP model developers, the method and values to be used are given in the table below. For other implementations, the method/value provided by the circuit simulator vendor is to be used.

Simulator	Model selection by	Global (geom.)	Global (binning)	Local
Spectre	name	psp1020	psp1021	psp102e
Pstar	LEVEL	1020	1021	102
ADS	name	psp1020	psp1021	psp102e
Verilog-A	name	PSP102VA	PSP102BVA	PSP102EVA

6.2 Case of parameters

Throughout this document, all parameter names are printed in uppercase characters. Similarly, in the Verilog-A code provided by the PSP model developers, the parameters are in upper case characters. However, in other PSP implementations a different choice can be made. For example, the parameter names may be in lowercase characters (possibly first character capitalized) if this is conform the conventions of the circuit simulator.

6.3 Embedding PSP in a Circuit Simulator

In CMOS technologies both *n*- and *p*-channel MOS transistors are supported. It is convenient to use the same set of equations for both types of transistor instead of two separate models. This is accomplished by mapping a *p*-channel device with its bias conditions and parameter set onto an equivalent *n*-channel device with appropriately changed bias conditions (i.e. currents, voltages and charges) and parameters. In this way both types of transistor can be treated internally as an *n*-channel transistor. Nevertheless, the electrical behavior of electrons and holes is not exactly the same (e.g., the mobility and tunneling behavior), and consequently slightly different equations have to be used in case of *n*- or *p*-type transistors.

Designers are used to the standard terminology of source, drain, gate and bulk. Therefore, in the context of a circuit simulator it is traditionally possible to address, say, the drain of MOST number 17, even if in reality the corresponding source is at a higher potential (*n*-channel case). More strongly, most circuit simulators provide for model evaluation values for V_{DS} , V_{GS} , and V_{SB} based on an a priori assignment of source, drain, and bulk, independent of the actual bias conditions. Since PSP assumes that saturation occurs at the drain side of the MOSFET, the basic model cannot cope with bias conditions that correspond to $V_{DS} < 0$. Again a transformation of the bias conditions is necessary. In this case, the transformation corresponds to internally reassigning source and drain, applying the standard electrical model, and then reassigning the currents and charges to the original terminals. In PSP care has been taken to preserve symmetry with respect to drain and source at $V_{DS} = 0$. In other words, no singularities will occur in the higher-order derivatives at $V_{DS} = 0$.

In detail, for correct embedding of PSP into a circuit simulator, the following procedure—illustrated in Fig. 6.1—is followed. It is assumed that the simulator provides the nodal potentials V_D^e , V_G^e , V_S^e and V_B^e based on an a priori assignment of drain, gate, source and bulk.

Step 1 The voltages V'_{DS} , V'_{GS} , and V'_{SB} are calculated from the nodal potentials provided by the circuit simulator. In the same step, the value of the parameter **TYPE** is used to deal with the polarity of the device. From here onwards, all transistors can be treated as *n*-channel devices.

Step 2 Depending on the sign of V'_{DS} , ‘source-drain interchange’ is performed. At this level, the voltages comply to all the requirements for input quantities of PSP.

Step 3 All the internal output quantities (i.e. channel current, weak-avalanche current, gate current, nodal charges, and noise-power spectral densities) are evaluated using the standard PSP equations (Section 4) and the internal voltages.

Step 4 The internal output quantities are corrected for a possible source-drain interchange.

Step 5 External output are corrected for a possible *p*-channel transformation and **MULT** is applied. The quantities of the intrinsic MOSFET and the junctions are combined.

In general, separate parameter sets are used for *n*- and *p*-channel transistors, which are distinguished by the value of **TYPE**. As a consequence, the changes in the parameter values necessary for a *p*-channel type transistor are normally already included in the parameter sets on file. The changes should therefore not be included in the simulator.

6.3.1 Selection of device type

In the SiMKit-based and built-in version of PSP in certain circuit simulators, the selection of device type (nmos or pmos) is done using a different parameter, or using different parameter values. The correct values for some circuit simulators are given in the table below.

Simulator	Parameter	Value NMOS	value PMOS
Spectre	type	n	p
Pstar	type	1	-1
ADS	gender	1	0
Verilog-A	TYPE	1	-1

6.4 Integration of JUNCAP2 in PSP

Introduction

The JUNCAP2 model 200.3 is an integral part of PSP 102.2. In addition, it is available as a stand-alone model. A complete description of the JUNCAP2-model (including all model equations) can be found in the

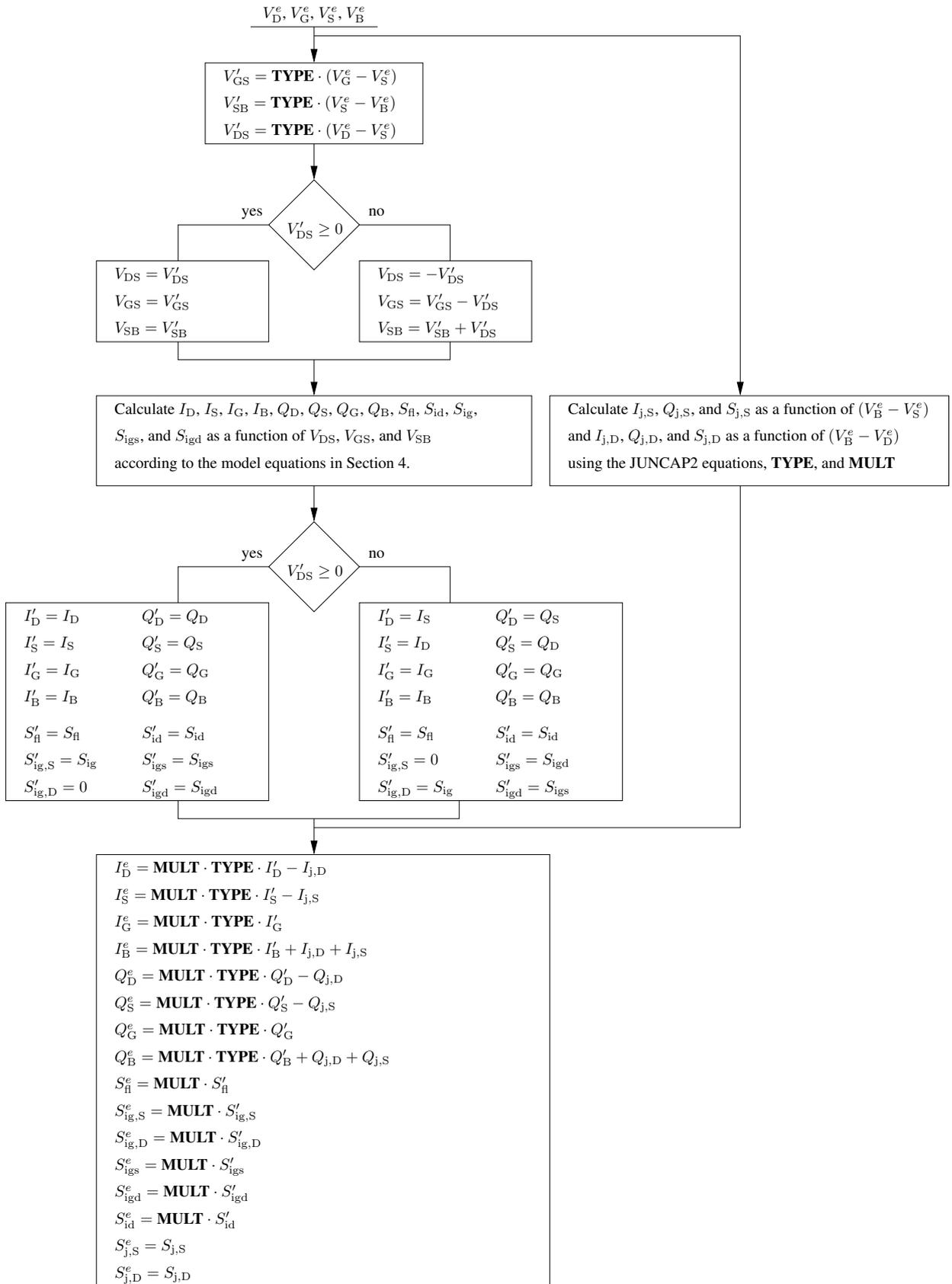


Figure 6.1: Schematic overview of source-drain interchange and handling of **TYPE** and **MULT**. Note that **TYPE** and **MULT** are included in the JUNCAP2 model equations.

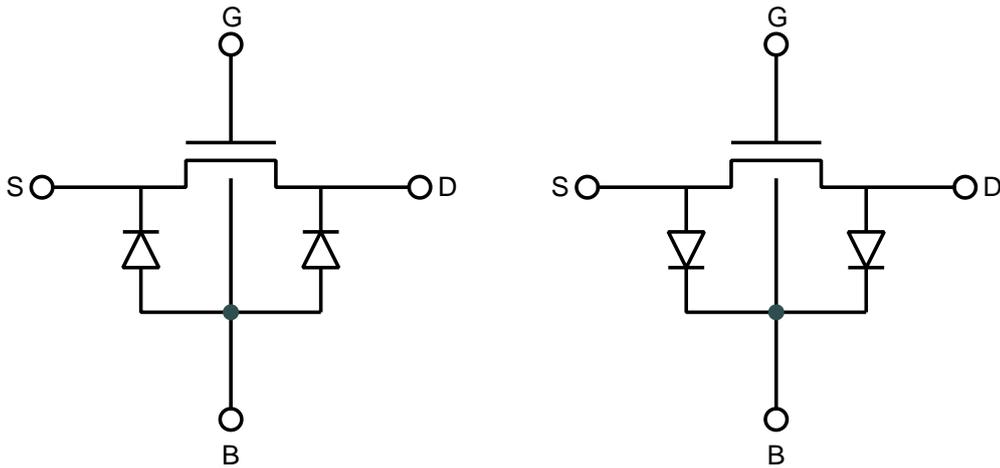


Figure 6.2: Topology of the PSP model. *Left*: *n*-channel MOSFET; *Right*: *p*-channel MOSFET. In PSP, the correct diode polarity is automatically chosen via the **TYPE**-parameter.

documentation of JUNCAP2's stand alone version [12]. In this section, only the integration of JUNCAP2 in PSP is described.

Topology

In a MOS transistor, there are two junctions: one between source and bulk, and one between drain and bulk. In case of an *n*-channel MOSFET, the junction anode corresponds to the MOSFET bulk terminal, and the junction cathodes correspond to the source and the drain. In case of a *p*-channel MOSFET, it is the other way around: now the junction cathode corresponds to the MOSFET bulk terminal, and the junction anodes correspond to the source and the drain. The connections are schematically given in Fig. 6.2. In PSP, this change of junction terminal connections in case of a *p*-MOSFET is handled automatically via the **TYPE** parameter.

In most cases, the MOSFET is operated in such a way that the junctions are either reverse biased in the reverse mode of operation or not biased at all. In some applications, however, the source-bulk junction has a small forward bias. This is also the case in partially depleted SOI (PDSOI).

As indicated in Fig. 6.1, the interchange of source and drain for $V_{DS} < 0$ (as explained above for the intrinsic MOS model) does *not* apply to the junctions. For example, **ABDRAIN** always refers to junction between the bulk and the terminal known as 'drain' to the simulator, independent of the sign of V_{DS} .

Global and local model level

As explained in the introduction, the PSP model has a local and a global level. The JUNCAP2 model is a geometrically scaled model, i.e. it is valid for a range of junction geometries (as described by the geometrical parameters **AB**, **LS**, and **LG**). It has turned out that it is very unnatural to create a local parameter set for JUNCAP2, valid for one particular junction geometry: such a parameter set would have as many parameters as the global parameter set, and would be of no use. (Note that, in contrast, the local model for the intrinsic MOSFET is very useful in, e.g., parameter extraction; this is not the case for JUNCAP2.)

Therefore, the JUNCAP2 model is connected in exactly the same way to both the local and global model levels of PSP. That means that the resulting PSP local model is valid for a MOSFET with one particular channel width and length, but with arbitrary junction geometry.

Parameters

Both junctions in the MOSFET are modeled with the same set of JUNCAP2 parameters. In the PSP model, the geometrical parameters **AB**, **LS**, and **LG** need to be specified for both source and drain. They will be denoted as **ABSOURCE**, **LSSOURCE**, and **LGSOURCE** for the source junction, and **ABDRAIN**, **LSDRAIN**, and **LGDRAIN** for the drain junction. For compatibility with BSIM instance parameters, there is also an option to use **AS**, **AD**, **PS**, and **PD**. The complete list of instance parameters (PSP and JUNCAP2) can be found in Sections 2.5.1 and 2.5.2.

The parameter **MULT** is merged with the parameter **MULT** of the intrinsic MOSFET model. In other words, both intrinsic currents, charges, and noise as well as junction currents, charges and noise are multiplied by one single parameter **MULT**. Beside **MULT**, also the parameters **DTA** and **TYPE** are shared by the intrinsic MOSFET model and the junction model. For clarity, we mention here that the reference temperatures of the intrinsic MOSFET model and junction model are *not* merged; they each have their own value and name (**TR** and **TRJ**, respectively). The currents, charges and spectral noise densities of the source and drain junctions are labeled $I_{j,S}$, $Q_{j,S}$, $S_{j,S}$, $I_{j,D}$, $Q_{j,D}$, and $S_{j,D}$ in Fig. 6.1.

6.5 Verilog-A versus C

As mentioned in Section 1.3, two implementations of the PSP-model are distributed: in Verilog-A language and in C-language (as part of the SiMKit). The C-version is automatically generated from the Verilog-A version by a software package called ADMS [1]. This procedure guarantees that the two implementations contain identical model equations.

Nevertheless, there are a few minor differences between the two, which are due to certain limitations of either the Verilog-A language or the circuit simulators supported in the SiMKit-framework. These differences are described below.

6.5.1 Implementation of GMIN

In both implementations, there is an additional term in Eqs. (4.191) and (4.192), resulting in

$$I_D = I_{DS} + I_{avl} - I_{GDov} - I_{GCD} + I_{gidl} + G_{min} \cdot V_{DS} \quad (6.1)$$

and

$$I_S = -I_{DS} - I_{GSov} - I_{GCS} + I_{gisl} - G_{min} \cdot V_{DS}. \quad (6.2)$$

In the SiMKit, G_{min} is a variable which is accessible by the circuit simulator. This allows the circuit simulator to improve the convergence properties of a circuit by making use of so-called ‘ G_{min} -stepping’.

In the Verilog-A version of PSP, G_{min} is set to a fixed value $G_{min} = 1 \cdot 10^{-15} \text{ S}$.¹

6.5.2 Implementation of parasitic resistances

From PSP 102.2 onwards, a network of parasitic resistors has been inserted around the intrinsic MOSFET. If the user sets one or more of these resistance values to zero, the associated internal node(s) could be shorted to one of its neighbors, reducing the size of the matrix in the circuit simulator. This phenomenon is called ‘node collapse’ and is supported by most major circuit simulators.

Flexible topology (and thus node collapse) is presently supported by most Verilog-A compilers. As a result, node collapse is functional in the official PSP Verilog-A in the majority of today’s circuit simulators.

¹If supported by the circuit simulator, Verilog-A version 2.2 allows the value of G_{min} to be accessed by the circuit simulator. Once this feature is generally available in Verilog-A compilers, it will be included in PSP as well.

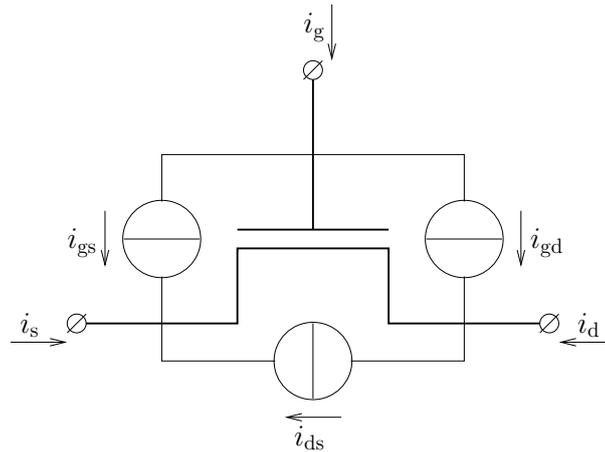


Figure 6.3: Definition of noise currents.

From SiMKit 3.0 onwards, the SiMKit architecture allows for flexible topologies and therefore supports node collapse in PSP. This functionality is therefore available in circuit simulations with that can work with SiMKit. Besides, many circuit simulators that have a native implementation of PSP support node collapse.

6.5.3 Implementation of the noise-equations

Definition of noise model

Eqs. (4.234), (4.235), and (4.236) describe the noise power spectral density of the thermal noise. In this section, the relationship between the quantities S_{id} , S_{ig} , and S_{igid} (as calculated in these equations) and noise sources in the model is defined.

Fig. 6.3 shows a schematic representation of a noiseless transistor (model) and three noise sources. The small-signal noise currents of these noise current sources are indicated by i_{ds} , i_{gs} , and i_{gd} . The two noise sources connected to G are fully correlated. Moreover, each of them is partly correlated with the noise source between S and D. More precisely, the noise powers and correlations associated with these sources are given by

$$\begin{aligned}
 \langle i_{ds} \cdot i_{ds}^* \rangle &= S_{id} \\
 \langle i_{gd} \cdot i_{ds}^* \rangle &= S_{igid}/2 \\
 \langle i_{gs} \cdot i_{ds}^* \rangle &= S_{igid}/2 \\
 \langle i_{gd} \cdot i_{gd}^* \rangle &= S_{ig}/4 \\
 \langle i_{gs} \cdot i_{gd}^* \rangle &= S_{ig}/4 \\
 \langle i_{gs} \cdot i_{gs}^* \rangle &= S_{ig}/4
 \end{aligned} \tag{6.3}$$

The non-listed elements follow from the fact that this is a complex correlation matrix and therefore self-adjoint. This defines the noise model of PSP.

For completeness, we will give the noise correlation matrix associated with the *terminal* currents i_d , i_g and i_s , because it is closer related to the numbers that are obtained in a circuit simulation. Because $i_d = i_{ds} - i_{gs}$, $i_g = i_{gs} + i_{gd}$ and $i_s = i_{gs} - i_{ds}$, we find by straightforward substitution and some basic arithmetic

$$\begin{aligned}
 \langle i_d \cdot i_d^* \rangle &= S_{id} + S_{ig}/4 - \text{Re}(S_{igid}) \\
 \langle i_g \cdot i_d^* \rangle &= S_{igid} - S_{ig}/2 \\
 \langle i_s \cdot i_d^* \rangle &= -S_{id} + S_{ig}/4 - \text{Im}(S_{igid}) \\
 \langle i_g \cdot i_g^* \rangle &= S_{ig} \\
 \langle i_s \cdot i_g^* \rangle &= -S_{igid}^* - S_{ig}/2 \\
 \langle i_s \cdot i_s^* \rangle &= S_{id} + S_{ig}/4 + \text{Re}(S_{igid})
 \end{aligned} \tag{6.4}$$

Verilog-A

In Verilog-A it is not possible to define noise sources that are frequency dependent (except for $1/f$ -noise), nor is it possible to directly define correlations between noise sources. Instead, the desired model must be created by using controlled sources and the frequency transfer of passive elements.²

The goal is to create the three noise sources shown in Fig. 6.3 with the noise powers (including frequency dependence and correlation) as described by Eq. (6.3).

To simplify notation, we rewrite Eqs. (4.235) and (4.236) as

$$S_{ig} = \frac{N_T}{m_{ig}} \cdot |T|^2 \quad (6.5)$$

and

$$S_{igid} = \frac{N_T}{m_{ig}} \cdot m_{igid} \cdot T, \quad (6.6)$$

where

$$T = \frac{j \cdot \omega \cdot \tau}{1 + j \cdot \omega \cdot \tau}, \quad (6.7)$$

$\tau = m_{ig} \cdot C_{Geff}$ and ω is the operating frequency.

Correlation between noise sources in verilog-A can be created by making linear combinations of independent sources. Therefore, we start with two *independent* white noise sources with current noise spectral densities S_1 and S_2 and noise currents i_1 and i_2 . If we set

$$i_{gs} = i_{gd} = \frac{1}{2} \cdot \alpha_1 \cdot i_1 \quad (6.8)$$

$$i_{ds} = \beta_1 \cdot i_1 + \beta_2 \cdot i_2, \quad (6.9)$$

where α_1 , β_1 , and β_2 are certain (complex) coefficients, we get

$$\begin{aligned} S_{ig} &= 4 \cdot \langle i_{gd} \cdot i_{gd}^* \rangle = |\alpha_1|^2 \cdot \langle i_1 \cdot i_1^* \rangle \\ &= |\alpha_1|^2 \cdot S_1 \end{aligned} \quad (6.10)$$

$$\begin{aligned} S_{id} &= \langle i_{ds} \cdot i_{ds}^* \rangle = |\beta_1|^2 \cdot \langle i_1 \cdot i_1^* \rangle + \beta_1 \cdot \beta_2^* \cdot \langle i_1 \cdot i_2^* \rangle + |\beta_2|^2 \cdot \langle i_2 \cdot i_2^* \rangle \\ &= |\beta_1|^2 \cdot S_1 + |\beta_2|^2 \cdot S_2 \end{aligned} \quad (6.11)$$

$$\begin{aligned} S_{igid} &= 2 \cdot \langle i_{gd} \cdot i_{ds}^* \rangle = \alpha_1 \cdot \beta_1^* \cdot \langle i_1 \cdot i_1^* \rangle + \alpha_1 \cdot \beta_2^* \cdot \langle i_1 \cdot i_2^* \rangle \\ &= \alpha_1 \cdot \beta_1^* \cdot S_1. \end{aligned} \quad (6.12)$$

Here we used that the noise currents i_1 and i_2 are independent, such that $\langle i_1 \cdot i_2^* \rangle = 0$. We need to choose proper values for the coefficients α_1 , β_1 and β_2 , as well as S_1 and S_2 , such that S_{ig} , S_{id} , and S_{igid} get the correct value. There is some freedom in choosing the numbers; the values that are used in the verilog-A implementation of PSP are

$$\alpha_1 = T \quad (6.13)$$

$$\beta_1 = m_{igid} \quad (6.14)$$

$$\beta_2 = 1 \quad (6.15)$$

$$S_1 = N_T/m_{ig} \quad (6.16)$$

$$S_2 = N_T \cdot (1 - C_{igid}^2) \cdot m_{id}, \quad (6.17)$$

²Although this appears to be a limitation, it is in fact very helpful to ensure that the resulting noise model is consistent with time-domain simulations.

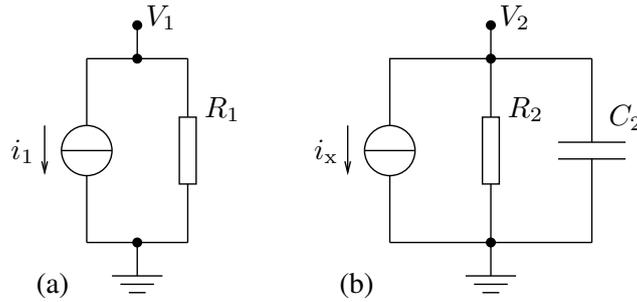


Figure 6.4: The two subcircuits used in PSP's Verilog-A implementation to model the correct frequency dependence of induced gate noise and its correlation with the channel thermal noise.

where

$$C_{\text{igid}} = \frac{m_{\text{igid}}}{\sqrt{m_{\text{ig}} \cdot m_{\text{id}}}}, \quad (6.18)$$

and m_{id} , m_{ig} , and m_{igid} are given by Eqs. (4.231), (4.232), and (4.233), respectively.

To achieve this, we make use of the subcircuits depicted in Fig. 6.4. The first subcircuit (a) contains a parallel connection of a white noise source with current small-signal noise current i_1 and a resistor R_1 . The voltage over the elements is denoted by V_1 . The second subcircuit (b) contains a voltage-controlled current source with current i_x , a resistor R_2 , and a capacitor C_2 . The nodal voltage is denoted by V_2 .

The parameters of these components are given by

$$S_1 = \langle i_1 \cdot i_1^* \rangle = S_{\text{ig}}^0 \cdot s_f^2 \quad (6.19)$$

$$R_1 = 1 \Omega \quad (6.20)$$

$$i_x = -V_1/s_f \quad (6.21)$$

$$R_2 = m_{\text{ig}} \quad (6.22)$$

$$C_2 = C_{\text{Geff}} \quad (6.23)$$

where the values of C_{Geff} is given by Eqs. (4.220) and

$$S_{\text{ig}}^0 = \frac{N_{\text{T}}}{m_{\text{ig}}}. \quad (6.24)$$

Moreover, we introduce a scaling factor $s_f = \omega_0 \cdot m_{\text{ig}} \cdot C_{\text{Geff}}$ with $\omega_0 = 1$ MHz. Note that the value of s_f and ω_0 do not affect the final result, but help to give the noise power of V_1 a reasonable value.

Choosing the elements in this way, creates a frequency dependent current i_C through the capacitor C_2 given by

$$i_C = T \cdot i_x. \quad (6.25)$$

The two noise sources connected to the gate in Fig. 6.3 are now realized as two current-controlled current sources with

$$i_{\text{gd}} = i_{\text{gs}} = \frac{1}{2} \cdot i_C. \quad (6.26)$$

The third source in Fig. 6.3 (between source and drain) is realized by putting two elements in parallel:

- A voltage controlled current source with value $(m_{\text{igid}}/s_f) \cdot V_1$ and
- A white noise source with current power spectral density $S_2 = N_{\text{T}} \cdot (1 - C_{\text{igid}}^2) \cdot m_{\text{id}}$.

To complete the model, we remark that from Fig. 6.3 it is clear that source-drain interchange only affects the sign of i_{ds} .

In summary, the relevant portion of the verilog-A implementation is given by (mult-scaling and labels are not included for clarity):

```

electrical NOI;
electrical NOI2;

branch (NOI) NOII;
branch (NOI) NOIR;
branch (NOI) NOIC;

// subcircuit (a)
I(NOI2) <+ V(NOI2);
I(NOI2) <+ white_noise(sqig * sqig * sf * sf);

// subcircuit (b)
I(NOII) <+ -V(NOI2) / sf;
I(NOIR) <+ V(NOIR) / mig;
I(NOIC) <+ ddt(CGeff * V(NOIC));

// noise sources ids, igs, and igd
I(DI,SI) <+ white_noise(sqid * sqid * (1.0 - c_igid * c_igid));
I(DI,SI) <+ sigVds * migid * V(NOI2) / sf;
I(GP,SI) <+ ddt(0.5 * CGeff * V(NOIC));
I(GP,DI) <+ ddt(0.5 * CGeff * V(NOIC));

```

It is straightforward to verify that this implementation of PSP's noise model in Verilog-A naturally yields the desired correlations and frequency dependence. However, it requires two additional internal nodes.

SiMKit C-code

Contrary to the limitation of Verilog-A language, most circuit simulators are able to directly deal with correlated and frequency dependent noise—without the use of additional internal nodes. In order to minimize the simulation time of the model, C-implementations should therefore avoid the use of such internal nodes whenever possible.

In SiMKit, the frequency dependence and correlation of the noise sources indicated in Fig. 6.3 are implemented directly according to Eq. (6.3). The result is therefore equivalent to the verilog-A implementation.

In summary, even though the SiMKit-implementation of the noise model in PSP is different from that in verilog-A (as it does not make use of additional internal nodes) the result of noise noise simulations will be identical.

6.5.4 Clip warnings

From SiMKit 3.7 onwards, it is possible to set the level of clip-warning information through the value of the parameter **PARAMCHK**. This functionality is available for most SiMKit models. It is *not* available in the verilog-A version of PSP.

If the value of **PARAMCHK** is

- < 0 All clip warnings are suppressed.
- ≥ 0 (default) Clip warnings for instance parameters.
- ≥ 1 Clip warnings for model parameters.
- ≥ 2 Clip warnings for internally computed local parameters during model initialization.
- ≥ 3 Clip warnings for internally computed local parameters during model evaluation.

This works in an accumulative manner: if a higher value of **PARAMCHK** is used, the warnings associated with lower levels are still included. Note that the highest level is of interest only for self heating models, where electrical parameters may change dependent on temperature. Hence, it is currently not applicable to PSP. Also note that the default value (0) results in less clip warnings than in earlier versions of the model.

Section 7

Parameter extraction

The parameter extraction strategy for PSP consists of four main steps:

1. Measurements
2. Extraction of local parameters at room temperature
3. Extraction of temperature scaling parameters
4. Extraction of geometry scaling (global) parameters

The above steps will be briefly described in the following sections. Note that the description of the extraction procedure is not ‘complete’ in the sense that only the most important parameters are discussed and in cases at hand it may be advantageous (or even necessary) to use an adapted procedure.

Throughout this section, bias and current conditions are given for an n -channel transistor only; for a p -channel transistor, all voltages and currents should be multiplied by -1 .

As explained in the introduction, the hierarchical setup of PSP (local and global level) allows for the two-step parameter extraction procedure described in this section; this is the recommended method of operation. Nevertheless, it is possible to skip the first steps and start extracting global parameters directly. This procedure is not described here, but the directions below may still be useful.

7.1 Measurements

The parameter extraction routine consists of six different DC-measurements (two of which are optional) and two capacitance measurements.¹ Measurement V and VI are only used for extraction of gate-current, avalanche, and GIDL/GISL parameters.

- **Measurement I** (“idvg”): I_D vs. V_{GS}
 $V_{GS} = 0 \dots V_{sup}$ (with steps of maximum 50 mV).
 $V_{DS} = 25$ or 50 mV
 $V_{BS} = 0 \dots -V_{sup}$ (3 or more values)
- **Measurement II** (“idvgh”): I_D vs. V_{GS}
 $V_{GS} = 0 \dots V_{sup}$ (with steps of maximum 50 mV).
 $V_{DS} = V_{sup}$
 $V_{BS} = 0 \dots -V_{sup}$ (3 or more values)

¹The bias conditions to be used for the measurements are dependent on the supply voltage of the process. Of course it is advisable to restrict the range of voltages to this supply voltage V_{sup} . Otherwise physical effects atypical for normal transistor operation—and therefore less well described by PSP—may dominate the characteristics.

- **Measurement III** (“idvd”): I_D vs. V_{DS}
 $V_{GS} = 0 \dots V_{sup}$ (3 or more values)
 $V_{DS} = 0 \dots V_{sup}$ (with steps of maximum 50 mV).
 $V_{BS} = 0 \text{ V}$

- **Measurement IV** (“idvdh”, optional): I_D vs. V_{DS}
 $V_{GS} = 0 \dots V_{sup}$ (3 or more values)
 $V_{DS} = 0 \dots V_{sup}$ (with steps of maximum 50 mV).
 $V_{BS} = -V_{sup}$

- **Measurement V** (“igvg”): I_G and I_B vs. V_{GS}
 $V_{GS} = -V_{sup} \dots V_{sup}$ (with steps of maximum 50 mV).
 $V_{DS} = 0 \dots V_{sup}$ (3 or more values)
 $V_{BS} = 0 \text{ V}$

- **Measurement VI** (“igvgh”, optional): I_G and I_B vs. V_{GS}
 $V_{GS} = -V_{sup} \dots V_{sup}$ (with steps of maximum 50 mV).
 $V_{DS} = 0 \dots V_{sup}$ (3 or more values)
 $V_{BS} = -V_{sup}$

- **Measurement VII** (“cgvg”): C_{CG} vs. V_{GS}
 $V_{GS} = -V_{sup} \dots V_{sup}$ (with steps of maximum 50 mV).
 $V_{DS} = 0 \text{ V}$
 $V_{BS} = 0 \text{ V}$

- **Measurement VIII** (“ccvg”): C_{CG} vs. V_{GS}
 $V_{GS} = -V_{sup} \dots V_{sup}$ (with steps of maximum 50 mV).
 $V_{DS} = 0 \text{ V}$
 $V_{BS} = 0 \text{ V}$

For the extraction procedure, the transconductance g_m (for Measurement I and II) and the output conductance g_{DS} (for Measurement III and IV) are obtained by numerical differentiation of the measured I - V -curves. Furthermore, I_{min} is the smallest current which can reliably be measured by the system (noise limit) and I_T is defined as 10% of the largest measured value of $|I_D|$ in Measurement I. The latter will be used to make a rough distinction between the subthreshold and superthreshold region.

The channel-to-gate capacitance C_{CG} in Measurement VIII is the summation of the drain-to-gate capacitance C_{DG} and the source-to-gate capacitance C_{SG} (i.e., source and drain are short-circuited); it is needed to extract overlap capacitance parameters.

The local parameter extraction measurements I through VI have to be performed at room temperature for every device. In addition, capacitance measurements VII and VIII need to be performed for at least a long/wide and a short/wide (i.e., $L = L_{min}$) transistor (at room temperature). Furthermore, for the extraction of temperature scaling parameters measurements I, III, and V have to be performed at different temperatures (at least two extra, typically -40°C and 125°C) for at least a long wide and a short wide transistor.

7.2 Extraction of local parameters at room temperature

General remarks

The simultaneous determination of *all* local parameters for a specific device is not advisable, because the value of some parameters can be wrong due to correlation and suboptimization. Therefore it is more practical to

split the parameters into several small groups, where each parameter group can be determined using specific measurements. In this section, such a procedure will be outlined.

The extraction of local parameters is performed for every device. In order to ensure that the temperature scaling relations do not affect the behavior at room temperature, the reference temperature **TR** should be set equal to room temperature.

Before starting the parameter extraction procedure, one should make sure that **SWIGATE**, **SWIMPACT**, **SWGIDL**, **SWJUNCAP**, and **TYPE** are set to the desired value. Moreover, **QMC** should be set to 1, in order to include quantum mechanical corrections in the simulations.

It is not the case that all local parameters are extracted for every device. Several parameters are only extracted for one or a few devices, while they are kept fixed for all other devices. Moreover, a number of parameters can generally be kept fixed at their default values and need only occasionally be used for fine-tuning in the optimization procedure. Details are given later in this section.

As a special case, it is generally not necessary to extract values for **AX**. In stead, they can be calculated from Eq. (3.57), using **AXO** \sim 18 and **AXL** \sim 0.25. It may be necessary to tune the latter value such that the value of **AX** is between 2 and 3 for the shortest channel in the technology under study.

It is recommended to start the extraction procedure with the long(est) wide(st) device, then the shortest device with the same width, followed by all remaining devices of the same width in order of decreasing length. Then the next widest-channel devices are extracted, where the various lengths are handled in the same order. In this way, one works ones way down to the narrowest channel devices.

AC-parameters

Some parameters (such as **TOX** and **NP**) that do affect the DC-behavior of a MOSFET can only be extracted accurately from *C-V*-measurements.² This should be done before the actual parameter extraction from DC-measurements is started. In Tables 7.1 and 7.2 the extraction procedure for the AC-parameters is given.

Table 7.1: AC-parameter extraction procedure for a long channel MOSFET.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	VFB , NEFF , DPHIB , NP , COX	VII: C_{GG}	Relative	–
2	Repeat Step 1			

Table 7.2: AC-parameter extraction procedure for a short channel MOSFET. The values of **VFB** and **NP** are taken from the long-channel case.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF , DPHIB , COX	VII: C_{GG}	Relative	–
2	CGOV , NOV	VIII: C_{CG}	Relative	$V_{GS} < 0$
3	Repeat Steps 1 and 2			

Starting from the default parameter set and setting **TOX** to a reasonable value (as known from technology), **VFB**, **NEFF**, **DPHIB**, **COX**, and **NP** can be extracted from C_{GG} in Measurement VII for a long, wide device. Next, **NOV** and **CGOV** can be extracted from C_{CG} in Measurement VIII for a short, wide device (see also Table 7.1), where **VFB** and **NP** are taken from the long channel case. In general, one can assume **TOXOV** = **TOX**.

The value of **TOX** can be determined from $\mathbf{COX} = \epsilon_{ox} \cdot L \cdot W / \mathbf{TOX}$. If the device is sufficiently long and wide, drawn length and width can be used in this formula. Even better, if Measurement VII is available for a

²Although parameter **NOV** can be determined from overlap gate current, it is nonetheless more accurately determined from Measurement VIII.

Table 7.3: Initial values for local parameter extraction for a *long*-channel device. For parameters which are not listed in this table, the default value (as given in Section 2.5.7) can be used as initial value.

Parameter	Initial value
BETN	$0.03 \cdot W/L$
RS	0
THESAT	0.1
AX	12
A1	0

few short/wide devices of different lengths, one can extract **TOX** and ΔL from a series of extracted values of **COX** vs. L_{draw} .

Some remarks:

- If C - V -measurements are not available, one could revert to values known from the fabrication process. Note that **TOX** and **TOXOV** are *physical* oxide thicknesses; poly-depletion and quantum-mechanical effects are taken care of by the model. If the gate dielectric is not pure SiO_2 , one should manually compensate for the deviating dielectric constant.
- In general, **VFB** and **NP** can be assumed independent of channel length and width (so, the long/wide-channel values can be used for all other devices as well). Only if no satisfactory fits are obtained, one could allow for a length dependence (for **NP**) or length *and* width dependence (for **VFB**). Then, one should proceed by extracting **VFB** and/or **NP** from capacitance measurements for various channel geometries, fit Eq. (3.12) / Eq. (3.27) to the result and use interpolated values in the DC parameter extraction procedure.
- The value of parameter **TOX** profoundly influences both the DC- and AC-behavior of the PSP-model and thus the values of many other parameters. It is therefore very important that this parameter is determined (as described above) and *fixed* before the rest of the extraction procedure is started.

If desired (e.g., for RF-characterization), parameters for several parasitic capacitances (gate-bulk overlap, fringe capacitance, etc.) can be extracted as well (**CGBOV** and **CFR**). However, this requires additional capacitance measurements.

The obtained values of **VFB**, **TOX**, **TOXOV**, **NP**, and **NOV** can now be used in the DC-parameter extraction procedure. The above values of **NEFF** and **DPHIB** can be disregarded; they will be determined more accurately from the DC-measurements.

DC-parameters

Before the optimization is started a reasonably good starting value has to be determined, both for the parameters to be extracted and for the parameters which remain constant. For most parameters to be extracted for a *long* channel device, the default values from Section 2.5.7 can be taken as initial values. Exceptions are given in Table 7.3. Starting from these values, the optimization procedure following the scheme below is performed. This method yields a proper set of parameters after the repetition indicated as the final step in the scheme. Experiments with transistors of several processes show that repeating those steps more than once is generally not necessary.

For an accurate extraction of parameter values, the parameter set for a long-channel transistor has to be determined first. In the long-channel case most of the mobility related parameters (i.e. **MUE** and **THEMU**) and the gate tunneling parameters (**GCO**, **GC2**, and **GC3**) are determined and subsequently fixed for the shorter-channel devices.

Table 7.4: DC-parameter extraction procedure for a long-channel MOSFET. The parameters **VFB**, **TOX**, **TOXOV**, **NP**, and **NOV** must be taken from C - V -measurements. The optimization is either performed on the absolute or relative deviation between model and measurements, as shown in the table.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF , BETN , MUE , THEMU ^a	I: I_D	Absolute	–
2	NEFF , DPHIB , CT	I: I_D	Relative	$I_{\min} < I_D < I_T$
3	MUE , THEMU ^a , CS , XCOR , BETN	I: I_D , g_m	Absolute	–
4	THESAT	III: I_D	Absolute	–
5	ALP , ALP1 , ALP2 , VP ^a , (AX)	III: g_{DS}	Relative	–
6	THESAT	II: I_D	Absolute	–
7	IGINV , GC2 ^a , GC3 ^a	V: I_G	Relative	$I_G > I_{\min}$
8	IGOV , (GCO ^a)	V: I_G	Relative	$V_{GS} < 0$ V, $I_G < -I_{\min}$
9	A1 , A2 ^a , A3	V: I_B	Relative	$V_{GS} > 0$ V, $I_B < -I_{\min}$
10	A4	VI: I_B	Relative	$V_{GS} > 0$ V, $I_B < -I_{\min}$
11	AGIDL , BGIDL ^a	V: I_B	Relative	$V_{GS} < 0$ V, $I_B < -I_{\min}$
12	CGIDL ^a	VI: I_B	Relative	$V_{GS} < 0$ V, $I_B < -I_{\min}$
13	Repeat Steps 2 – 12			

^aOnly extracted for the *widest* long channel device and fixed for all other geometries.

In Table 7.4 the complete DC extraction procedure for long-channel transistors is given. The magnitude of the simulated I_D and the overall shape of the simulated I_D - V_{GS} -curve is roughly set in Step 1. Next the parameters **NEFF**, **DPHIB**, and **CT**—which are important for the subthreshold behavior—are optimized in Step 2, neglecting short-channel effects such as drain-induced barrier-lowering (DIBL). After that, the mobility parameters are optimized in Step 3, neglecting the influence of series-resistance. In Step 4 a preliminary value of the velocity saturation parameter is obtained, and subsequently the conductance parameters **ALP**, **ALP1**, **ALP2**, and **VP** are determined in Step 5. A more accurate value of **THESAT** can now be obtained using Step 6. The gate current parameters are determined in Steps 7 and 8, where it should be noted that **GCO** should only be extracted if the influence of gate-to-bulk tunneling is visible in the measurements. This is usually the case if $V_{\text{sup}} \gtrsim |\text{VFB}|$. This is followed by the weak-avalanche parameters in Step 9 and (optionally) 10, and finally, the gate-induced leakage current parameters are optimized in Step 11 and (optionally) 12.

After completion of the extraction for the long-channel device, it is recommended to first extract parameters for the shortest-channel device (of the same width). The mobility-reduction parameters (**MUE**, **THEMU**) and the gate tunneling probability factors (**GCO**, **GC2**, **GC3**) found from the corresponding long-channel device should be used. The extraction procedure as given in Table 7.5 should be used.

Once the value for **RS** has been found from the shortest device, it should be copied into the long-channel parameter set and steps 2–3 (Table 7.4) should be repeated, possibly leading to some readjustment of **MUE** and **THEMU**. If necessary, this procedure must be repeated. Similarly—once the value of **THESATG** and **THESATB** have been determined from the shortest widest channel device—steps 4, 5, and 6 of the long-channel extraction procedure (Table 7.4) must be repeated to obtain updated values for **THESAT**, **ALP**, **ALP1**, and **ALP2**.

If consistent parametersets have been found for the longest and shortest channel device, the extraction procedure as given in Table 7.5 can be executed for all intermediate channel lengths. The extracted parameter values of the next-longer device can be used as initial values.

Table 7.5: DC-parameter extraction procedure for a short-channel MOSFET. Parameters **MUE**, **THEMU**, **VP**, **GCO**, **GC2**, **GC3**, **A2**, **A4**, **BGIDL**, and **CGIDL** are taken from the corresponding long-channel case. The optimization is either performed on the absolute or relative deviation between model and measurements, as indicated in the table.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF , DPHIB , BETN , RS^a	I: I_D	Absolute	–
2	NEFF , DPHIB , CT	I: I_D	Relative	$I_{\min} < I_D < I_T$
3	BETN , RS^a , XCOR	I: I_D , g_m	Absolute	–
4	THESAT	III: I_D	Absolute	–
5	ALP , ALP1 , ALP2 , CF , (AX)	III: g_{DS}	Relative	–
6	CFB^b	IV: g_{DS}	Relative	–
7	THESAT , THESATG^b , THESATB^b	II: I_D , g_m	Absolute	–
8	IGINV , IGOV	V: I_G	Relative	$ I_G > I_{\min}$
9	A1 , A3	V: I_B	Relative	$V_{GS} > 0 \text{ V}$, $I_B < -I_{\min}$
10	AGIDL	V: I_B	Relative	$V_{GS} < 0 \text{ V}$, $I_B < -I_{\min}$
11	Repeat Steps 2 – 10			

^aOnly extracted for the *shortest* channel of each width and fixed for all other geometries.

^bOnly extracted for the *shortest widest* device and fixed for all other geometries.

Table 7.6: Temperature scaling parameter extraction procedure for a long wide channel MOSFET. This scheme only makes sense if measurements have been performed at one or (preferably) more temperatures which differ from room temperature.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	STVFB^a	I: I_D	Relative	$I_D < I_T$
2	STBETN^a , STMUE , STTHEMU , STCS , STXCOR	I: I_D	Absolute	–
3	STTHESAT^a	II: I_D	Absolute	–
4	STIG	V: I_G	Relative	$ I_G > I_{\min}$
5	STA2	V: I_B	Relative	$V_{GS} > 0 \text{ V}$, $I_B < -I_{\min}$
6	STBGIDL	V: I_B	Relative	$V_{GS} < 0 \text{ V}$, $I_B < -I_{\min}$

^aAlso extracted for one or more long *narrow* devices.

7.3 Extraction of Temperature Scaling Parameters

For a specific device, the temperature scaling parameters can be extracted after determination of the local parameters at room temperature. In order to do so, measurements I, II and IV need to be performed at various temperature values (at least two values different from room temperature, typically $-40 \text{ }^\circ\text{C}$ and $125 \text{ }^\circ\text{C}$), at least for a long wide device and a short wide device. If the reference temperature **TR** has been chosen equal to room temperature (as recommended in Section 7.2), the modeled behavior at room temperature is insensitive to the value of the temperature scaling parameters. As a first-order estimate of the temperature scaling parameter values, the default values as given in Section 2.5.7 can be used. Again the parameter extraction scheme is slightly different for the long-channel and for the short-channel case.

For an accurate extraction, the temperature scaling parameters for a long-wide-channel device have to be de-

Table 7.7: Temperature scaling parameter extraction procedure for short-channel MOSFETs (both wide and narrow). This scheme only makes sense if measurements have been performed at one or (preferably) more temperatures which differ from room temperature.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	STVFB	I: I_D	Relative	$V_{GS} < V_T$
2	STBETN, STRS^a	I: I_D	Absolute	$V_{GS} > V_T$
3	STTHESAT	II: I_D	Absolute	–

^aOnly extracted for a short *narrow* device and fixed for all other geometries.

terminated first. In the long-wide-channel case the carrier mobility parameters can be determined, and they are subsequently fixed for all other devices. In Table 7.6 the appropriate extraction procedure is given. In Step 1 the subthreshold temperature dependence is optimized, followed by the optimization of mobility reduction parameters in Step 2. Next the temperature dependence of velocity saturation is optimized in Step 3. In the subsequent steps, parameters for the temperature dependence of the gate current, the impact ionization current and gate-induced drain leakage are determined. The determined values of the mobility reduction temperature scaling parameters (i.e., **STMUE**, **STTHEMU**, **STCS**, and **STXCOR**) are copied to all other devices and kept fixed during the remainder of the temperature-scaling parameter extraction procedure. Step 1 and 2 could then be performed on one or more long narrow devices as well (for **STVFB**, **STBETN**, and **STTHESAT** only).

Next the extraction procedure as given in Table 7.7 is carried out for several short devices of different widths. Preferably, the extraction is done first for a short narrow device, such that the determined value of **STRS** can be used during the extraction of the wider devices.

7.4 Extraction of Geometry Scaling Parameters

The aim of the complete extraction procedure is the determination of the geometry scaling parameters (global parameters), i.e., a single set of parameters (see Section 2.5.3) which gives a good description of the MOSFET-behavior over the full geometry range of a CMOS technology.

Determination of ΔL and ΔW

An extremely important part of the geometry scaling extraction scheme is an accurate determination of ΔL and ΔW , see Eqs. (3.6) and (3.7).³ Since it affects the DC-, the AC- as well as the noise model and, moreover, it can heavily influence the quality of the resulting global parameter set, it is very important that this step is carried out with care.

Traditionally, ΔW can be determined from the extrapolated zero-crossing in **BETN** versus mask width W . In a similar way ΔL can be determined from $1/\mathbf{BETN}$ versus mask length L . For modern MOS devices with pocket implants, however, it has been found that the above ΔL extraction method is no longer valid [13, 14]. Another, more accurate method is to measure the gate-to-bulk capacitance C_{GB} in accumulation for different channel lengths [14, 15]. In this case the extrapolated zero-crossing in the C_{GB} versus mask length L curve will give ΔL . Similarly, the extracted values for **COX** (from the procedure in Table 7.1 and 7.2) vs. mask length L may be used for this purpose. Unfortunately for CMOS technologies in which gate current is non-negligible, capacitance measurements may be hampered by gate current [16]. In this case gate current parameter **IGINV** plotted as a function of channel length L may be used to extract ΔL [16]. If possible, ΔL extraction from C - V -measurements is the preferred method.

Finally, **LOV** can be obtained from (a series of) extracted values of **CGOV** from one or more short devices.

³Note that ΔL_{PS} and ΔW_{OD} are expected to be known from the fabrication process. So, in fact, only **LAP** and **WOT** are extracted from the electrical measurements.

From local to global

First of all, the global parameters **TYPE**, **QMC**, and the ‘switch’-parameters should be set to the appropriate value. Next, parameters for which no geometrical scaling rules exist must be taken directly from the local set (this applies to **TR**, **TOXO**, **VNSUBO**, **NSLPO**, **DNSUBO**, **TOXOVO**, **NOVO**, **CFBO**, **STMUEO**, **THE-MUO**, **STTHEMUO**, **STCSO**, **STXCORO**, **FETAO**, **STRSO**, **RSBO**, **RSGO**, **THESATBO**, **THESATGO**, **VPO**, **A2O**, **STA2O**, **GCOO**, **STIGO**, **GC2O**, **GC3O**, **CHIBO**, **BGIDLO**, **STBGIDLO**, **CGIDLO**, and **DTA**). Generally, these parameters have been left at their default values or they have been extracted for one device only and subsequently fixed for all other devices. The parameters **LVARO**, **LVARL**, **LVARW**, **WVARO**, **WVARL**, and **WVARW** should be known from technology.

Once the values of ΔL and ΔW are firmly established (as described above), **LAP** and **WOT** can be set and the actual extraction procedure of the geometry scaling parameters can be started. It consists of several *independent* sub-steps (which can be carried out in random order), one for each geometry dependent local parameter.

To illustrate such a sub-step, the local parameter **CT** is taken as an example. The relevant geometry scaling equation from Section 3.2 is Eq. (3.28), from which it can be seen that **CTO**, **CTL**, **CTLEXP**, and **CTW** are the global parameters which determine the value of **CT** as a function of L and W . First, the extracted **CT** of each device in a length-series of measured (preferably wide) devices are considered as a function of L . In this context **CTO**, **CTL**, and **CTLEXP** are optimized such that the fit of Eq. (3.28) to the extracted **CT**-values is as good as possible, while keeping **CTW** fixed at 0. Then **CTW** is determined by considering the extracted **CT**-values from a length-series of measured narrow devices. Finally, the four global parameters may be fine-tuned by optimizing all four parameters to all extracted **CT**-values simultaneously. The default values given in Section 2.5.3 are good initial values for the optimization procedure.

All other parameters can be extracted in a similar manner. The local parameters **BETN** and **NEFF** have quite complicated scaling rules, particularly due to the non-uniform doping profiles employed in modern CMOS technologies. Therefore, a few additional guidelines are in place.

- The optimization procedure for **BETN** is facilitated if not **BETN**, but $\text{BETN}_{\text{sq}} \stackrel{\text{def}}{=} \text{BETN} \cdot L_E/W_E$ is considered.
- Starting from the default values, first **UO**, **FBET1**, **LP1**, **FBET2**, and **LP2** should be determined from a length-series of wide devices. Then **BETW1**, **BETW2**, and **WBET** should be determined from a width-series of long devices. Finally, **FBET1W** and **LP1W** can be found by considering some short narrow devices.
- Starting from the default values, first extract **FOL1**, **FOL2**, **NSUBO**, **NPCK**, and **LPCK** from a length-series of wide devices. Here, **NSUBO** determines the long-channel value of **NEFF**. Moreover, **NPCK** and **LPCK** determine the increase of **NEFF** for shorter channels (reverse short channel effect), while **FOL1** and **FOL2** are used to describe the decrease of **NEFF** for very short channels (short channel effect).
- Then **NSUBW** and **WSEG** can be determined from a width-series of long devices. Finally, **NPCKW**, **LPCKW** and **WEGP** are determined from a width-series of short devices.
- Especially for **BETN** and **NEFF** it is advisable—after completing the procedure described above—to fine tune the global parameters found by considering all extracted values of **BETN** (or **NEFF**) simultaneously.

Note that in many cases it may not be necessary to use the full flexibility of PSP’s parameter scaling, e.g., for many technologies **NP** and **VFB** may be considered as independent of geometry. If such a geometry-independence is anticipated, the corresponding local parameter should be fixed during local parameter extraction. Only if the resulting global parameter set is not satisfactory, the parameter should be allowed to vary during a subsequent optimization round.

Fine tuning

Once the complete set of global parameters is found, the global model should give an accurate description of the measured I - V -curves and capacitance measurements. Either for fine tuning or to facilitate the extraction

of global parameters for which the geometry scaling of the corresponding extracted local parameters is not well-behaved, there are two more things that can be done.

- Local parameters for which the fitting of global parameters was completed satisfactorily could be replaced by the values calculated from the geometrical scaling rules and fixed. Then one could redo (parts of) the local parameter extraction procedure for the remaining local parameters, making them less sensitive for cross-correlations.
- Small groups of global parameters may be fitted directly to the measurements of a well-chosen series of devices, using the global model.

7.5 Summary – Geometrical scaling

Summarizing, for the determination of a full parameter set, the following procedure is recommended.

1. Determine local parameter sets (**VFB**, **NEFF**, ...) for all measured devices, as explained in Section 7.2 and 7.3.
2. Find ΔL and ΔW .
3. Determine the global parameters by fitting the appropriate geometry scaling rules to the extracted local parameters.
4. Finally, the resulting global can be fine-tuned, by fitting the result of the scaling rules and current equations to the measured currents of all devices simultaneously.

7.6 Extraction of Binning Parameters

In this section, expressions will be given for the parameters in the binning scaling rules, **POYYY**, **PLYYY**, **PWYYY**, and **PLWYYY**, as given in Section 3.3. These coefficients will be expressed in terms of parameter values at the corners of bin (see Fig. 7.1). These expressions can be easily found by substituting the parameter values at the bin corners into the binning scaling rules and inverting the resulting four equations. Note once

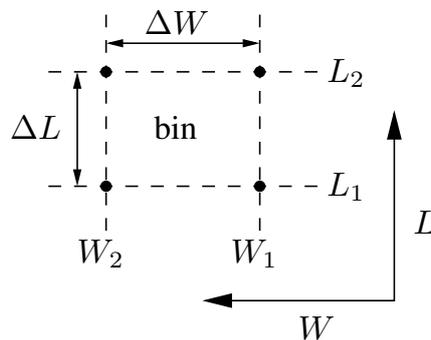


Figure 7.1: Schematic view of a bin, showing the coordinates of the four corners. Note that L_1 , L_2 , W_1 , and W_2 denote the *effective* length and width (L_E and W_E) at the bin corners.

more that this results in a *separate parameter set for each bin*.

In the expression below, the value of parameter **YYY** at bin corner (L_i, W_j) is denoted by Y_{ij} ($i = 1, 2$, $j = 1, 2$). Moreover, $\Delta L = L_2 - L_1$, $\Delta W = W_2 - W_1$, $A = 1/(\Delta L \cdot \Delta W)$.

1. Coefficients for type I scaling

$$\mathbf{POYYY} = A \cdot (L_1 \cdot W_1 \cdot Y_{11} - L_1 \cdot W_2 \cdot Y_{12} - L_2 \cdot W_1 \cdot Y_{21} + L_2 \cdot W_2 \cdot Y_{22}) \quad (7.1)$$

$$\mathbf{PLYYY} = A \cdot \frac{L_1 \cdot L_2}{L_{\text{EN}}} \cdot (-W_1 \cdot Y_{11} + W_2 \cdot Y_{12} + W_1 \cdot Y_{21} - W_2 \cdot Y_{22}) \quad (7.2)$$

$$\mathbf{PWYYY} = A \cdot \frac{W_1 \cdot W_2}{W_{\text{EN}}} \cdot (-L_1 \cdot Y_{11} + L_1 \cdot Y_{12} + L_2 \cdot Y_{21} - L_2 \cdot Y_{22}) \quad (7.3)$$

$$\mathbf{PLWYYY} = A \cdot \frac{L_1 \cdot L_2 \cdot W_1 \cdot W_2}{L_{\text{EN}} \cdot W_{\text{EN}}} \cdot (Y_{11} - Y_{12} - Y_{21} + Y_{22}) \quad (7.4)$$

2. Coefficients for type II scaling

$$\mathbf{POYYY} = A \cdot (L_2 \cdot W_2 \cdot Y_{11} - L_2 \cdot W_1 \cdot Y_{12} - L_1 \cdot W_2 \cdot Y_{21} + L_1 \cdot W_1 \cdot Y_{22}) \quad (7.5)$$

$$\mathbf{PLYYY} = A \cdot L_{\text{EN}} \cdot (-W_2 \cdot Y_{11} + W_1 \cdot Y_{12} + W_2 \cdot Y_{21} - W_1 \cdot Y_{22}) \quad (7.6)$$

$$\mathbf{PWYYY} = A \cdot W_{\text{EN}} \cdot (-L_2 \cdot Y_{11} + L_2 \cdot Y_{12} + L_1 \cdot Y_{21} - L_1 \cdot Y_{22}) \quad (7.7)$$

$$\mathbf{PLWYYY} = A \cdot L_{\text{EN}} \cdot W_{\text{EN}} \cdot (Y_{11} - Y_{12} - Y_{21} + Y_{22}) \quad (7.8)$$

3. Coefficients for type III scaling

$$\mathbf{POYYY} = A \cdot (-L_1 \cdot W_2 \cdot Y_{11} + L_1 \cdot W_1 \cdot Y_{12} + L_2 \cdot W_2 \cdot Y_{21} - L_2 \cdot W_1 \cdot Y_{22}) \quad (7.9)$$

$$\mathbf{PLYYY} = A \cdot \frac{L_1 \cdot L_2}{L_{\text{EN}}} \cdot (W_2 \cdot Y_{11} - W_1 \cdot Y_{12} - W_2 \cdot Y_{21} + W_1 \cdot Y_{22}) \quad (7.10)$$

$$\mathbf{PWYYY} = A \cdot W_{\text{EN}} \cdot (L_1 \cdot Y_{11} - L_1 \cdot Y_{12} - L_2 \cdot Y_{21} + L_2 \cdot Y_{22}) \quad (7.11)$$

$$\mathbf{PLWYYY} = A \cdot \frac{L_1 \cdot L_2 \cdot W_{\text{EN}}}{L_{\text{EN}}} \cdot (-Y_{11} + Y_{12} + Y_{21} - Y_{22}) \quad (7.12)$$

Note: For L_1 , L_2 , W_1 , and W_2 in the formulas above one must take the *effective* length and width (L_{E} and W_{E}) as defined in Section 3.2.

Section 8

DC Operating Point Output

The DC operating point output facility gives information on the state of a device at its operation point. Beside terminal currents and voltages, the magnitudes of linearized internal elements are given. In some cases meaningful quantities can be derived which are then also given (e.g., f_T). The objective of the DC operating point facility is twofold:

- Calculate small-signal equivalent circuit element values
- Open a window on the internal bias conditions of the device and its basic capabilities.

All accessible quantities are described in the table below. The symbols in the ‘value’ column are defined in Section 4. Besides, the following notation is used: $P_D = 1 + k_p \cdot G/4$, where k_p is defined in Eq. (4.16).

Important note: For *all* operating point output the signs are such as if the device is an NMOS. Moreover, whenever there is a reference to the ‘drain’, this is always the terminal which is acting as drain for the actual bias conditions. This is even true for variables such as **vds** (which is therefore always nonnegative) and the junction-related variables. The output variable **sdint** shows whether or not this ‘drain’ is the same as the terminal which was named ‘drain’ in the simulator.

No.	Name	Unit	Value	Description
0	ctype	–	1 for NMOS, –1 for PMOS	Flag for channel-type
1	sdint	–	1 if $V'_{DS} \geq 0$, –1 otherwise	Flag for source-drain interchange
Current components				
2	ise	A	$I_S - I_{JS}$	Total source current
3	ige	A	I_G	Total gate current
4	ide	A	$I_D - I_{JD}$	Total drain current
5	ibe	A	$I_B + I_{JS} + I_{JD}$	Total bulk current
6	ids	A	I_{DS}	Drain current, excl. avalanche and tunnel currents
7	idb	A	$I_{avl} + I_{gidl} - I_{JD}$	Drain-to-bulk current
8	isb	A	$I_{gisl} - I_{JS}$	Source-to-bulk current
9	igs	A	$I_{GCS} + I_{GSov}$	Gate-source tunneling current
10	igd	A	$I_{GCD} + I_{GDov}$	Gate-drain tunneling current
11	igb	A	I_{GB}	Gate-bulk tunneling current
12	igcs	A	I_{GCS}	Gate-channel tunneling current (source component)

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No.	Name	Unit	Value	Description
13	igcd	A	I_{GCD}	Gate-channel tunneling current (drain component)
14	iavl	A	I_{avl}	Substrate current due to weak-avalanche
15	igisl	A	I_{gisl}	Gate-induced source leakage current
16	igidl	A	I_{gidl}	Gate-induced drain leakage current
Junction currents				
17	ijs	A	I_{JS}	Total source junction current
18	ijsbot	A	$I_{JS,bot}$	Source junction current, bottom component
19	ijsgat	A	$I_{JS,gat}$	Source junction current, gate-edge component
20	ijssti	A	$I_{JS,sti}$	Source junction current, STI-edge component
21	ijd	A	I_{JD}	Total drain junction current
22	ijdbot	A	$I_{JD,bot}$	Drain junction current, bottom component
23	ijdgat	A	$I_{JD,gat}$	Drain junction current, gate-edge component
24	ijdsti	A	$I_{JD,sti}$	Drain junction current, STI-edge component
Voltages				
25	vds	V	V_{DS}	Drain-source voltage
26	vgs	V	V_{GS}	Gate-source voltage
27	vsb	V	V_{SB}	Source-bulk voltage
28	vto	V	$\mathbf{VFB} + P_D \cdot (\phi_B + 2 \cdot \phi_T^*) + G \cdot \sqrt{\phi_T^* \cdot (\phi_B + 2 \cdot \phi_T^*)}$	Zero-bias threshold voltage
29	vts	V	$\mathbf{VFB} + P_D \cdot (V_{SB}^* + \phi_B + 2 \cdot \phi_T^*) - V_{SB}^* + G \cdot \sqrt{\phi_T^* \cdot (V_{SB}^* + \phi_B + 2 \cdot \phi_T^*)}$	Threshold voltage including back-bias effects
30	vth	V	$\mathbf{vts} - \Delta V_G$	Threshold voltage including back-bias and drain-bias effects
31	vgt	V	$\mathbf{vgs} - \mathbf{vth}$	Effective gate drive voltage including drain- and back-bias effects
32	vdss	V	V_{dsat}	Drain saturation voltage at actual bias
33	vsat	V	$V_{DS} - V_{dsat}$	Saturation limit
(Trans-)conductances				
34	gm	A/V	$\partial \mathbf{id} / \partial V_{GS}$	Transconductance
35	gmb	A/V	$-\partial \mathbf{id} / \partial V_{SB}$	Substrate-transconductance
36	gds	A/V	$\partial \mathbf{id} / \partial V_{DS}$	Output conductance
37	gjs	A/V	$-\partial \mathbf{ijs} / \partial V_{SB}$	Source junction conductance

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No.	Name	Unit	Value	Description
38	gjd	A/V	$-(\partial i_{jd}/\partial V_{DS} + \partial i_{jd}/\partial V_{SB})$	Drain junction conductance
Capacitances				
39	cdd	F	$\partial Q_D^{(i)}/\partial V_{DS}$	Drain capacitance
40	cdg	F	$-\partial Q_D^{(i)}/\partial V_{GS}$	Drain-gate capacitance
41	cds	F	cdd - cdg - cdb	Drain-source capacitance
42	cdb	F	$\partial Q_D^{(i)}/\partial V_{SB}$	Drain-bulk capacitance
43	cgd	F	$-\partial Q_G^{(i)}/\partial V_{DS}$	Gate-drain capacitance
44	cgg	F	$\partial Q_G^{(i)}/\partial V_{GS}$	Gate capacitance
45	cgs	F	cgg - cgd - cgb	Gate-source capacitance
46	cgb	F	$\partial Q_G^{(i)}/\partial V_{SB}$	Gate-bulk capacitance
47	csd	F	$-\partial Q_S^{(i)}/\partial V_{DS}$	Source-drain capacitance
48	csg	F	$-\partial Q_S^{(i)}/\partial V_{GS}$	Source-gate capacitance
49	css	F	csg + csd + csb	Source capacitance
50	csb	F	$\partial Q_S^{(i)}/\partial V_{SB}$	Source-bulk capacitance
51	cbd	F	$-\partial Q_B^{(i)}/\partial V_{DS}$	Bulk-drain capacitance
52	cbg	F	$-\partial Q_B^{(i)}/\partial V_{GS}$	Bulk-gate capacitance
53	cbs	F	cbb - cbd - cbg	Bulk-source capacitance
54	cbb	F	$-\partial Q_B^{(i)}/\partial V_{SB}$	Bulk capacitance
55	cgso	F	$\partial(Q_{sov} + Q_{ofs})/\partial V_{GS}$	Total gate-source overlap capacitance
56	cgdo	F	$\partial(Q_{dov} + Q_{ofd})/\partial V_{DS}$	Total gate-drain overlap capacitance
Junction capacitances				
57	cjs	F	C_{JS}	Total source junction capacitance
58	cjsbot	F	$C_{JS,bot}$	Source junction capacitance, bottom component
59	cjsgat	F	$C_{JS,gat}$	Source junction capacitance, gate-edge component
60	cjssti	F	$C_{JS,sti}$	Source junction capacitance, STI-edge component
61	cjd	F	C_{JD}	Total drain junction capacitance
62	cjdbot	F	$C_{JD,bot}$	Drain junction capacitance, bottom component
63	cjdgat	F	$C_{JD,gat}$	Drain junction capacitance, gate-edge component
64	cjdsti	F	$C_{JD,sti}$	Drain junction capacitance, STI-edge component
Miscellaneous				
65	w_{eff}	m	W_E	Effective channel width for geometrical models
66	l_{eff}	m	L_E	Effective channel length for geometrical models
67	u	-	gm/g_{ds}	Transistor gain

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No.	Name	Unit	Value	Description
68	rout	Ω	$1/g_{ds}$	Small-signal output resistance
69	vearly	V	$ i_{de} /g_{ds}$	Equivalent Early voltage
70	beff	A/V^2	$2 \cdot i_{de} /v_{gt}^2$	Gain factor
71	fug	Hz	$g_m/[2 \cdot \pi \cdot (c_{gg} + c_{gsol} + c_{gdol})]$	Unity gain frequency at actual bias
72	rg	Ω	RG	Gate resistance
Noise				
73	sfl	A^2/Hz	$S_{fl}(1\text{ Hz})$	Flicker noise current spectral density at 1 Hz
74	sqrtsff	V/\sqrt{Hz}	$\sqrt{S_{fl}(1\text{ kHz})}/g_m$	Input-referred RMS white noise voltage spectral density at 1 kHz
75	sqrtsfw	V/\sqrt{Hz}	$\sqrt{S_{id}}/g_m$	Input-referred RMS white noise voltage spectral density
76	sid	A^2/Hz	S_{id}	Channel thermal noise current spectral density
77	sig	A^2/Hz	$S_{ig}(1\text{ kHz})$	Induced gate noise current spectral density at 1 kHz
78	cigid	–	$\frac{m_{igid}}{\sqrt{m_{ig} \cdot m_{id}}}$	Imaginary part of correlation coefficient between S_{ig} and S_{id}
79	fknee	Hz	$1\text{ Hz} \cdot S_{fl}(1\text{ Hz})/S_{id}$	Cross-over frequency above which white noise is dominant
80	sigs	A^2/Hz	S_{igs}	Gate-source current noise spectral density
81	sigd	A^2/Hz	S_{igd}	Gate-drain current noise spectral density
82	siavl	A^2/Hz	S_{avl}	Impact ionization current noise spectral density
83	ssi	A^2/Hz	$S_{S,I}$	Total source junction current noise spectral density
84	sdi	A^2/Hz	$S_{D,I}$	Total drain junction current noise spectral density

From PSP 102.4 onwards, the values of local parameters are provided in the operating point output. They are listed in the table below.

No.	Name	Unit	Description
Process Parameters			
0	lp_vfb	V	Local parameter VFB after T-scaling and clipping
1	lp_stvfb	V/K	Local parameter STVFB after clipping
2	lp_tox	m	Local parameter TOX after clipping
3	lp_epsrox	–	Local parameter EPSROX after clipping
4	lp_neff	m ⁻³	Local parameter NEFF after clipping
5	lp_vnsub	V	Local parameter VNSUB after clipping
6	lp_nslp	V	Local parameter NSLP after clipping
7	lp_dnsb	V ⁻¹	Local parameter DNSUB after clipping
8	lp_dphib	V	Local parameter DPHIB after clipping
9	lp_np	m ⁻³	Local parameter NP after clipping
10	lp_ct	–	Local parameter CT after clipping
11	lp_toxov	m	Local parameter TOXOV after clipping
12	lp_toxovd	m	Local parameter TOXOVD after clipping
13	lp_nov	m ⁻³	Local parameter NOV after clipping
14	lp_novd	m ⁻³	Local parameter NOVD after clipping
DIBL Parameters			
15	lp_cf	–	Local parameter CF after clipping
16	lp_cfb	V ⁻¹	Local parameter CFB after clipping
Mobility Parameters			
17	lp_betn	m ² /V/s	Local parameter BETN after T-scaling and clipping
18	lp_stbet	–	Local parameter STBET after clipping
19	lp_mue	m/V	Local parameter MUE after T-scaling and clipping
20	lp_stmue	–	Local parameter STMUE after clipping
21	lp_themu	–	Local parameter THEMU after T-scaling and clipping
22	lp_stthemu	–	Local parameter STTHEMU after clipping
23	lp_cs	–	Local parameter CS after T-scaling and clipping
24	lp_stcs	–	Local parameter STCS after clipping
25	lp_xcor	V ⁻¹	Local parameter XCOR after T-scaling and clipping
26	lp_stxcor	–	Local parameter STXCOR after clipping
27	lp_feta	–	Local parameter FETA after clipping
Series Resistance Parameters			
28	lp_rs	Ω	Local parameter RS after T-scaling and clipping
29	lp_strs	–	Local parameter STRS after clipping
30	lp_rsb	V ⁻¹	Local parameter RSB after clipping
31	lp_rsg	V ⁻¹	Local parameter RSG after clipping
Velocity Saturation Parameters			
32	lp_thesat	V ⁻¹	Local parameter THESAT after T-scaling and clipping

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No.	Name	Unit	Description
33	lp_stthesat	–	Local parameter STTHESAT after clipping
34	lp_thesatb	V ⁻¹	Local parameter THESATB after clipping
35	lp_thesatg	V ⁻¹	Local parameter THESATG after clipping
Saturation Voltage Parameters			
36	lp_ax	–	Local parameter AX after clipping
Channel Length Modulation (CLM) Parameters			
37	lp_alp	–	Local parameter ALP after clipping
38	lp_alp1	V	Local parameter ALP1 after clipping
39	lp_alp2	V ⁻¹	Local parameter ALP2 after clipping
40	lp_vp	V	Local parameter VP after clipping
Impact Ionization (II) Parameters			
41	lp_a1	–	Local parameter A1 after clipping
42	lp_a2	V	Local parameter A2 after T-scaling and clipping
43	lp_sta2	–	Local parameter STA2 after clipping
44	lp_a3	–	Local parameter A3 after clipping
45	lp_a4	1/√V	Local parameter A4 after clipping
Gate Current Parameters			
46	lp_gco	–	Local parameter GCO after clipping
47	lp_iginv	A	Local parameter IGINV after T-scaling and clipping
48	lp_igov	A	Local parameter IGOV after T-scaling and clipping
49	lp_igovd	A	Local parameter IGOVD after T-scaling and clipping
50	lp_stig	–	Local parameter STIG after clipping
51	lp_gc2	–	Local parameter GC2 after clipping
52	lp_gc3	–	Local parameter GC3 after clipping
53	lp_chib	V	Local parameter CHIB after clipping
Gate-Induced Drain Leakage Parameters			
54	lp_agidl	A/V ³	Local parameter AGIDL after clipping
55	lp_agidld	A/V ³	Local parameter AGIDLD after clipping
56	lp_bgidl	V	Local parameter BGIDL after T-scaling and clipping
57	lp_bgidld	V	Local parameter BGIDLD after T-scaling and clipping
58	lp_stbgidl	V/K	Local parameter STBGIDL after clipping
59	lp_stbgidld	V/K	Local parameter STBGIDLD after clipping
60	lp_cgidl	–	Local parameter CGIDL after clipping
61	lp_cgidld	–	Local parameter CGIDLD after clipping
Charge Model Parameters			
62	lp_cox	F	Local parameter COX after clipping
63	lp_cgov	F	Local parameter CGOV after clipping
64	lp_cgovd	F	Local parameter CGOVD after clipping
65	lp_cgbov	F	Local parameter CGBOV after clipping

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No.	Name	Unit	Description
66	lp_cfr	F	Local parameter CFR after clipping
67	lp_cfrd	F	Local parameter CFRD after clipping
Noise Model Parameters			
68	lp_fnt	–	Local parameter FNT after clipping
69	lp_fntexc	–	Local parameter FNTEXC after clipping
70	lp_nfa	1/V/m ⁴	Local parameter NFA after clipping
71	lp_nfb	1/V/m ²	Local parameter NFB after clipping
72	lp_nfc	V ⁻¹	Local parameter NFC after clipping
73	lp_ef	–	Local parameter EF after clipping
Parasitic Resistance Parameters			
74	lp_rg	Ω	Local parameter RG after clipping
75	lp_rbulk	Ω	Local parameter RBULK after clipping
76	lp_rwell	Ω	Local parameter RWELL after clipping
77	lp_rjuns	Ω	Local parameter RJUNS after clipping
78	lp_rjund	Ω	Local parameter RJUND after clipping
Junction Parameters			
79	cjosbot	F	Bottom component of total zero-bias source junction capacitance at device temperature
80	cjossti	F	STI-edge component of total zero-bias source junction capacitance at device temperature
81	cjoggat	F	Gate-edge component of total zero-bias source junction capacitance at device temperature
82	vbisbot	V	Built-in voltage of source-side bottom junction at device temperature
83	vbissti	V	Built-in voltage of source-side STI-edge junction at device temperature
84	vbisgat	V	Built-in voltage of source-side gate-edge junction at device temperature
85	idsatsbot	A	Total source-side bottom junction saturation current
86	idsatssti	A	Total source-side STI-edge junction saturation current
87	idsatgat	A	Total source-side gate-edge junction saturation current
88	cjosbotd	F	Bottom component of total zero-bias drain junction capacitance at device temperature
89	cjosstd	F	STI-edge component of total zero-bias drain junction capacitance at device temperature
90	cjoggatd	F	Gate-edge component of total zero-bias drain junction capacitance at device temperature
91	vbisbotd	V	Built-in voltage of drain-side bottom junction at device temperature
92	vbisstd	V	Built-in voltage of drain-side STI-edge junction at device temperature
93	vbisgatd	V	Built-in voltage of drain-side gate-edge junction at device temperature

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No.	Name	Unit	Description
94	idsatsbotd	A	Total drain-side bottom junction saturation current
95	idsatsstid	A	Total drain-side STI-edge junction saturation current
96	idsatsgatd	A	Total drain-side gate-edge junction saturation current

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Appendix A

Auxiliary Equations

In this Appendix, some auxiliary functions which are used in the model equations are defined.

The MINA-smoothing function:

$$\text{MINA}(x, y, a) = \frac{1}{2} \cdot \left[x + y - \sqrt{(x - y)^2 + a} \right] \quad (\text{A.1})$$

The MAXA-smoothing function:

$$\text{MAXA}(x, y, a) = \frac{1}{2} \cdot \left[x + y + \sqrt{(x - y)^2 + a} \right] \quad (\text{A.2})$$

The functions $\chi(y)$, its derivatives, σ_1 , and σ_2 , which are used in the explicit approximation of surface potential:

$$\chi(y) = \frac{y^2}{2 + y^2} \quad (\text{A.3})$$

$$\chi'(y) = \frac{4y}{(2 + y^2)^2} \quad (\text{A.4})$$

$$\chi''(y) = \frac{8 - 12y^2}{(2 + y^2)^3} \quad (\text{A.5})$$

$$\nu = a + c \quad (\text{A.6})$$

$$\mu_1 = \frac{v^2}{\tau} + \frac{c^2}{2} - a \quad (\text{A.7})$$

$$\sigma_1(a, c, \tau, \eta) = \frac{a \cdot \nu}{\mu_1 + (c^2/3 - a) \cdot c \cdot \nu / \mu_1} + \eta \quad (\text{A.8})$$

$$\mu_2 = \frac{v^2}{\tau} + \frac{c^2}{2} - a \cdot b \quad (\text{A.9})$$

$$\sigma_2(a, b, c, \tau, \eta) = \frac{a \cdot \nu}{\mu_2 + (c^2/3 - a \cdot b) \cdot c \cdot \nu / \mu_2} + \eta \quad (\text{A.10})$$

Appendix B

Layout parameter calculation

In post-layout simulations, various PSP instance parameters should be supplied either manually or by a layout extraction tool. In this appendix, it is shown how these parameters should be calculated.

Note: These equations are *not* part of the PSP model.

B.1 Stress parameters

B.1.1 Layout effects for irregular shapes

For irregular shapes the following effective values for **SA** and **SB** are to be used (see Fig B.1).

$$\frac{1}{\mathbf{SA}_{\text{eff}} + 0.5 \cdot L} = \sum_{i=1}^n \frac{\mathbf{SW}_i}{W} \cdot \frac{1}{\mathbf{SA}_i + 0.5 \cdot L} \quad (\text{B.1})$$

$$\frac{1}{\mathbf{SB}_{\text{eff}} + 0.5 \cdot L} = \sum_{i=1}^n \frac{\mathbf{SW}_i}{W} \cdot \frac{1}{\mathbf{SB}_i + 0.5 \cdot L} \quad (\text{B.2})$$

B.2 Well proximity effect parameters

The values of the instance parameters **SCA**, **SCB** and **SCC** can be calculated from layout parameters using the equations below.

$$f_A(u) = \frac{\mathbf{SCREF}^2}{u^2} \quad (\text{B.3})$$

$$f_B(u) = \frac{u}{\mathbf{SCREF}} \cdot \exp\left(-10 \cdot \frac{u}{\mathbf{SCREF}}\right) \quad (\text{B.4})$$

$$f_C(u) = \frac{u}{\mathbf{SCREF}} \cdot \exp\left(-20 \cdot \frac{u}{\mathbf{SCREF}}\right) \quad (\text{B.5})$$

$$A_{\text{corner}} = \sum_{i=m+1}^{m+k} \left(\frac{L}{2} \cdot \int_{\mathbf{SCX}_i + \mathbf{SCY}_i}^{\mathbf{SCX}_i + \mathbf{SCY}_i + W} f_A(u) \, du \right) + \sum_{i=n+1}^{n+k} \left(\frac{W}{2} \cdot \int_{\mathbf{SCX}_i + \mathbf{SCY}_i}^{\mathbf{SCX}_i + \mathbf{SCY}_i + L} f_A(u) \, du \right) \quad (\text{B.6})$$

$$\begin{aligned}
 B_{\text{corner}} = \sum_{i=m+1}^{m+k} \left(\frac{L}{2} \cdot \int_{\text{SCX}_i+\text{SCY}_i}^{\text{SCX}_i+\text{SCY}_i+W} f_B(u) \, du \right) \\
 + \sum_{i=n+1}^{n+k} \left(\frac{W}{2} \cdot \int_{\text{SCX}_i+\text{SCY}_i}^{\text{SCX}_i+\text{SCY}_i+L} f_B(u) \, du \right) \quad (\text{B.7})
 \end{aligned}$$

$$\begin{aligned}
 C_{\text{corner}} = \sum_{i=m+1}^{m+k} \left(\frac{L}{2} \cdot \int_{\text{SCX}_i+\text{SCY}_i}^{\text{SCX}_i+\text{SCY}_i+W} f_C(u) \, du \right) \\
 + \sum_{i=n+1}^{n+k} \left(\frac{W}{2} \cdot \int_{\text{SCX}_i+\text{SCY}_i}^{\text{SCX}_i+\text{SCY}_i+L} f_C(u) \, du \right) \quad (\text{B.8})
 \end{aligned}$$

$$\begin{aligned}
 \mathbf{SCA} = \frac{1}{W \cdot L} \cdot \left[\sum_{i=1}^n \left(W_i \cdot \int_{\text{SC}_i}^{\text{SC}_i+L} f_A(u) \, du \right) \right. \\
 \left. + \sum_{i=n+1}^{n+m} \left(L_i \cdot \int_{\text{SC}_i}^{\text{SC}_i+W} f_A(u) \, du \right) + A_{\text{corner}} \right] \quad (\text{B.9})
 \end{aligned}$$

$$\begin{aligned}
 \mathbf{SCB} = \frac{1}{W \cdot L} \cdot \left[\sum_{i=1}^n \left(W_i \cdot \int_{\text{SC}_i}^{\text{SC}_i+L} f_B(u) \, du \right) \right. \\
 \left. + \sum_{i=n+1}^{n+m} \left(L_i \cdot \int_{\text{SC}_i}^{\text{SC}_i+W} f_B(u) \, du \right) + B_{\text{corner}} \right] \quad (\text{B.10})
 \end{aligned}$$

$$\begin{aligned}
 \mathbf{SCC} = \frac{1}{W \cdot L} \cdot \left[\sum_{i=1}^n \left(W_i \cdot \int_{\text{SC}_i}^{\text{SC}_i+L} f_C(u) \, du \right) \right. \\
 \left. + \sum_{i=n+1}^{n+m} \left(L_i \cdot \int_{\text{SC}_i}^{\text{SC}_i+W} f_C(u) \, du \right) + C_{\text{corner}} \right] \quad (\text{B.11})
 \end{aligned}$$

Here, m and n are the number of projections of the well edge along the length and width of the devices, respectively. Moreover, k is the number of corners selected to account for the ‘corner’ effects.

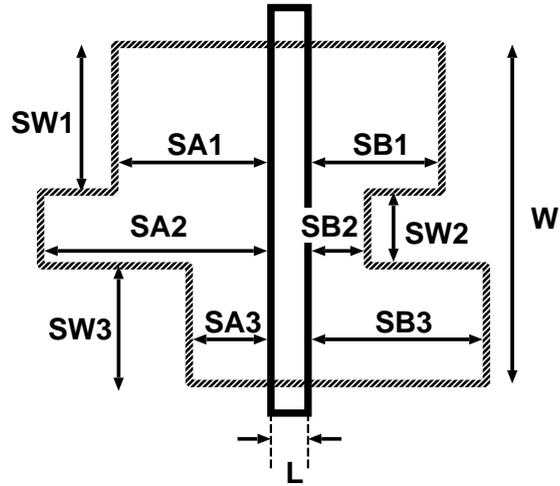


Figure B.1: A typical layout of MOS devices with more instance parameters (SW_i, SA_i and SB_i) in addition to the traditional L and W .

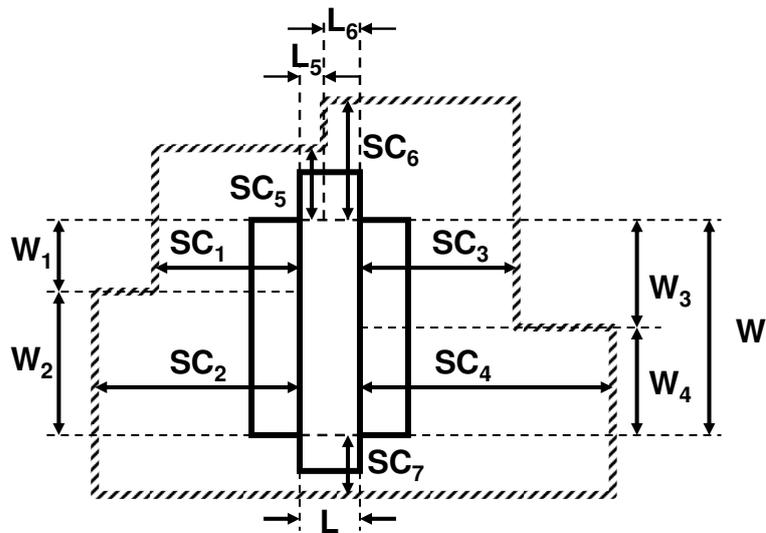


Figure B.2: A typical layout of MOS devices with **WPE** instance parameters

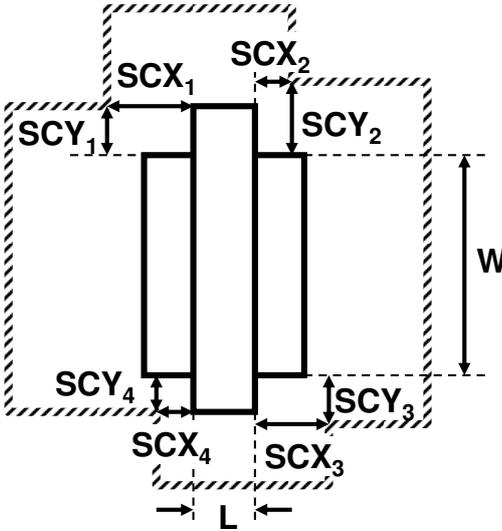


Figure B.3: A layout of MOS devices for corner terms calculation